

# X-ray Nano-Analytics and Microscopy

Part II



Christian G. Schroer  
DESY & Universität Hamburg

# Current State of X-ray Microscopy

## Conventional X-ray microscopy

→ optics limit spatial resolution: diffraction limit

$$d = \frac{\lambda}{2n \sin \alpha}$$

(typically: a few tens of nanometers)

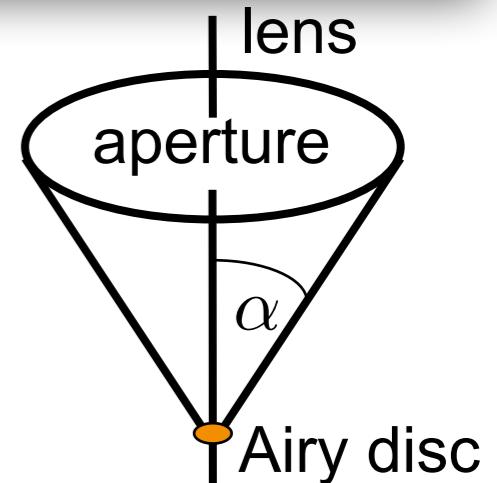
optics are technology limited!

Theoretical extrapolation of X-ray optical performance to the atomic level.

[PRB **74**, 033405 (2006); H. Yan, et al., PRB **76**, 115438 (2007)]



Ernst Abbe



## Coherent X-ray imaging techniques (CXDI, ptychography)

→ no imaging optic!

→ limited by statistics of far-field diffraction patterns ...

highest resolution: a few nanometers, focusing coherent beam

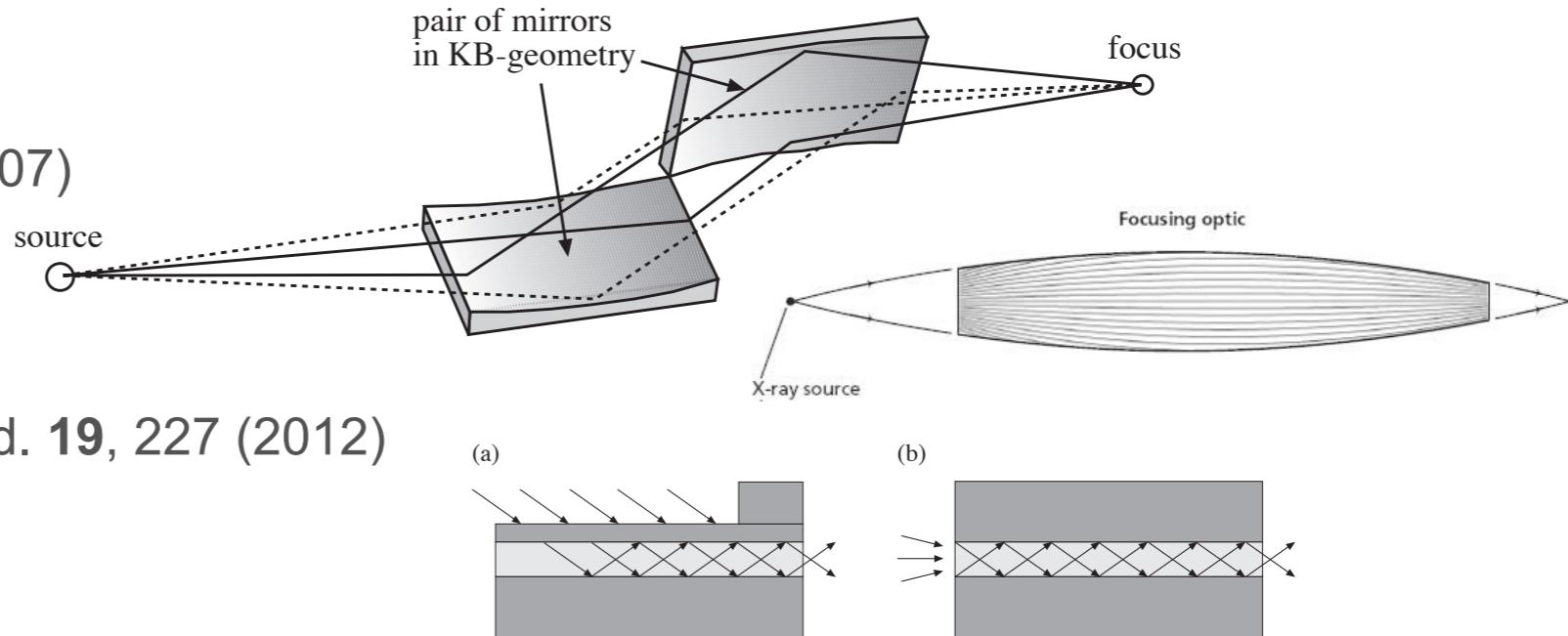
[PRL **101**, 090801 (2008); Y. Takahashi, et al., PRB **80**, 054103 (2009);  
A. Schropp, et al., APL **100**, 253112 (2012)]

# Nanofocusing Optics

## reflection:

- > mirrors (25 nm)

H. Mimura, et al., APL **90**, 051903 (2007)



- > capillaries

- > wave guides (~10 nm)

S. P. Krüger, et al., J. Synchrotron Rad. **19**, 227 (2012)

## diffraction:

- > Fresnel zone plates (< 10 nm)

J. Vila-Comamala, et al., Ultramic. **109**, 1360 (2009)

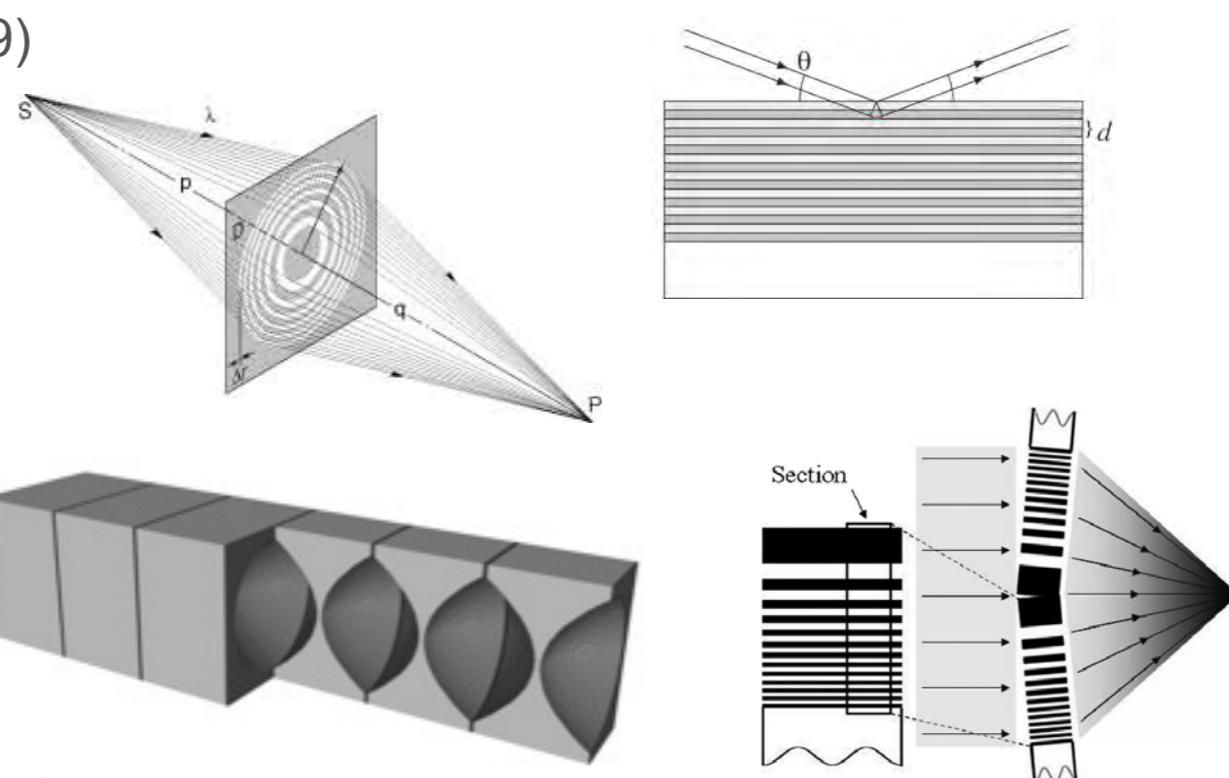
- > multilayer mirrors (7 nm)

H. Mimura, et al., Nat. Phys. **6**, 122 (2010)

- > multilayer Laue lenses (8 x 7 nm)

S. Bajt, et al., Light: Sci. & App. **7**, 17162 (2018)

- > bent crystals



## refraction:

- > lenses (43 nm, 18 nm)

C. G. Schroer, et al., AIP Conf. Ser. **1365**, 227 (2011)

J. Patommel, et al., APL **110**, 101103 (2017)

# Refraction

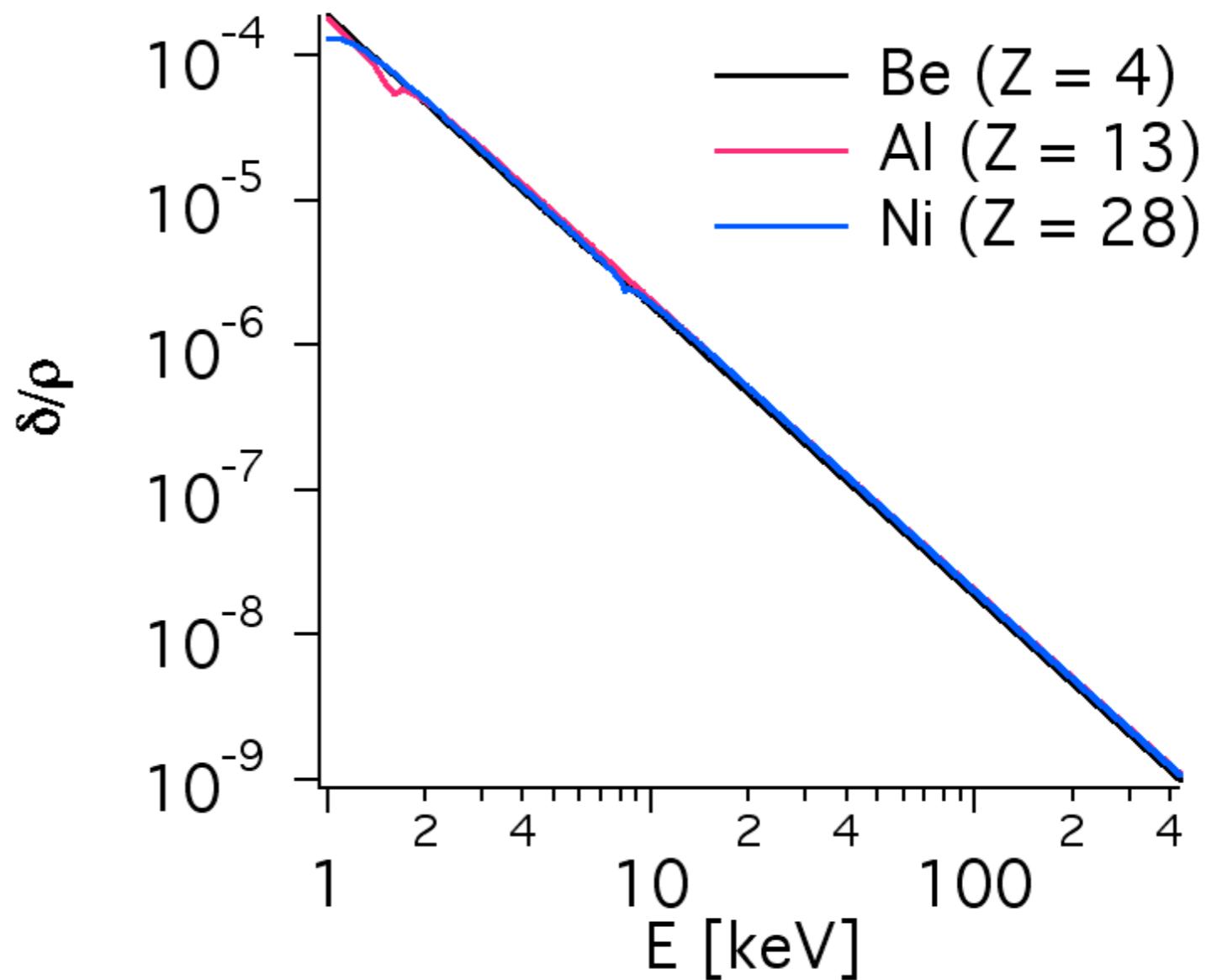
$$n = 1 - \delta + i\beta, \quad \delta > 0$$

Vacuum is optically denser than matter!

$$\delta = \frac{N_A}{2\pi} r_0 \lambda^2 \rho \frac{Z + f'}{A}$$

specific refraction:

- > independent of material
- > very weak



# Absorption

$$n = 1 - \delta + i\beta, \quad \delta > 0$$

Lambert-Beer law:

$$I(x) = I_0 e^{-\mu x}$$

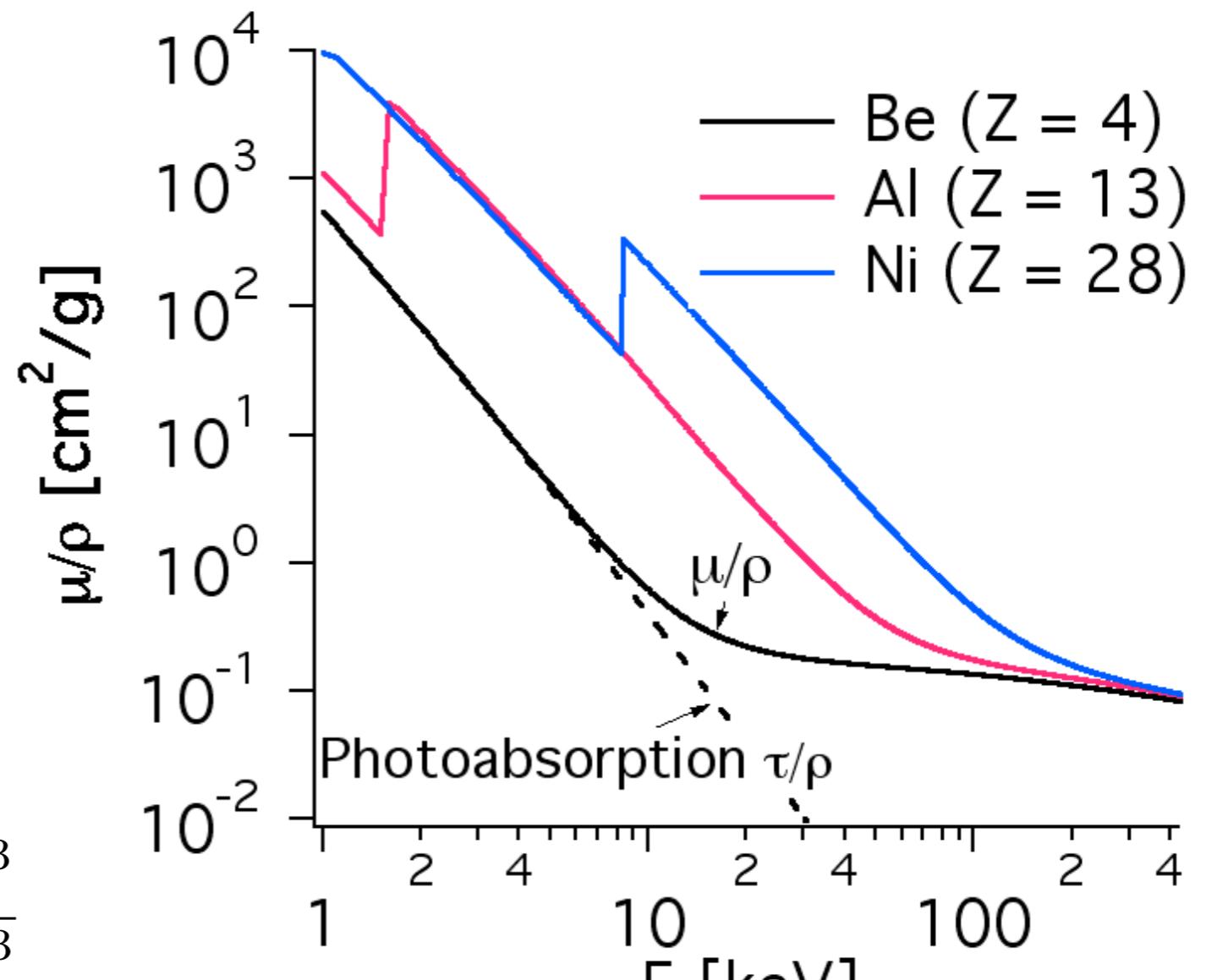
attenuation coefficient  $\mu$ :

$$\mu = \frac{4\pi\beta}{\lambda}$$

two main contributions:

> photoabsorption  $\tau \propto \frac{Z^3}{E^3}$

> Compton scattering  $\mu_C$



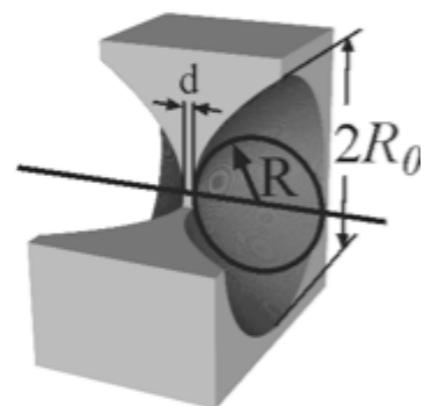
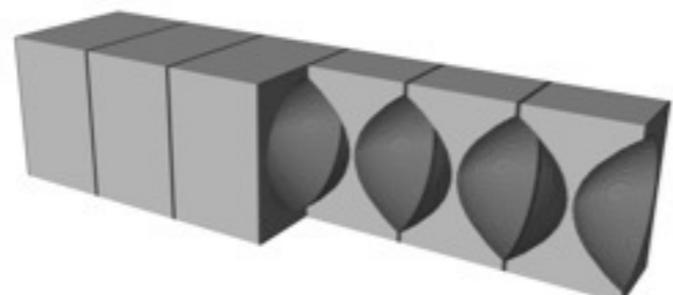
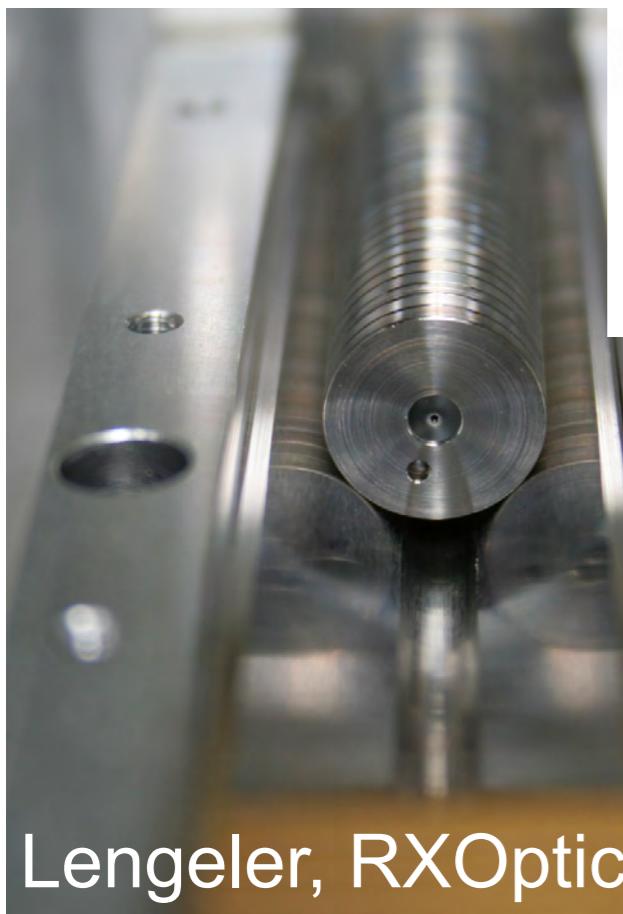
for comparison:  $\mu_{\text{glas}} = 10^{-7} \text{ cm}^{-1}$

for visible light!

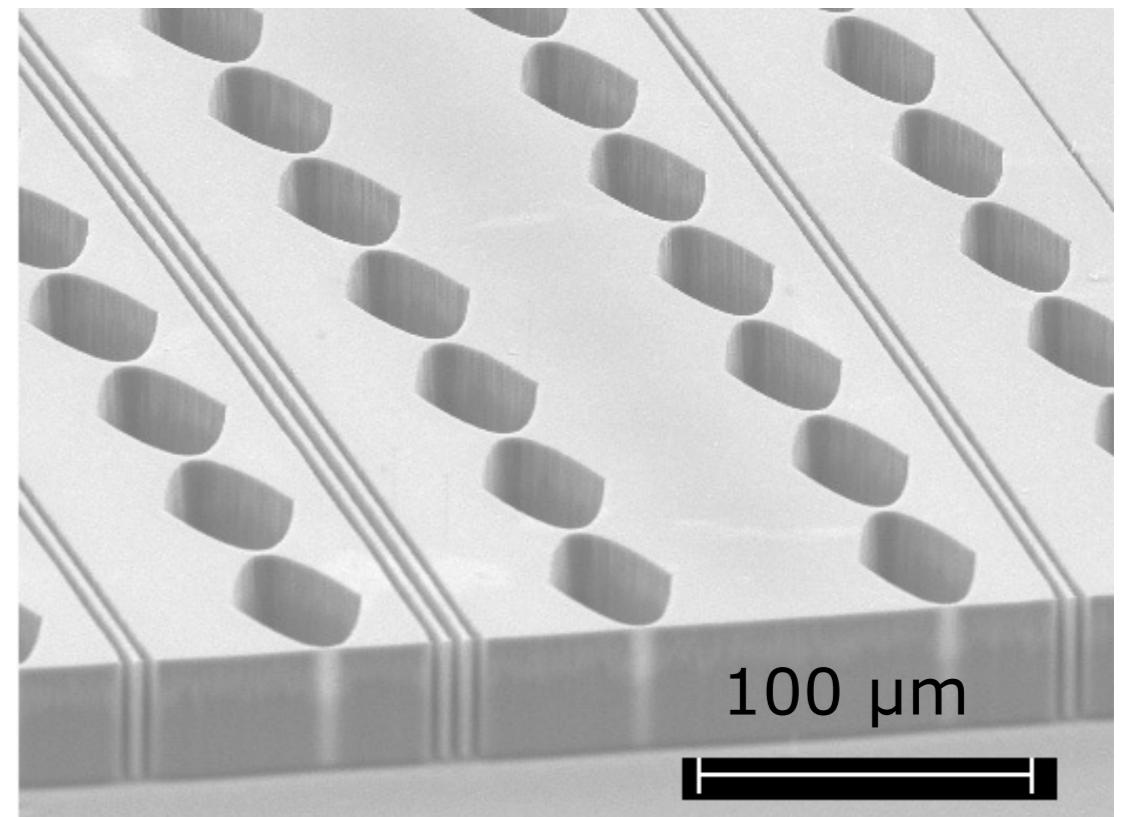
# Refractive X-Ray Lenses

- > first realized in 1996 (Snigirev et al.)
- > a variety of refractive lenses have been developed since
- > applied in full-field imaging and scanning microscopy
- > most important to achieve optimal performance:

parabolic lens shape



nanofocusing lenses



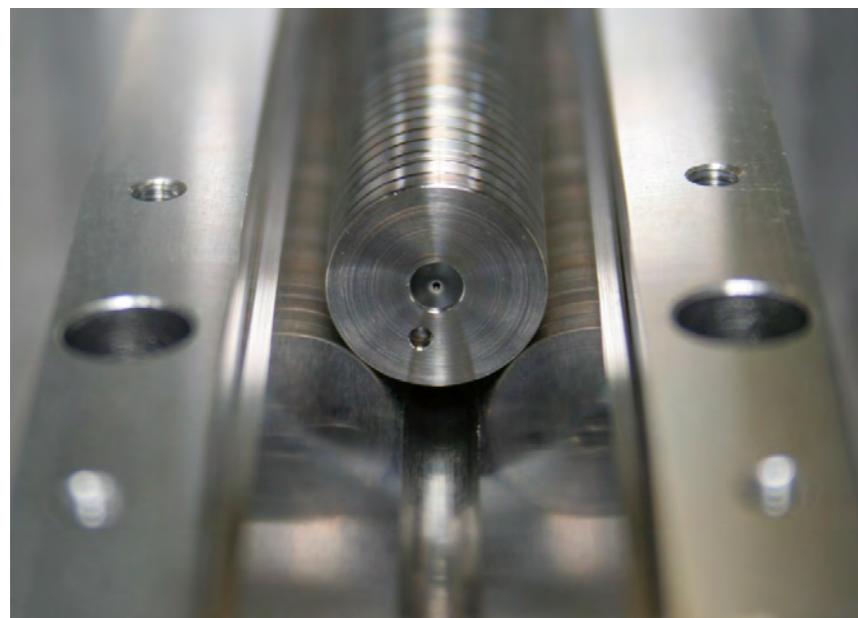
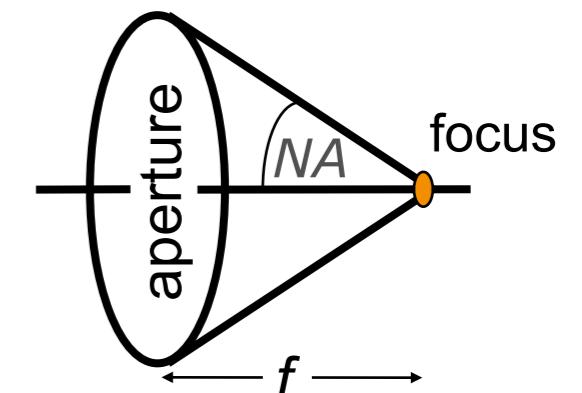
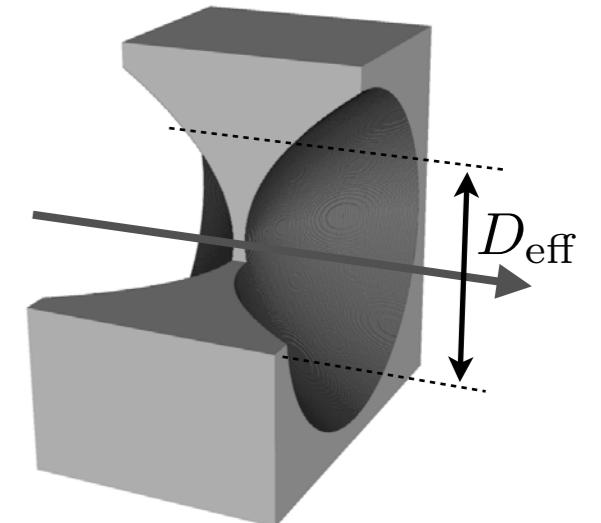
Lengeler, RXOptics

# Nanofocus

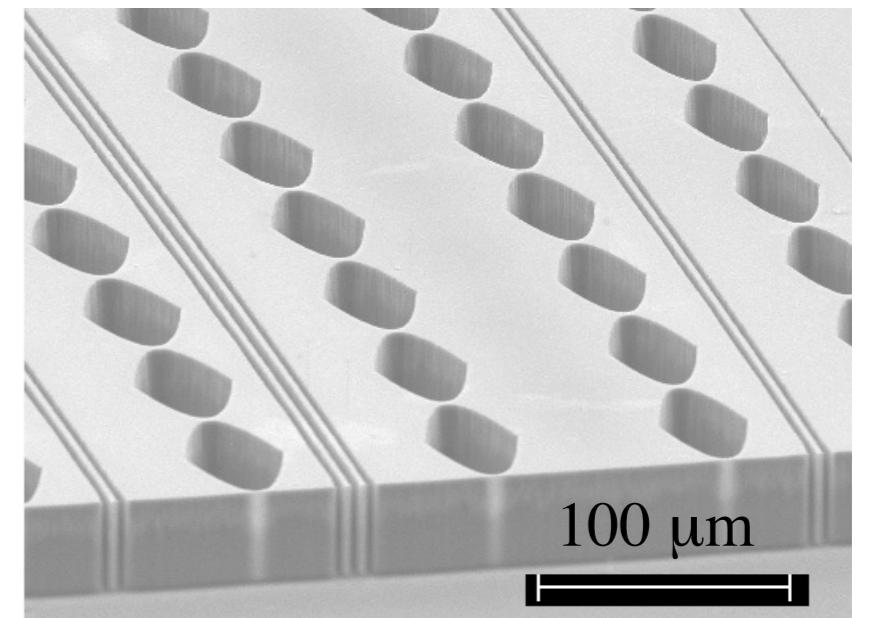
Large focal length  $f$ : aperture limited by absorption

$$D_{\text{eff}} = 4 \sqrt{\frac{f\delta}{\mu}} \propto \sqrt{f}$$

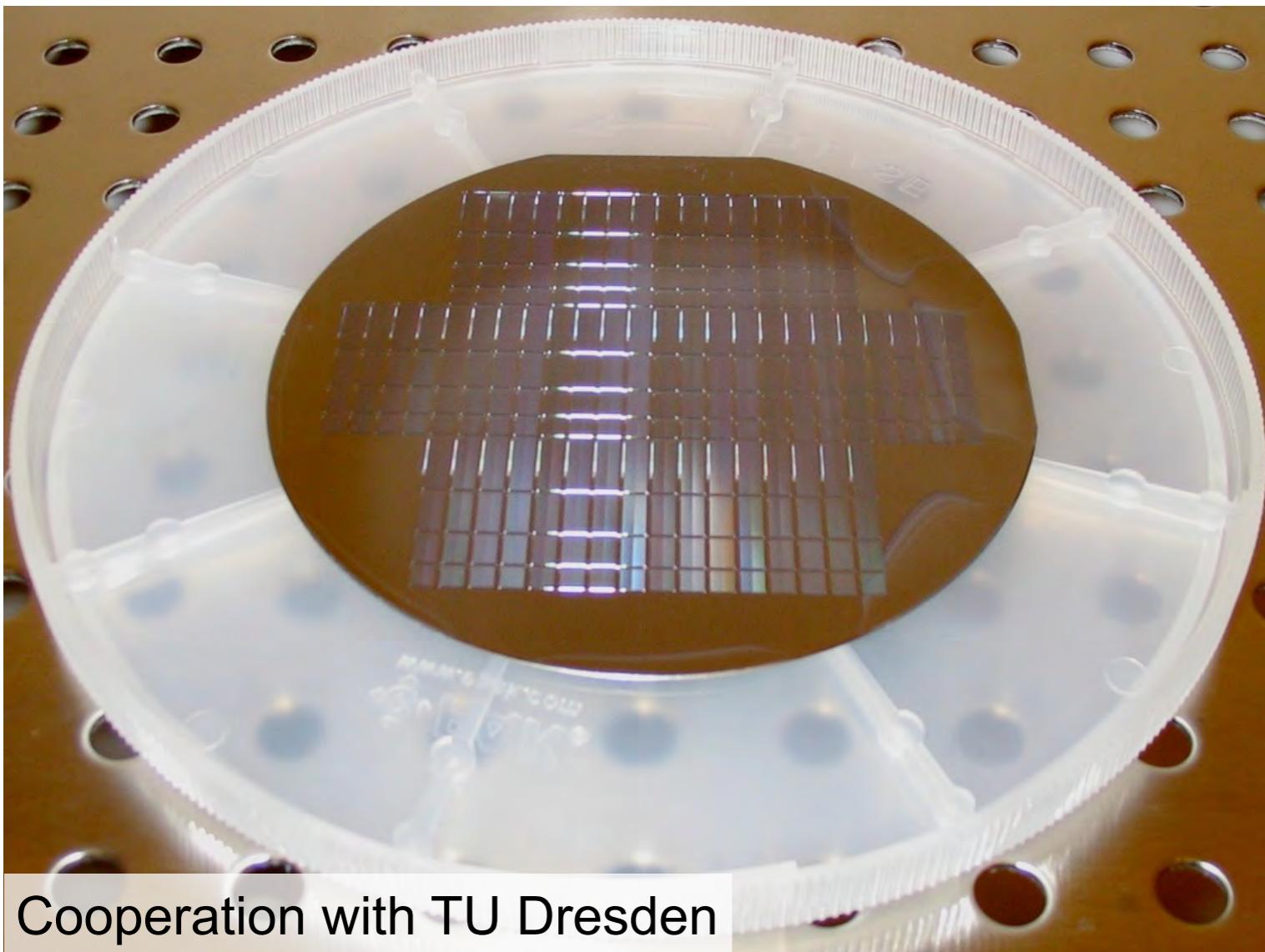
- minimize  $\mu/\delta$  ( $\Rightarrow$  small atomic number  $Z$ )
- $NA = \frac{D_{\text{eff}}}{2f} \propto \frac{1}{\sqrt{f}}$  ( $\Rightarrow$  minimize focal length  $f$ )



transition to  
nanofocusing  
lenses (NFLs)

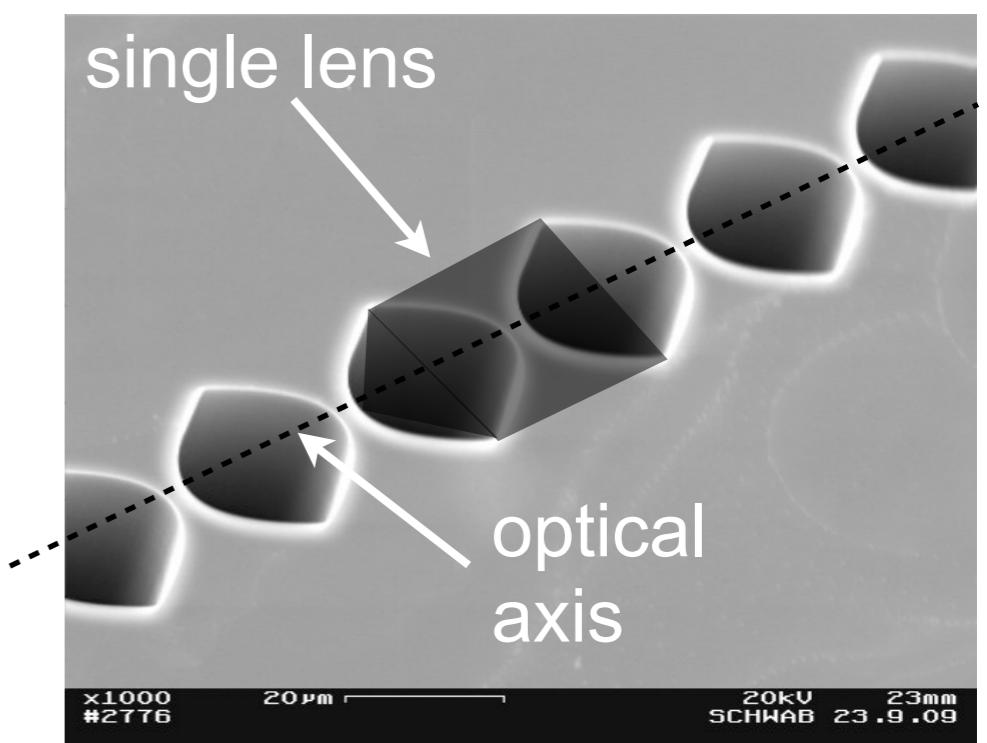
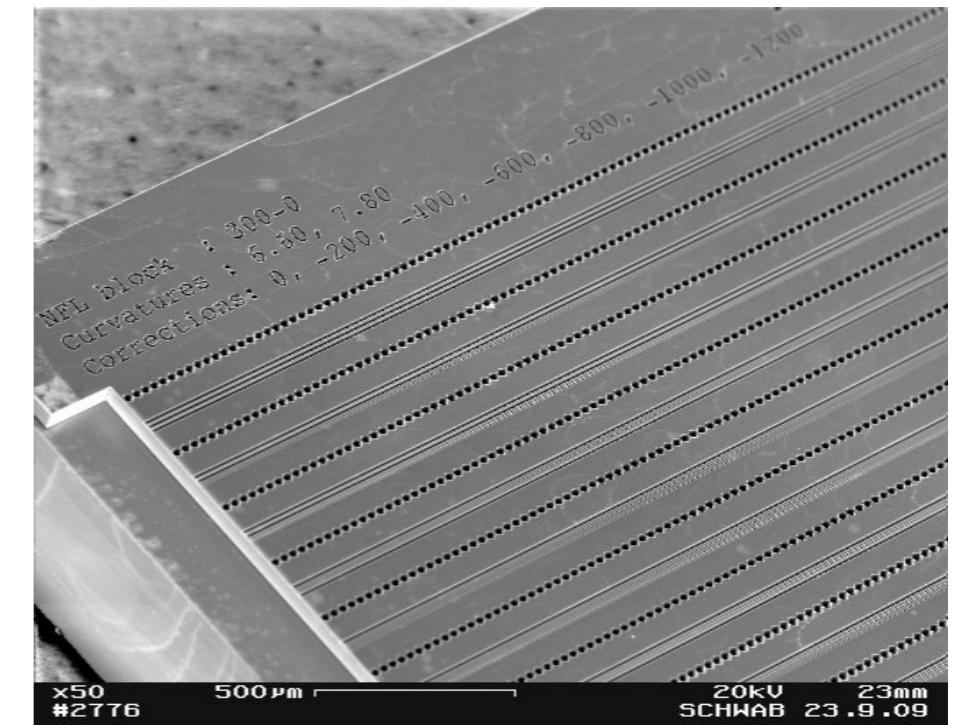


# Nanofocusing Lenses (NFLs) Made of Silicon



3136 NFLs on wafer!  
about 600000 single lenses!

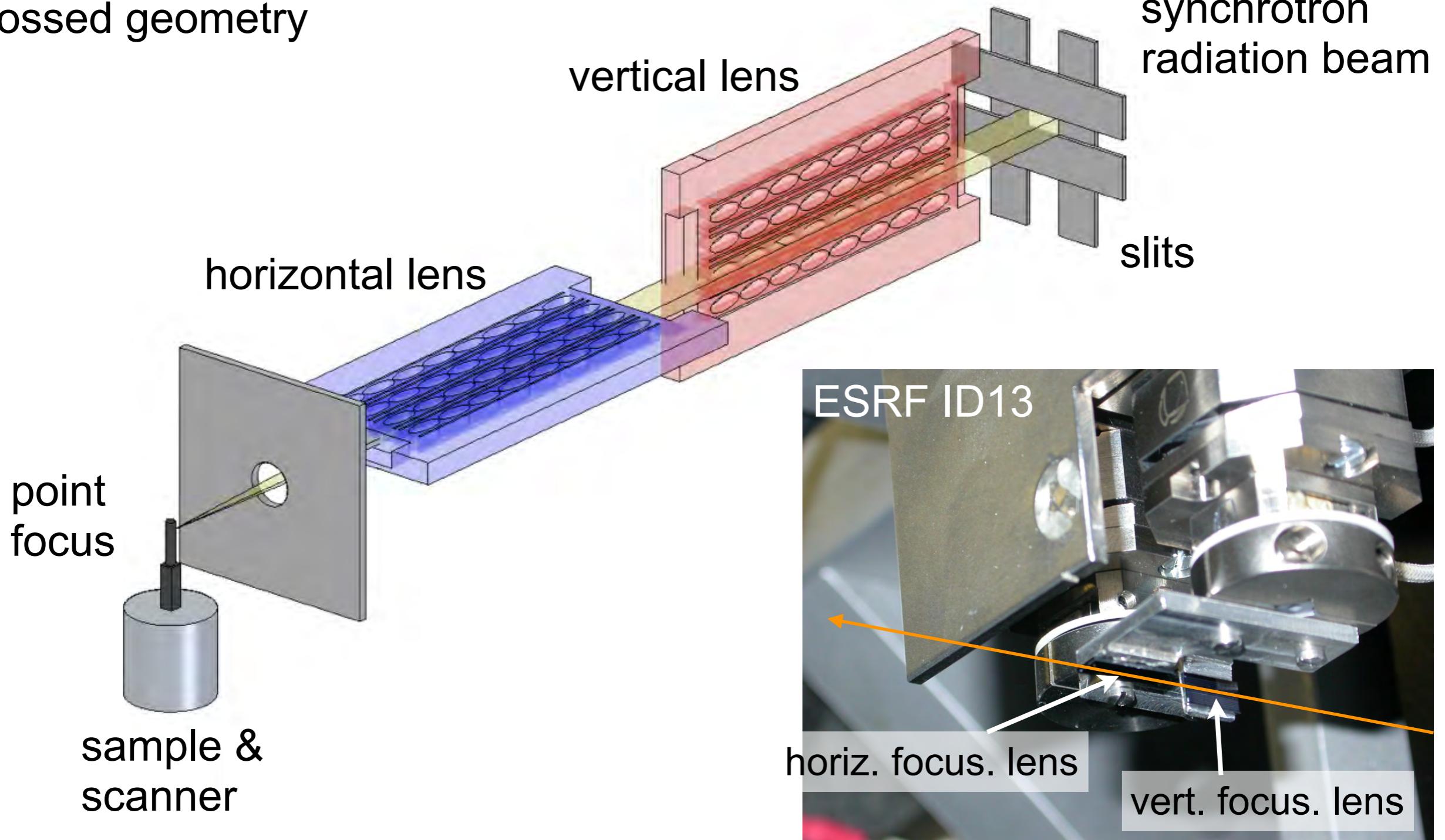
→ high accuracy, reproducibility



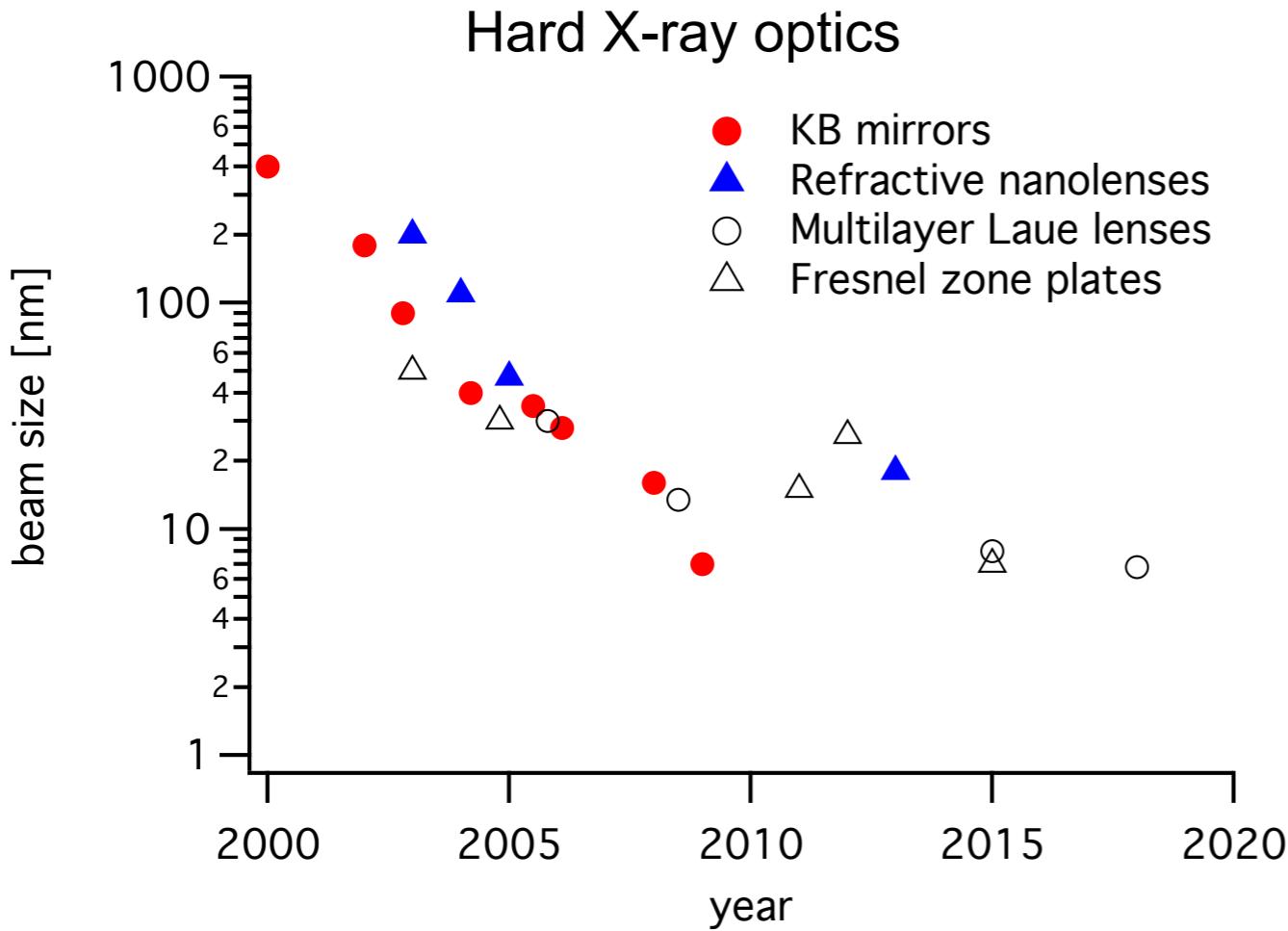
APL 82, 1485 (2003).

# Nanofocusing Lenses (NFLs)

Point focus requires two lenses in crossed geometry

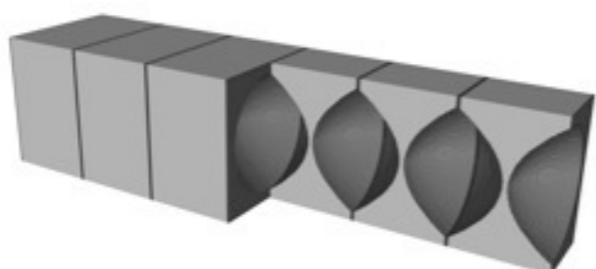


# X-Ray Optics: Towards 1 nm Focusing



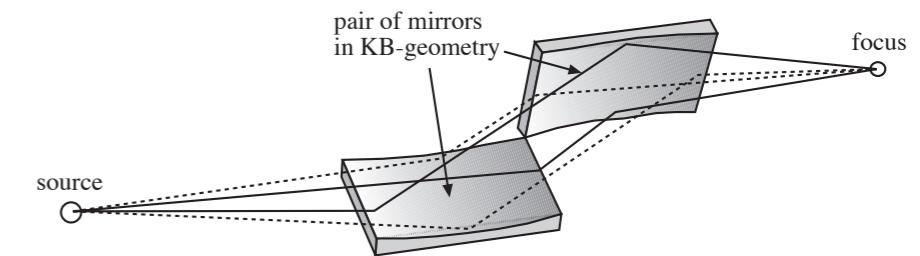
refraction:

- > refractive lenses (43 nm)
- > adiabatically focusing lenses (18 nm)



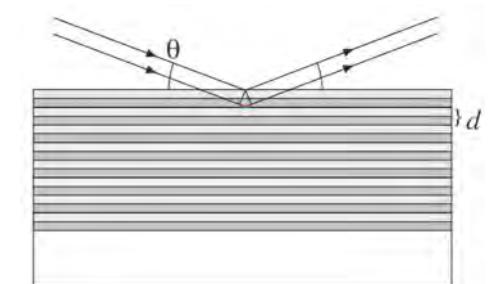
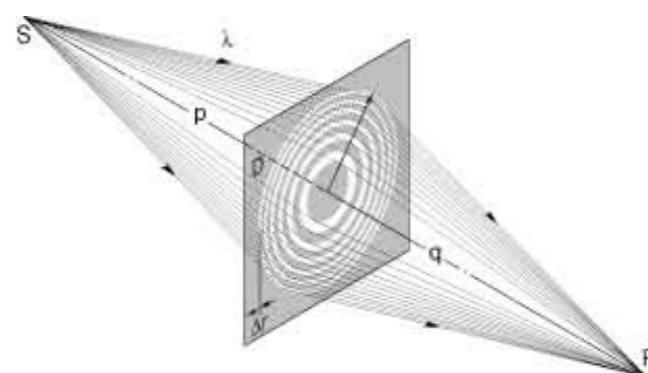
external total reflection

- > mirrors (25 nm)
- > capillaries
- > waveguides (~10 nm)



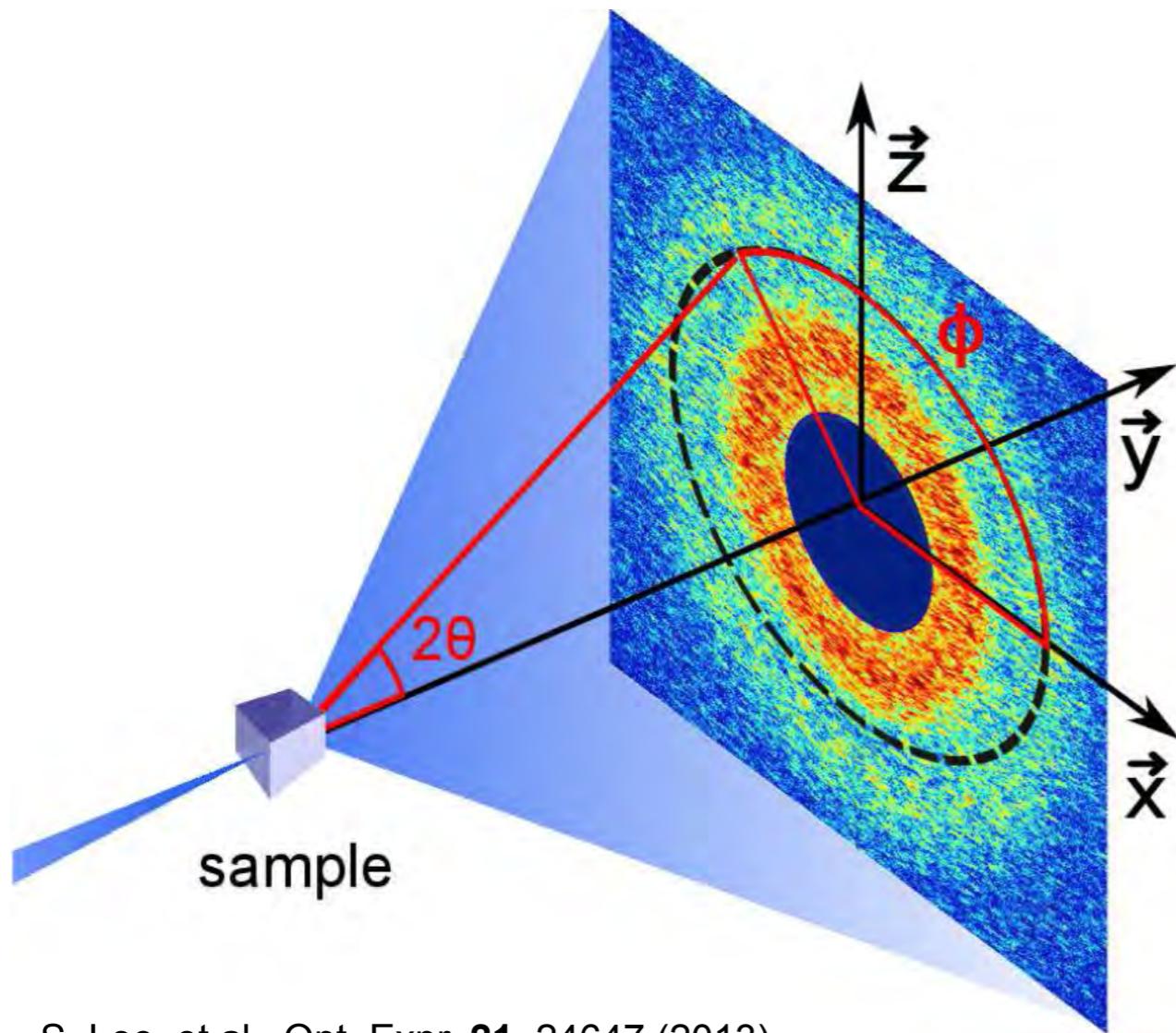
diffraction:

- > Fresnel zone plate (~20 nm)
- > multilayer mirror (7 nm)
- > multilayer Laue lenses (8 nm)
- > bent crystals



# Workaround: Coherent X-Ray Diffraction Imaging

Sample illuminated by coherent X-rays:



S. Lee, et al., Opt. Expr. **21**, 24647 (2013).

Speckle pattern encodes information about the sample

No optics:

> No limitation of numerical aperture

$$NA = \sin 2\theta$$

→ limited by intensity in diffraction pattern

> But no direct image of sample

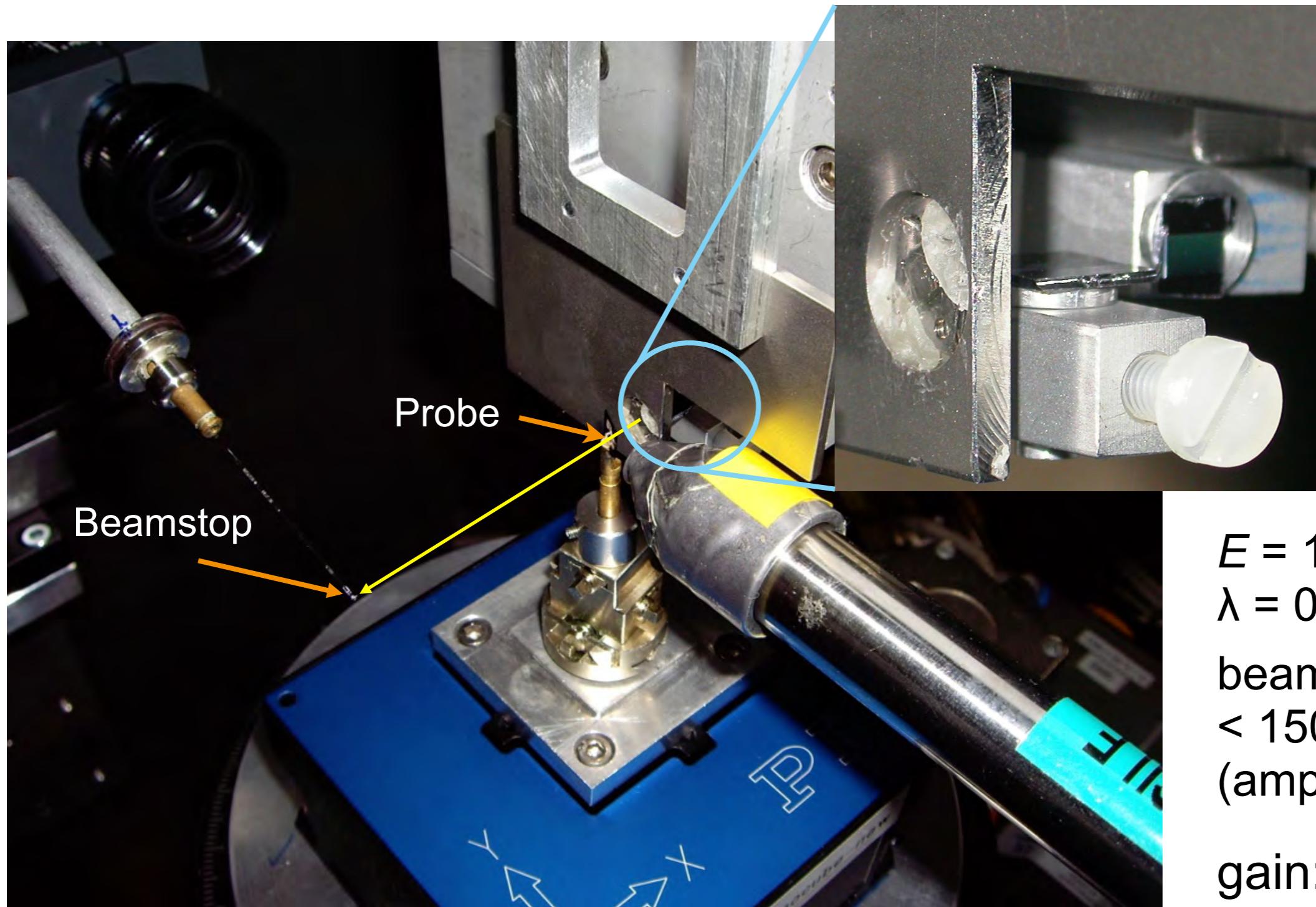
→ Far-field diffraction pattern

→ Absolute square of Fourier amplitudes

Important ingredient:

Coherent light

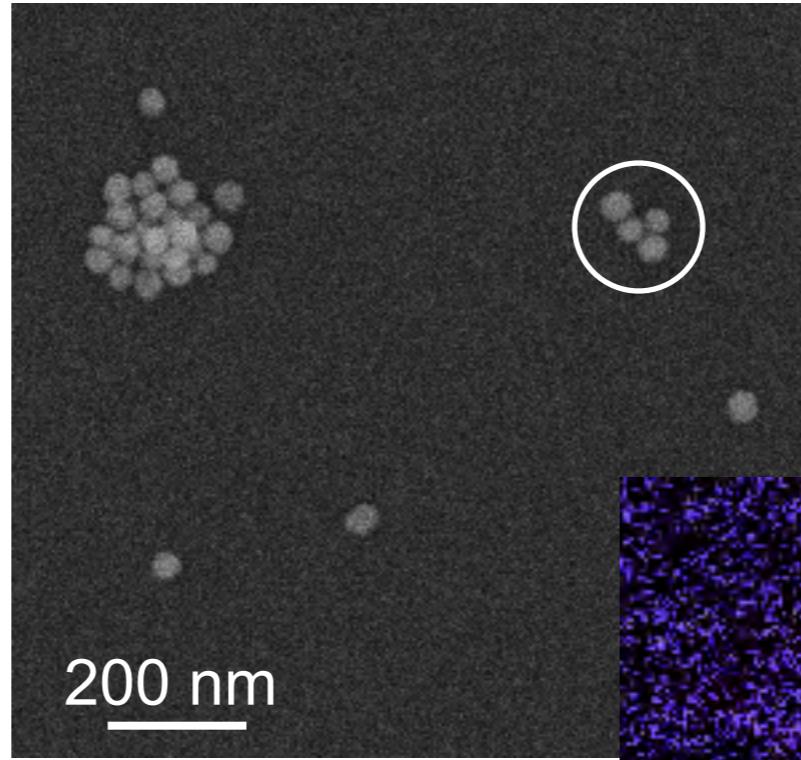
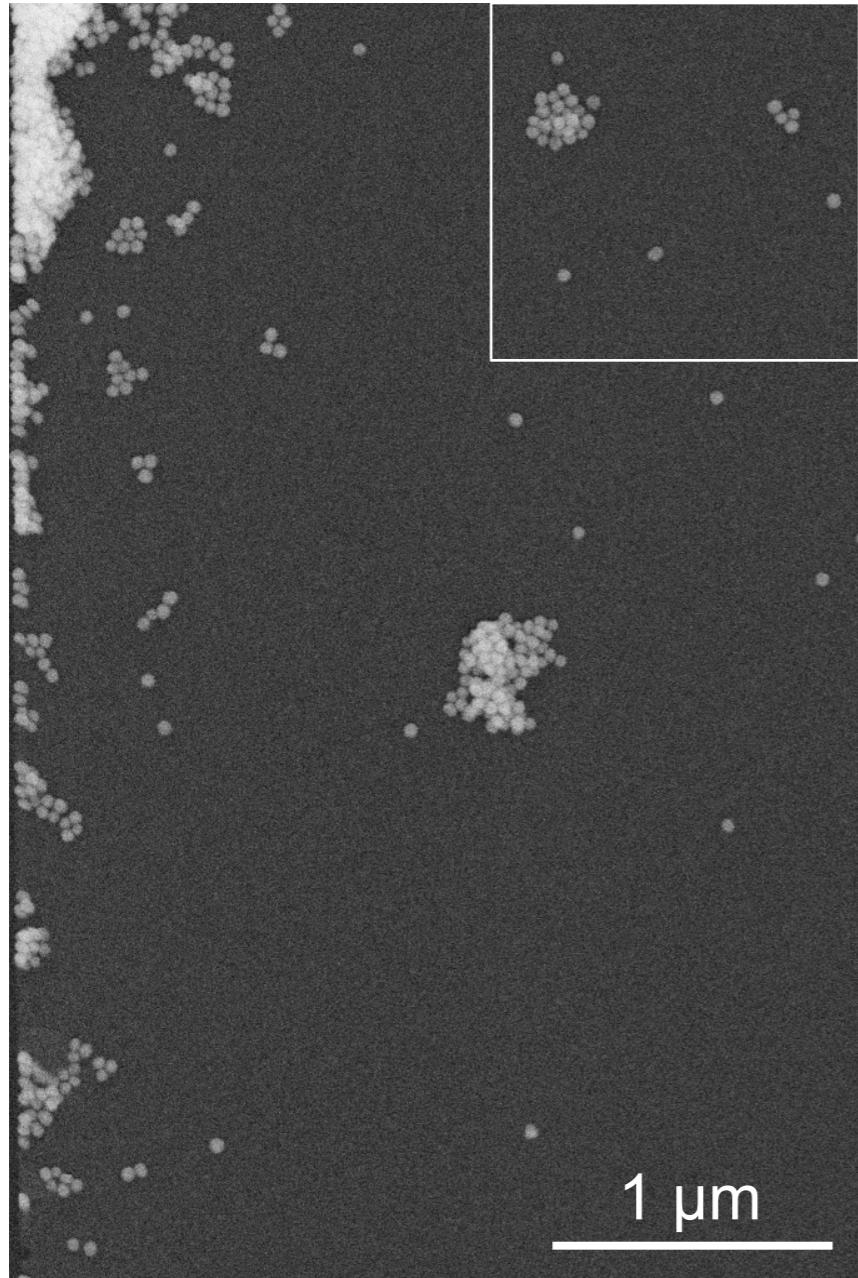
# Example: Coherent X-Ray Diffraction Imaging



$E = 15.25 \text{ keV}$   
 $\lambda = 0.813 \text{ \AA}$   
beam size:  
 $< 150 \times 150 \text{ nm}^2$   
(amplitude)  
gain:  $10^4$

C. Schroer, et al., Phys. Rev. Lett. 101, 090801 (2008).

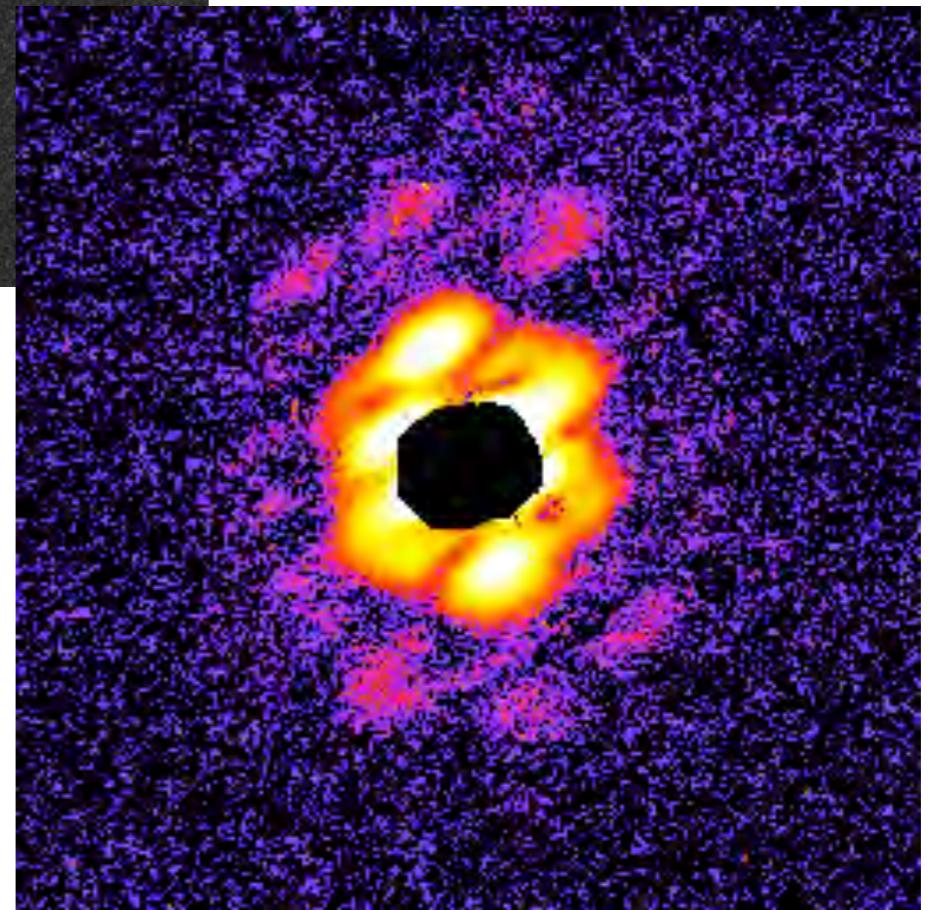
# Imaging of a Small Object



fluence:  
 $1 \cdot 10^5 \text{ ph/nm}^2$

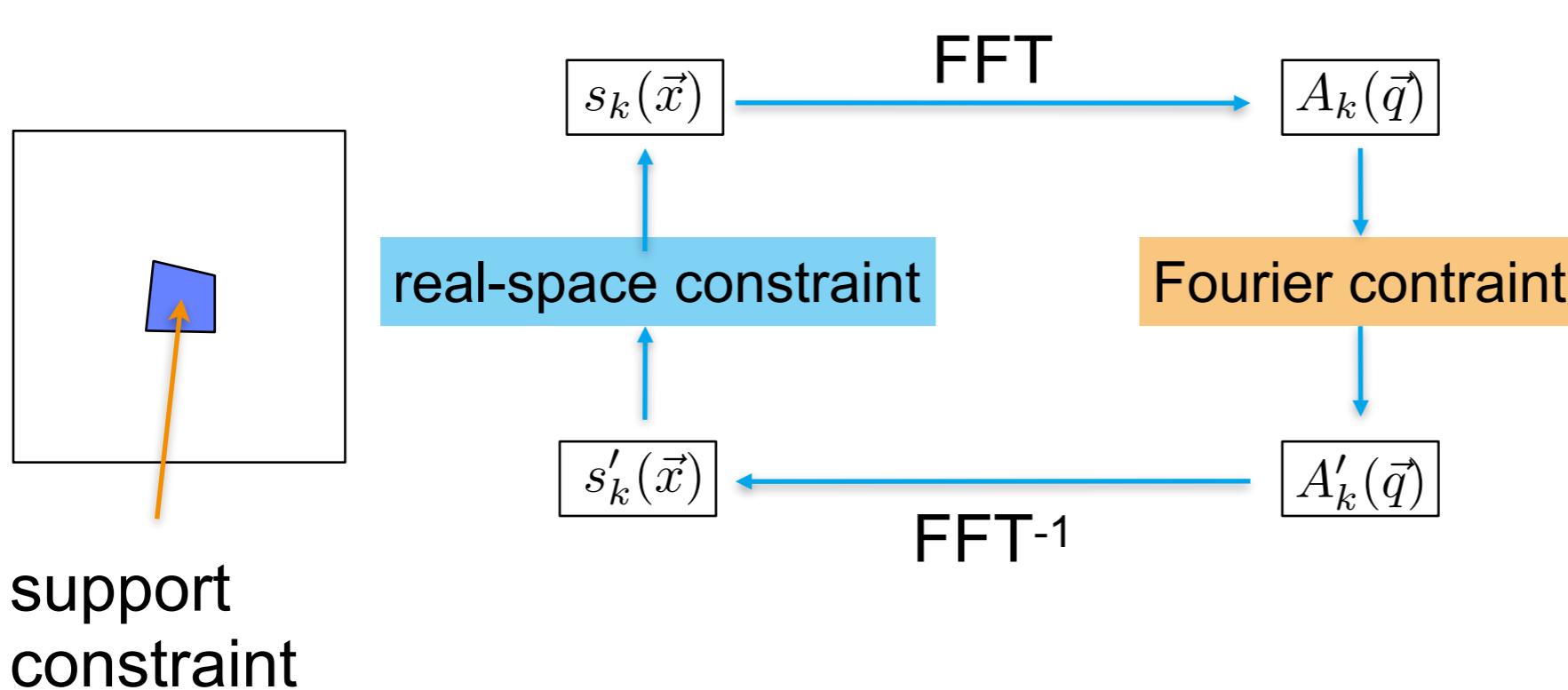
dose:  
 $1 \cdot 10^{10} \text{ ph}$

4 gold particles:  
diameter  $\sim 40 \text{ nm}$   
 $\rightarrow 7.5 \cdot 10^6 \text{ atoms}$

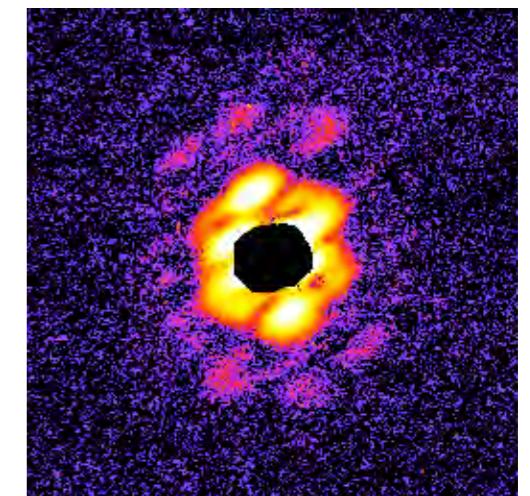


# Coherent X-ray Diffraction Imaging

Iterative phase reconstruction:



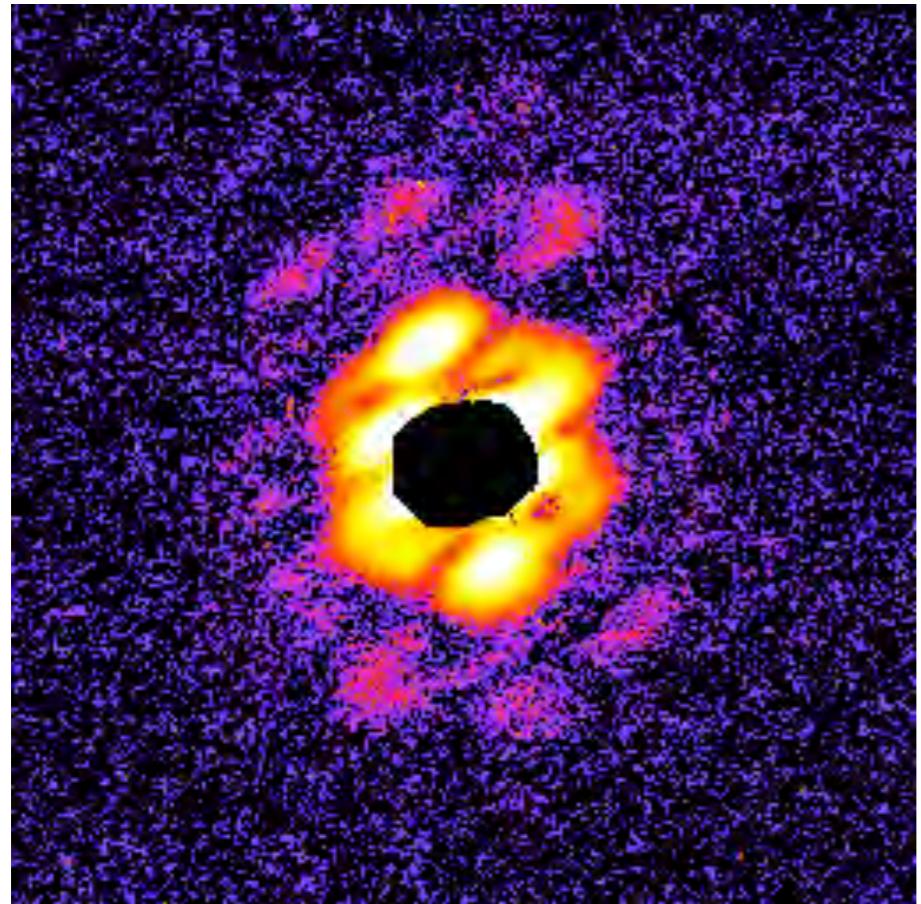
$$|A'_k(\vec{q})| \stackrel{!}{=} \sqrt{I_{\text{exp}}(\vec{q})}$$



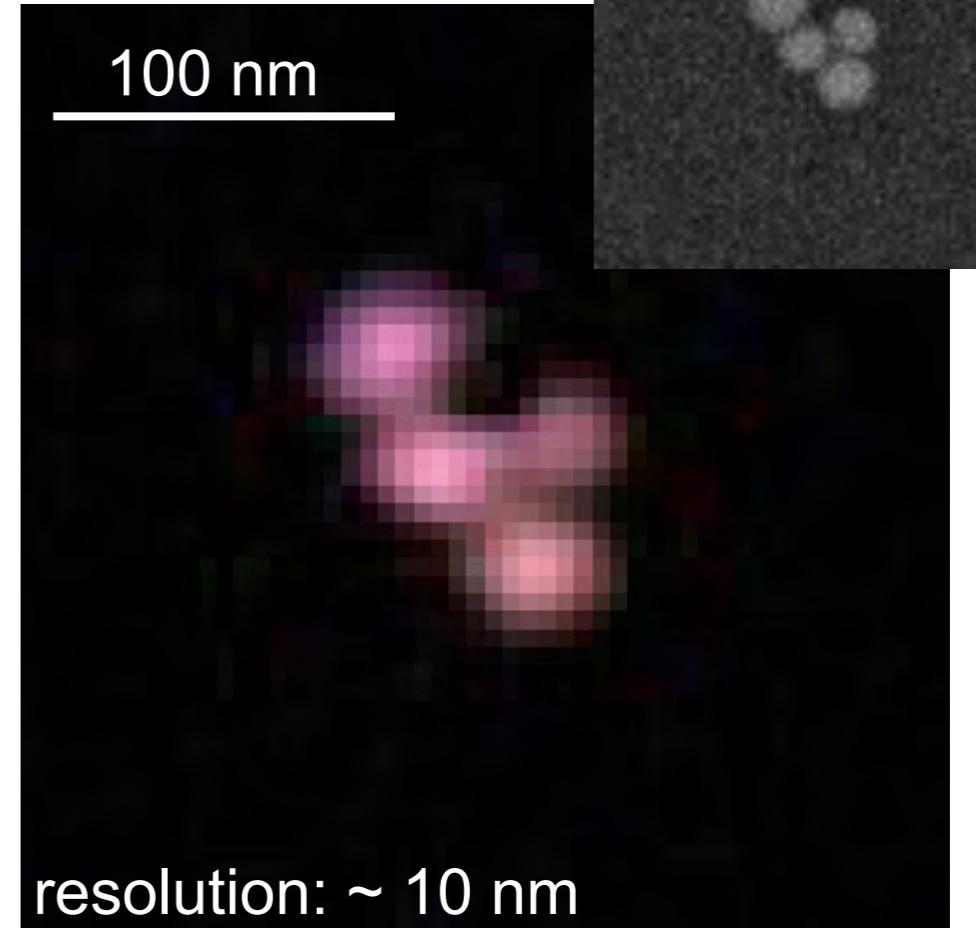
- R. W. Gerchberg & W. O. Saxton, *Optic* (1972) **35**, 237  
J. R. Fienup, *Appl Opt.* (1982). **21**, 2758  
R. P. Millane & W.J. Stroud, *J. Opt. Soc. Am.* (1997) **A14**, 568

# Coherent X-ray Diffraction Imaging

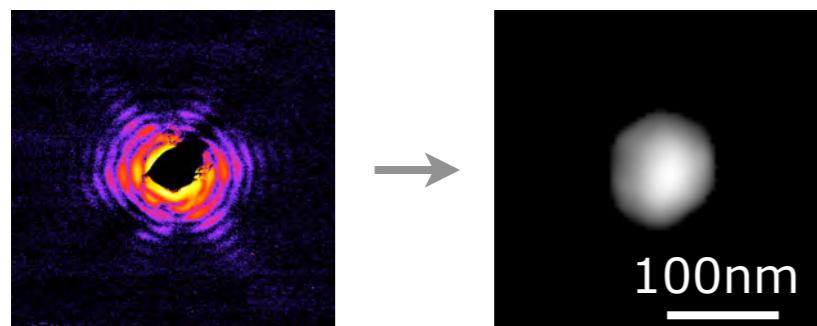
Iterative phase reconstruction:



HIO  
→  
shrink-wrap



record resolution: 5 nm



CXDI at an individual gold particle  
PRL 101, 090801 (2008)

Difficulty:

- > half of the information is missing
- > additional knowledge needed (e. g., support constraint)

# Hard X-ray Scanning Microscopy at PETRA III



Microscope:

~98 m from source

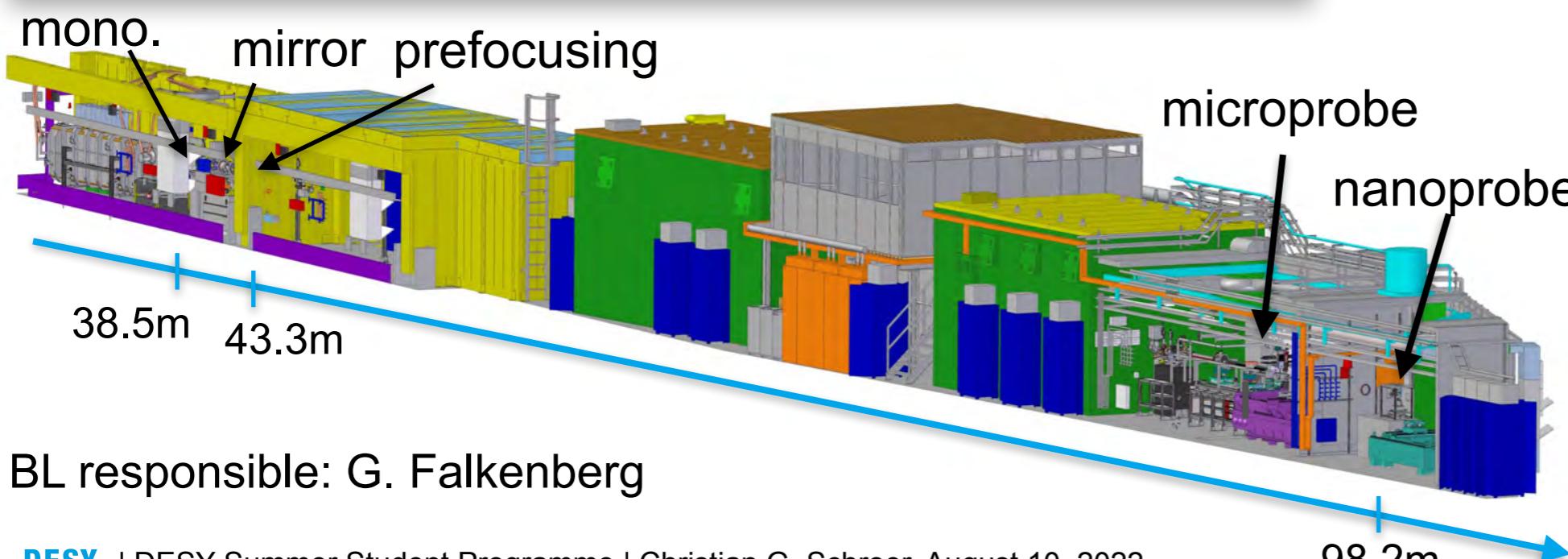
different contrasts:

- > fluorescence
- > diffraction (SAXS, WAXS)
- > absorption (XAS)
- > XBIC/XBIV
- > ptychography & CXDI

spatial resolution:

down to < 50 nm

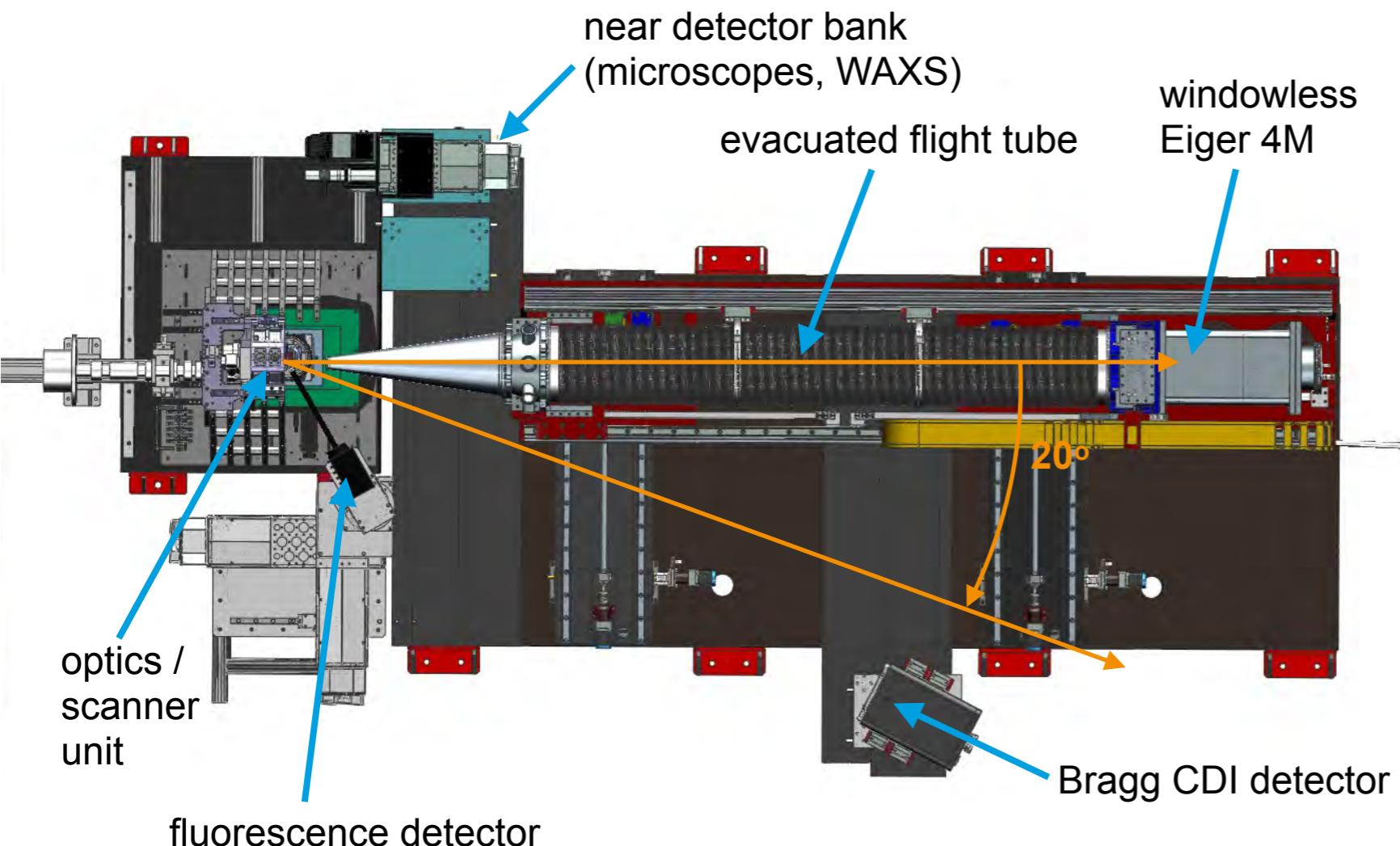
down to < 5 nm (CXDI)



BL responsible: G. Falkenberg

# PtyNAMi: Ptychographic Nano-Analytical Microscope

## Ongoing Upgrade Project



### Goals:

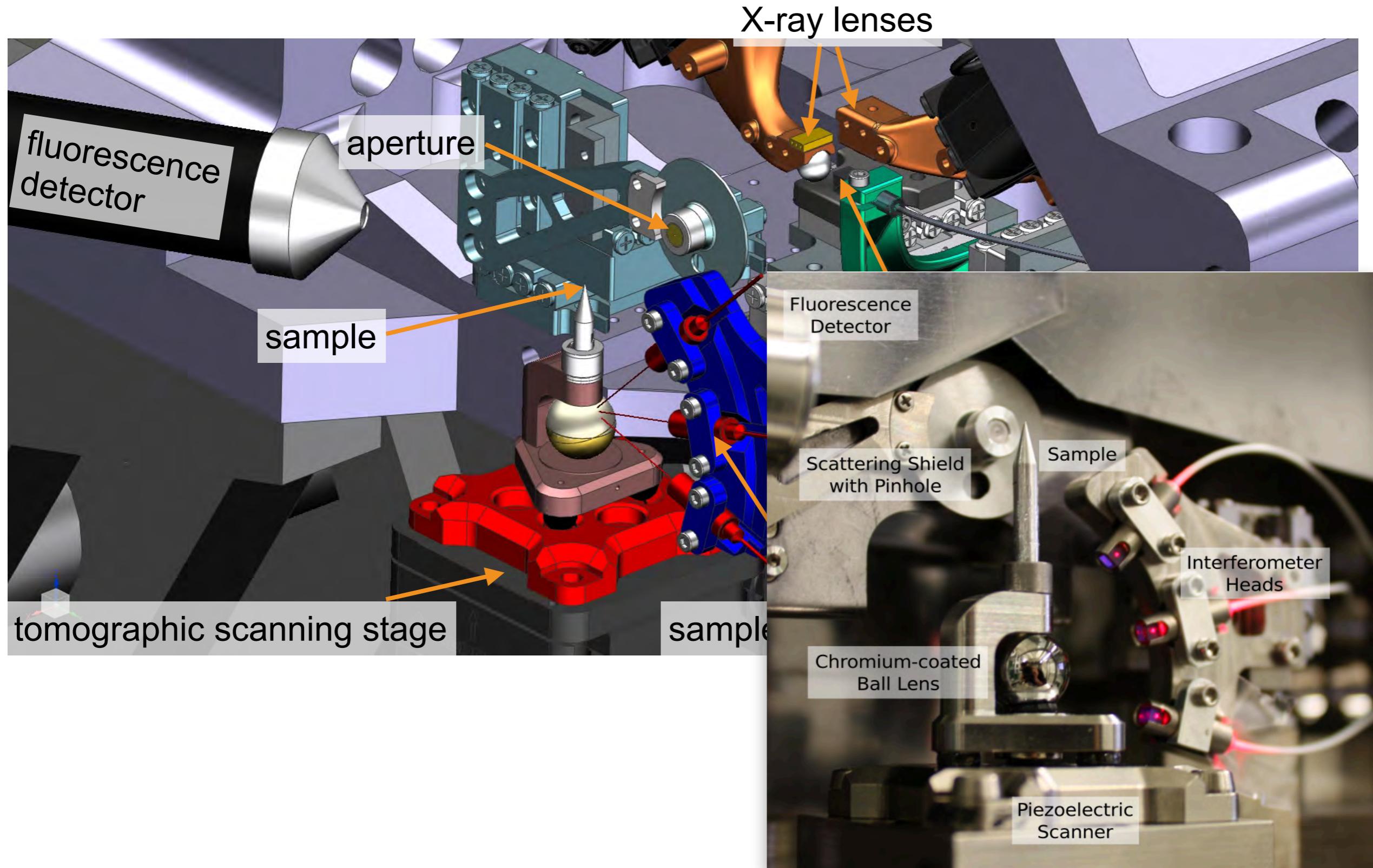
- > multimodal: ptychography, XRF, SAXS, WAXS, XAS
- > high spatial resolution
- > high sensitivity
- > 2D and 3D imaging
- > *in situ* & *operando*

### Experimental requirements:

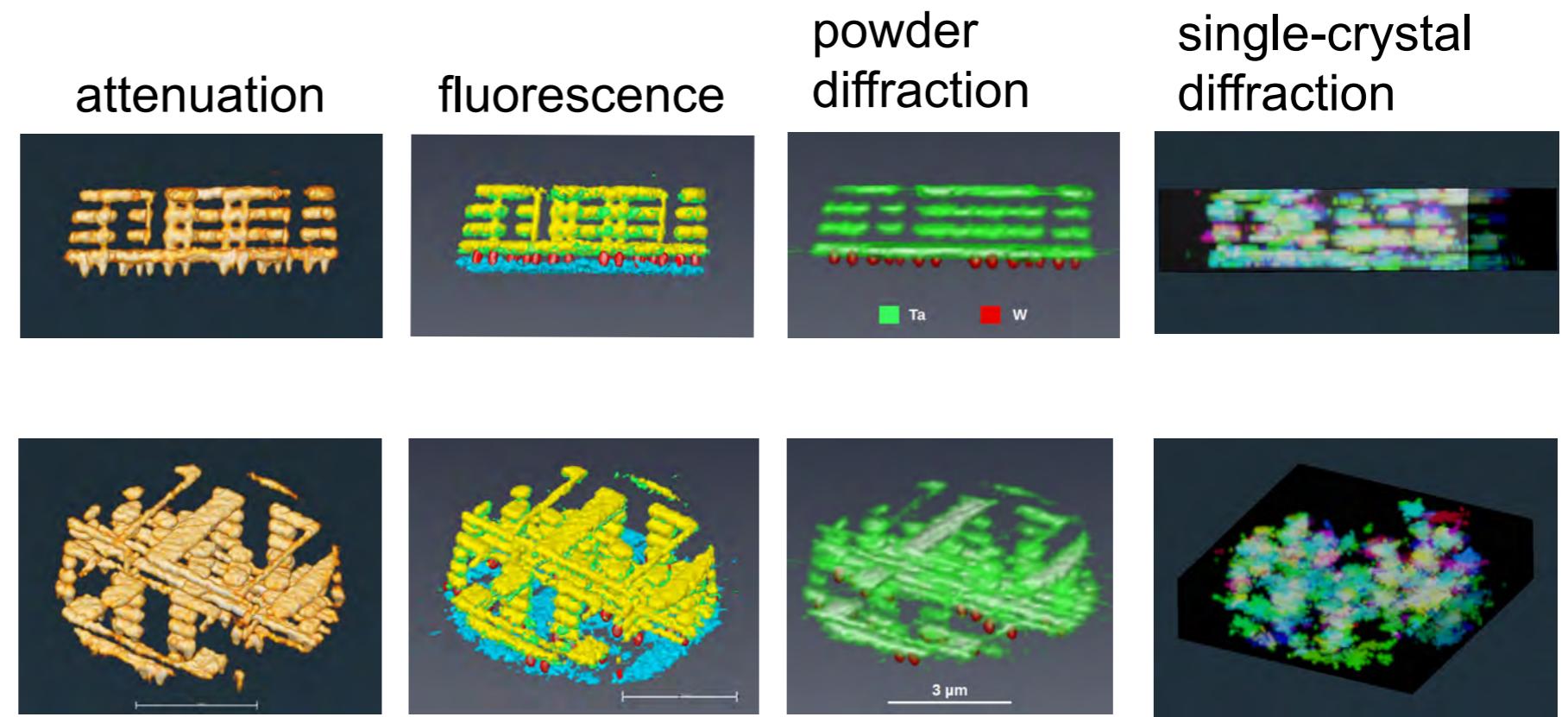
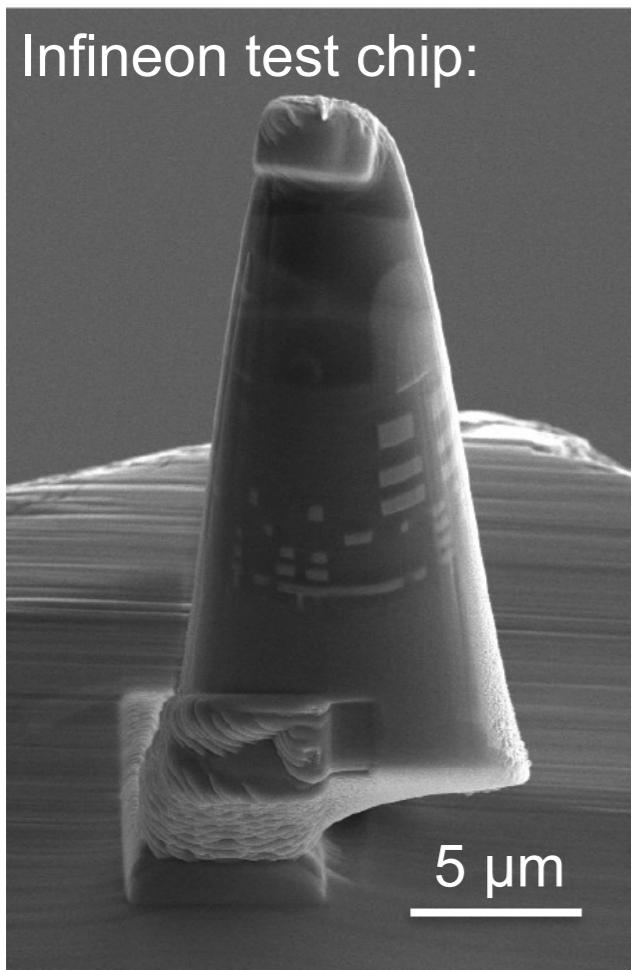
- > optimised coherent flux with pre-focusing
- > high-performance optics
- > high mechanical stability and control
- > low background

A. Schropp, et al., *PtyNAMi: Ptychographic Nano-Analytical Microscope*, J. Appl. Crystallogr. **53**, 957 (2020).

# PtyNAMi: Optics and Scanner Unit



# Example: Micro-Electronic Devices



$E = 18 \text{ keV}$

beam size:  $61 \times 80 \text{ nm}^2$

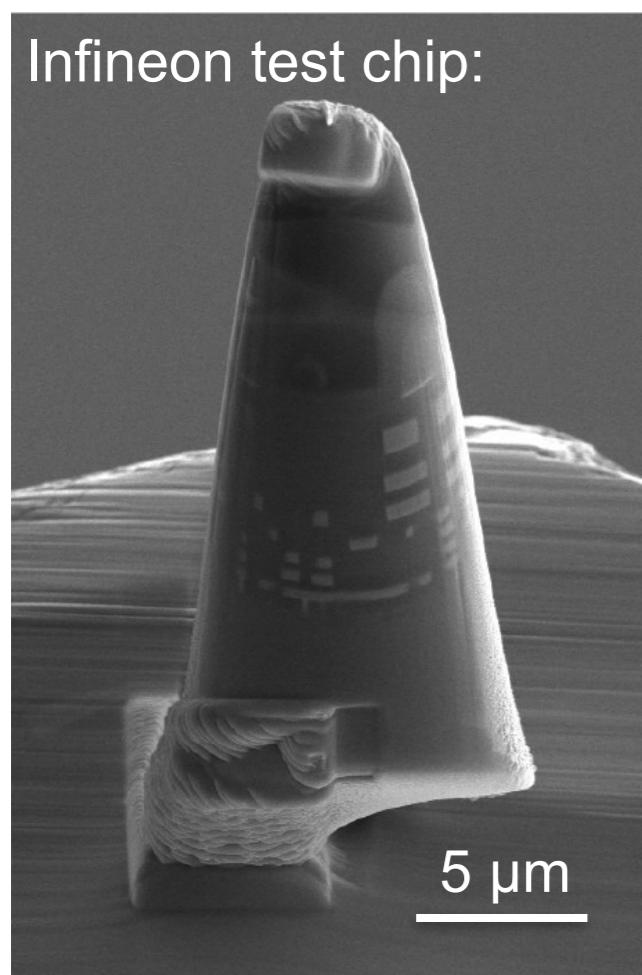
tomographic scan:

- > fluorescence radiation
- > diffraction patterns

PhD work: Maria Scholz

# Example: Micro-Electronic Devices

Infineon test chip:



$E = 18 \text{ keV}$

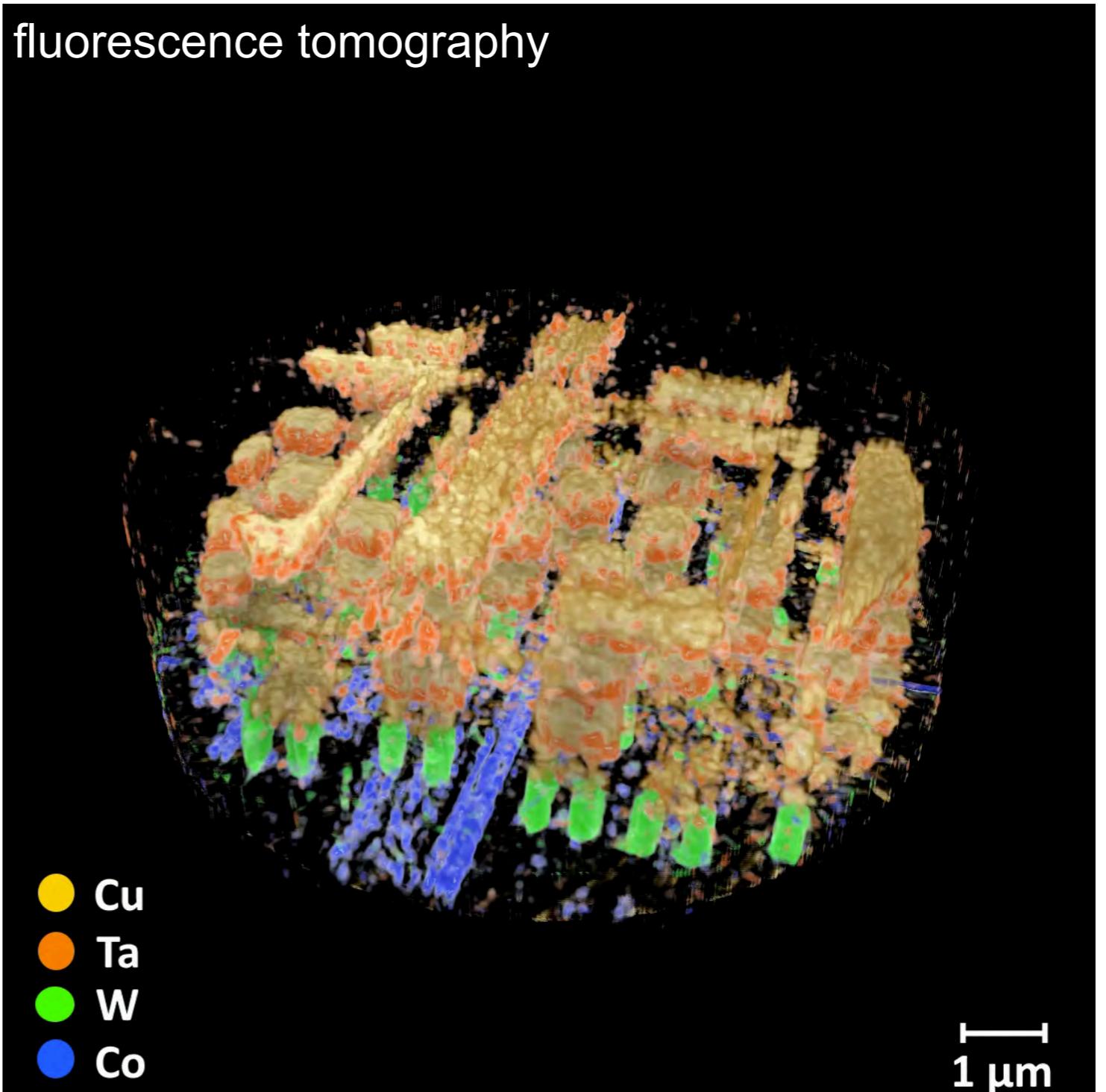
beam size:  $61 \times 80 \text{ nm}^2$

tomographic scan:

- > fluorescence radiation
- > diffraction patterns

PhD work: Maria Scholz

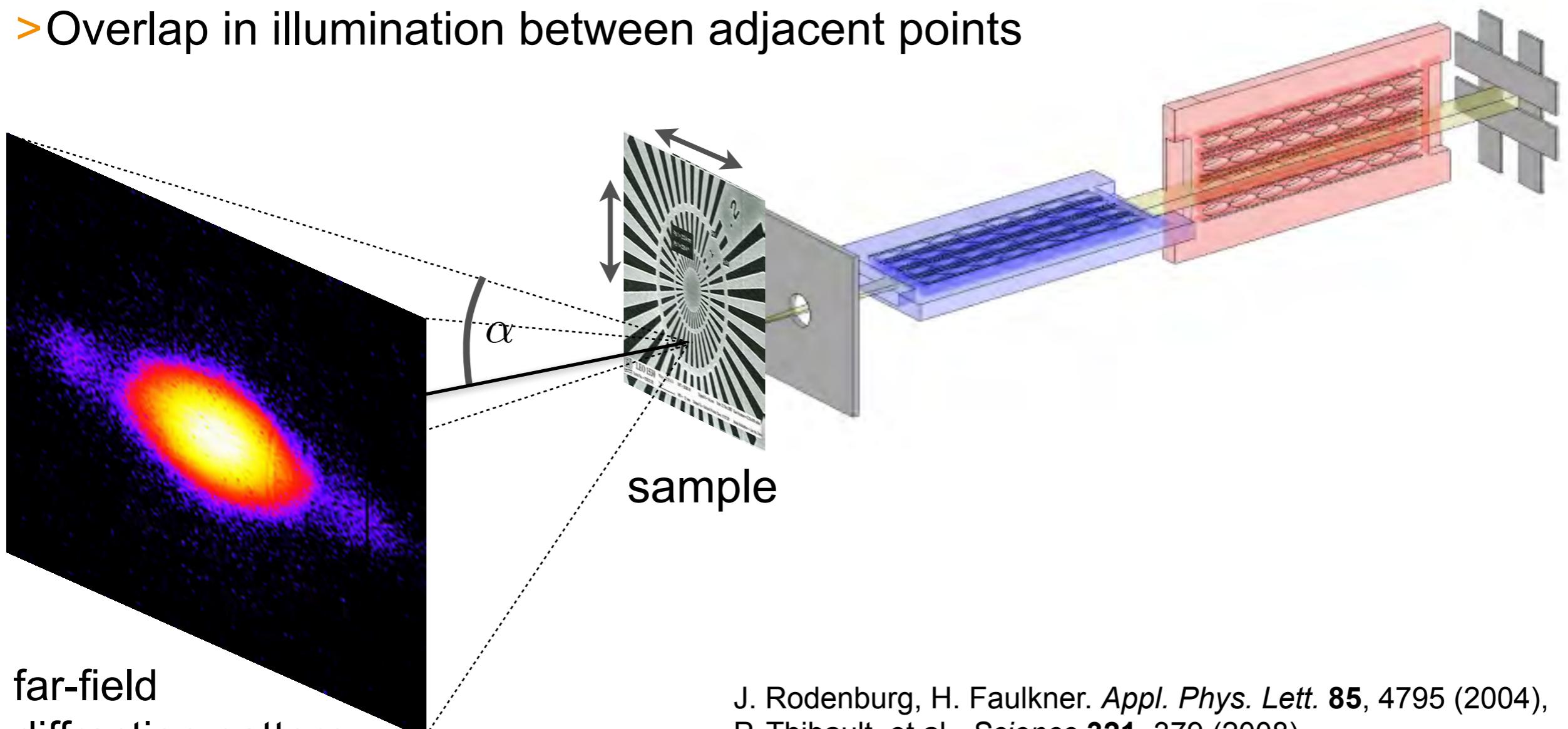
fluorescence tomography



Master thesis of Lukas Grote

# Scanning Coherent Diffraction Imaging: Ptychography

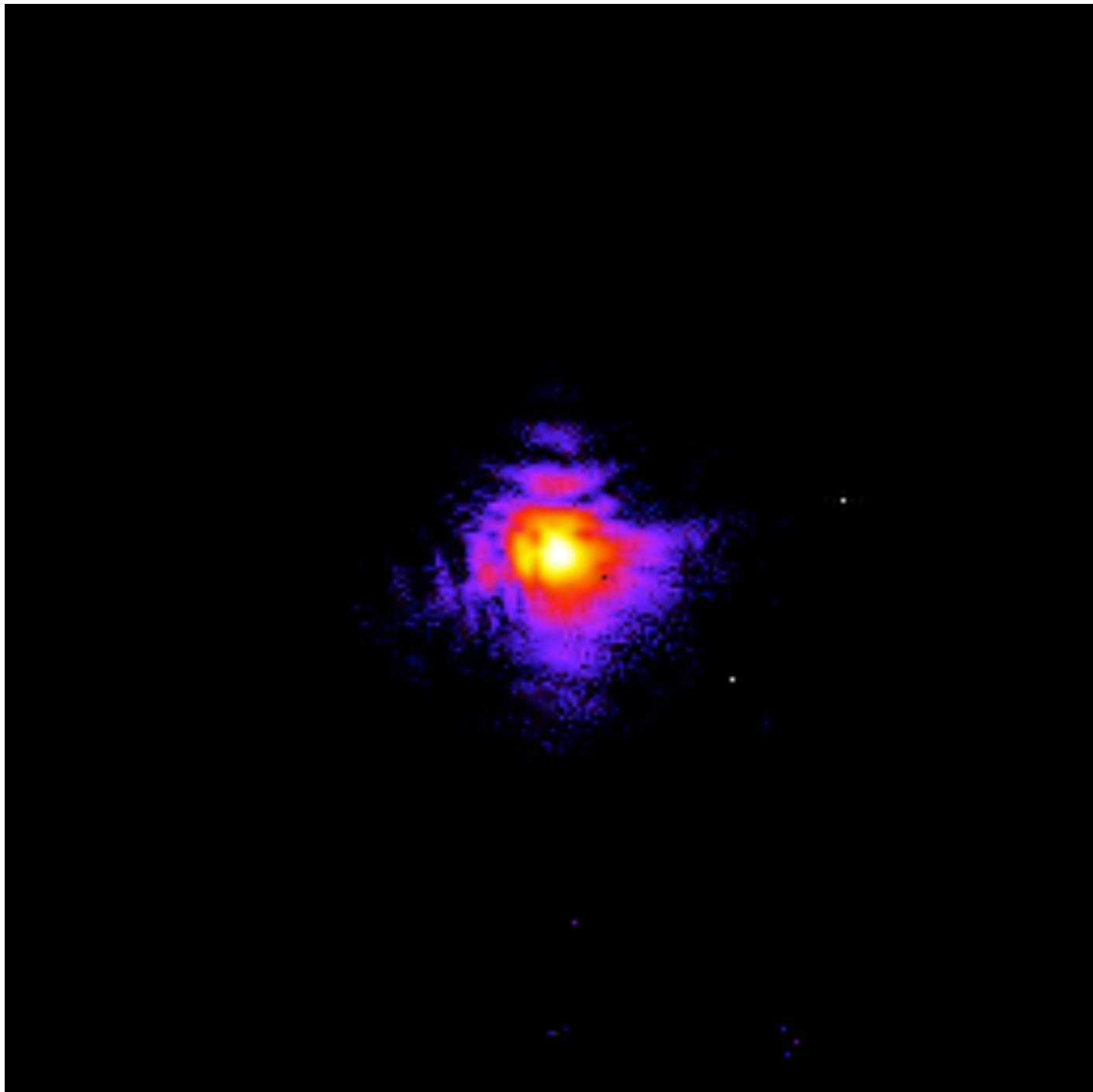
- > Sample is raster scanned through confined beam
- > At each position of scan: diffraction pattern is recorded
- > Overlap in illumination between adjacent points



far-field  
diffraction pattern

J. Rodenburg, H. Faulkner. *Appl. Phys. Lett.* **85**, 4795 (2004),  
P. Thibault, et al., *Science* **321**, 379 (2008),  
A. Schropp, et al., *Appl. Phys. Lett.* **96**, 091102 (2010),  
M. Dierolf, et al., *Nature* **467**, 436 (2010).

# Ptychography: Characterization of Nanobeam



A. Schropp, et al., Appl. Phys. Lett. **96**, 091102 (2010).  
C. G. Schroer, et al., Proc. SPIE **8848**, 884807 (2013).

Nanofocusing lenses at PETRA III

$E = 8 \text{ keV}$

detector:

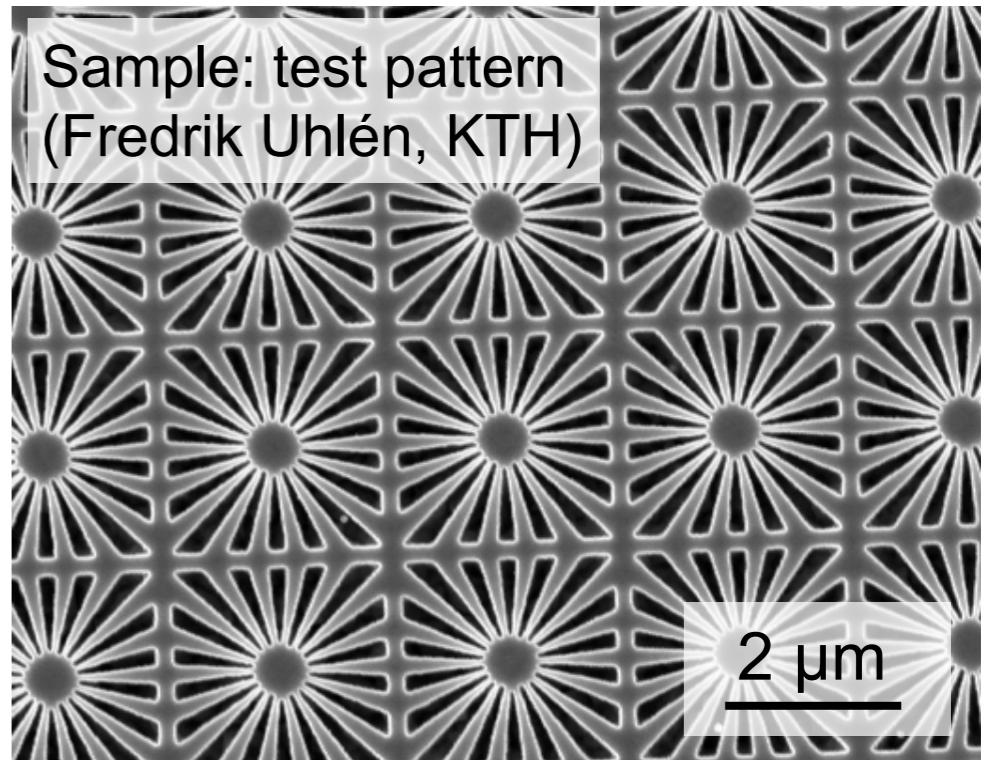
Pilatus 300k ( $172\mu\text{m}$  pixel size)

sample-detector distance:

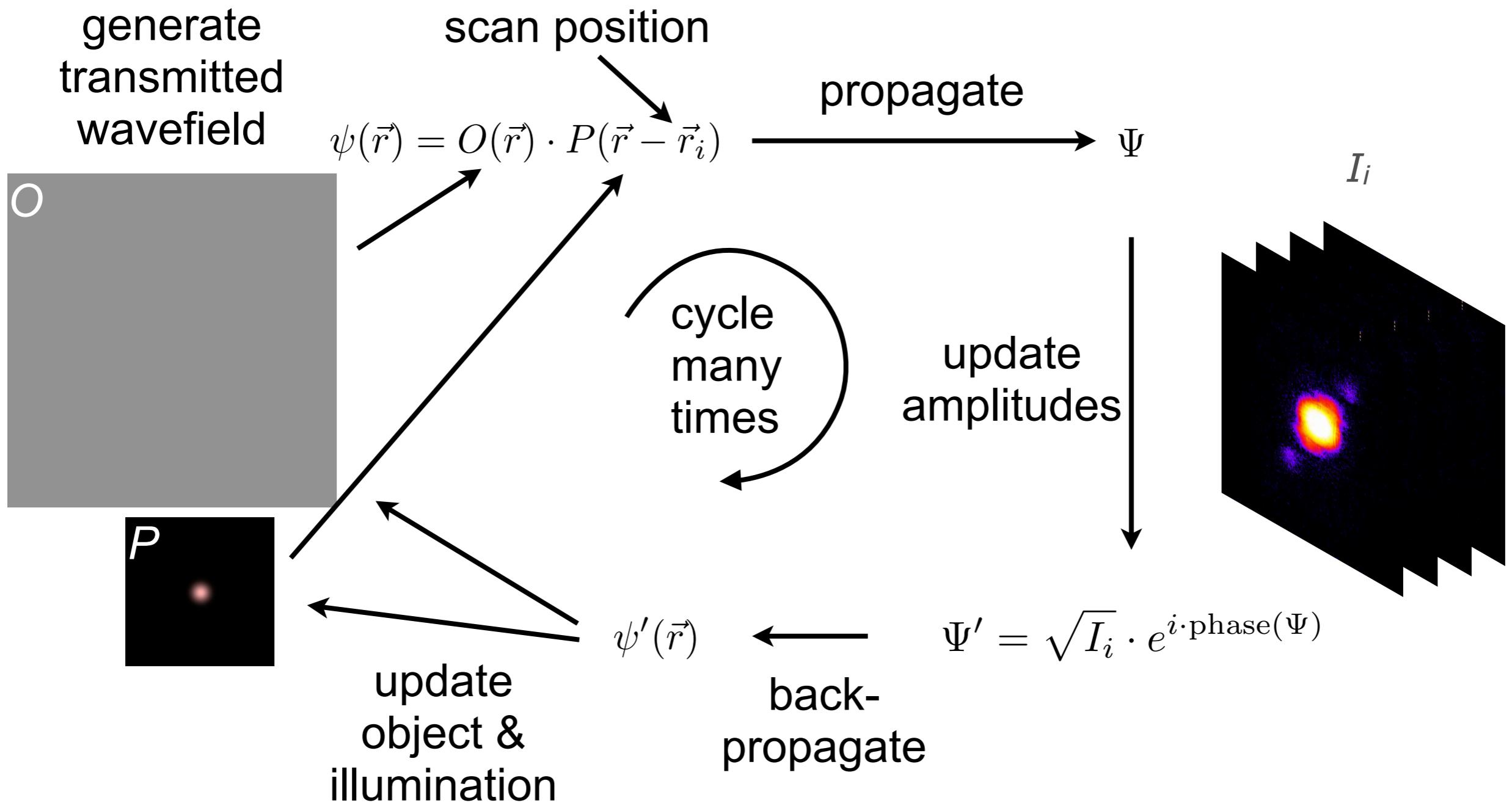
2080 mm

exposure time:

1.0 s per point

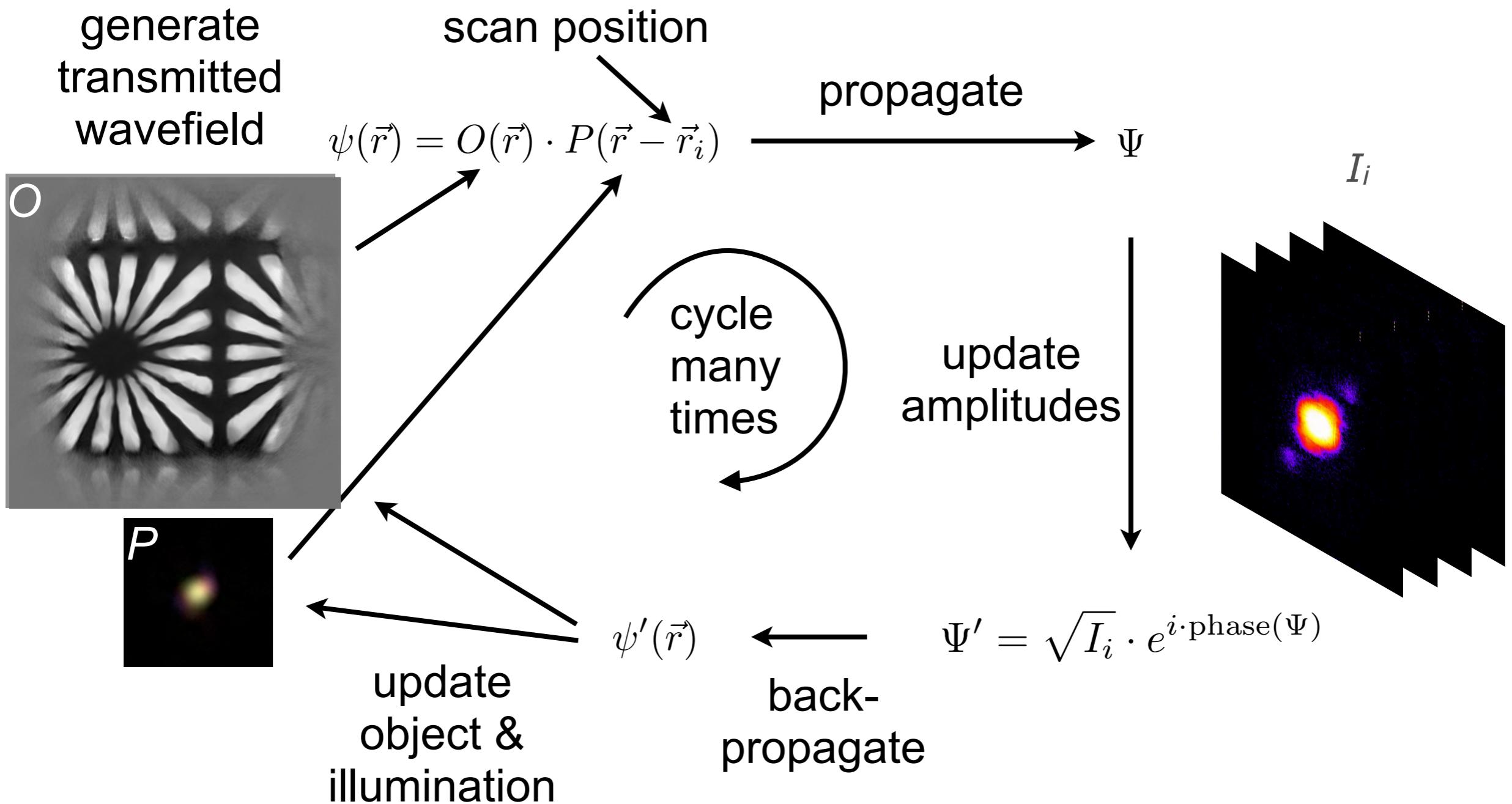


# Ptychography: Reconstruction



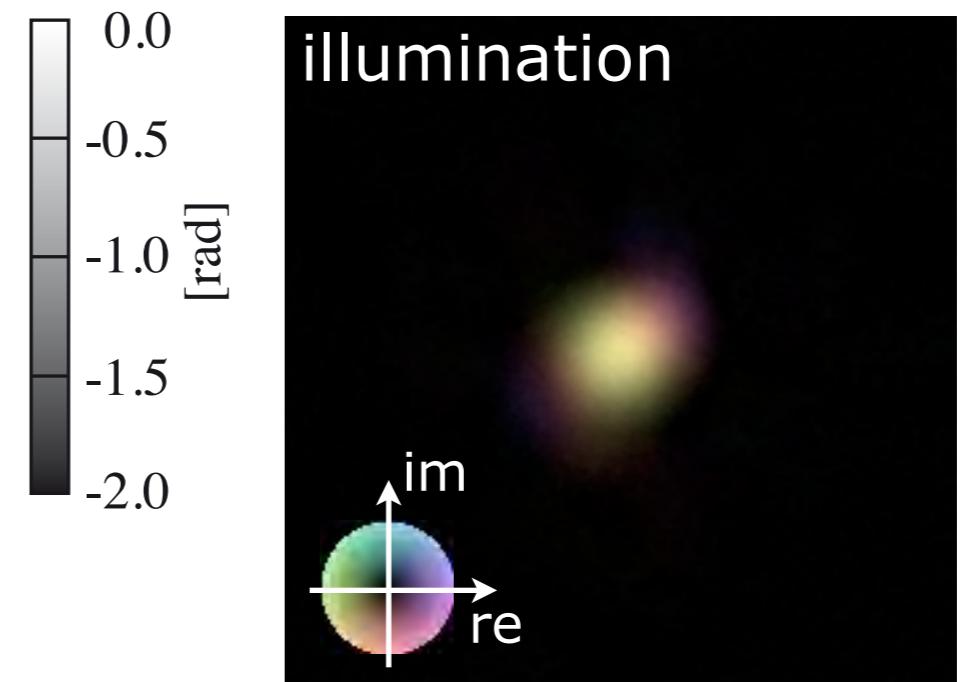
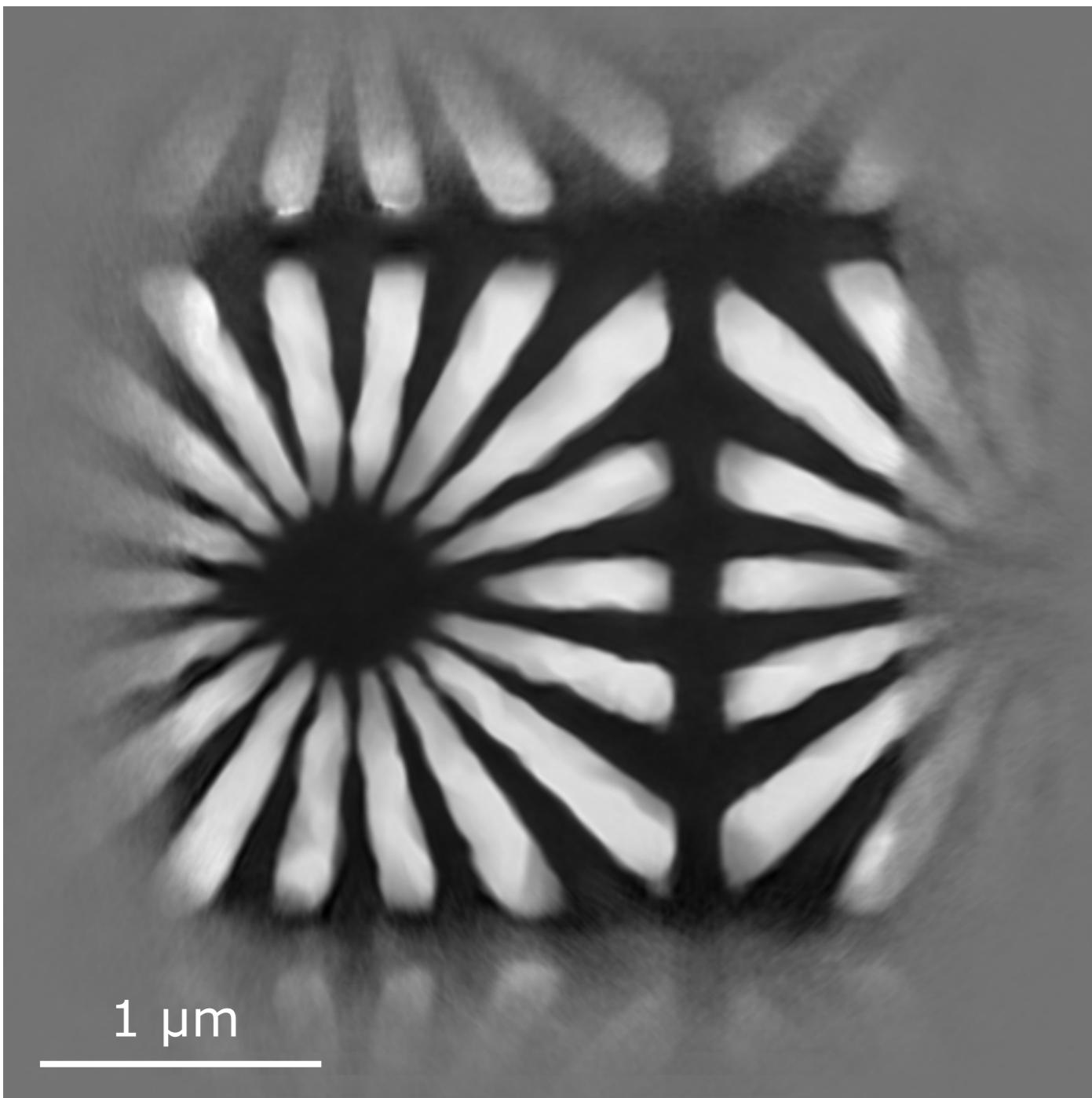
Maiden & Rodenburg, Ultramicroscopy **109**, 1256 (2009).

# Ptychography: Reconstruction



Maiden & Rodenburg, Ultramicroscopy **109**, 1256 (2009).

# Ptychography: Reconstruction of Sample and Probe

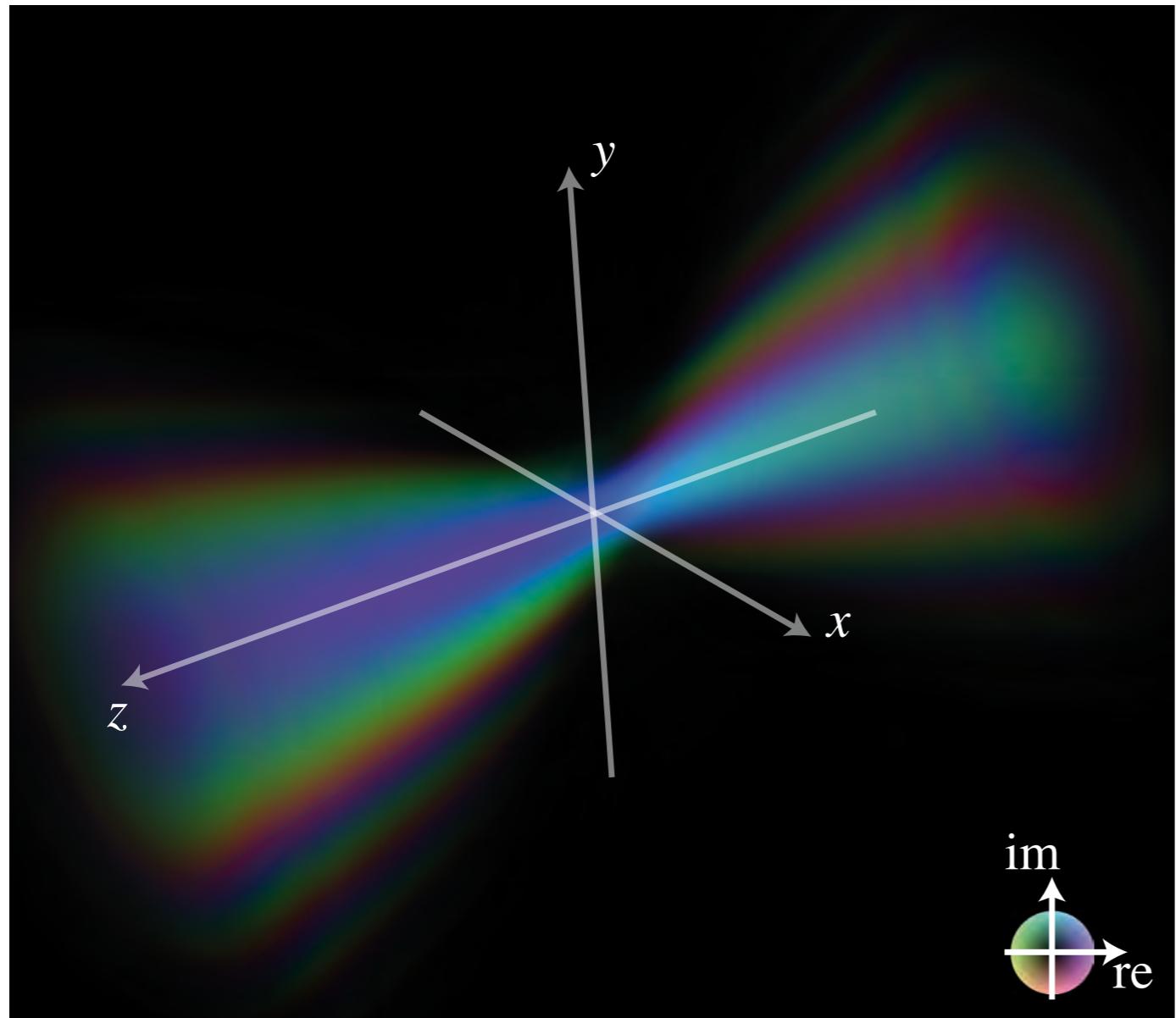


Full state (solution of Helmholtz equation)

$E = 8.0 \text{ keV}$   
 $25 \times 25 \text{ steps of } 80 \times 80 \text{ nm}^2$   
 $2 \times 2 \mu\text{m}^2 \text{ FOV}$   
exposure: 1.0 s per point  
detected fluence: 120 ph/nm<sup>2</sup>

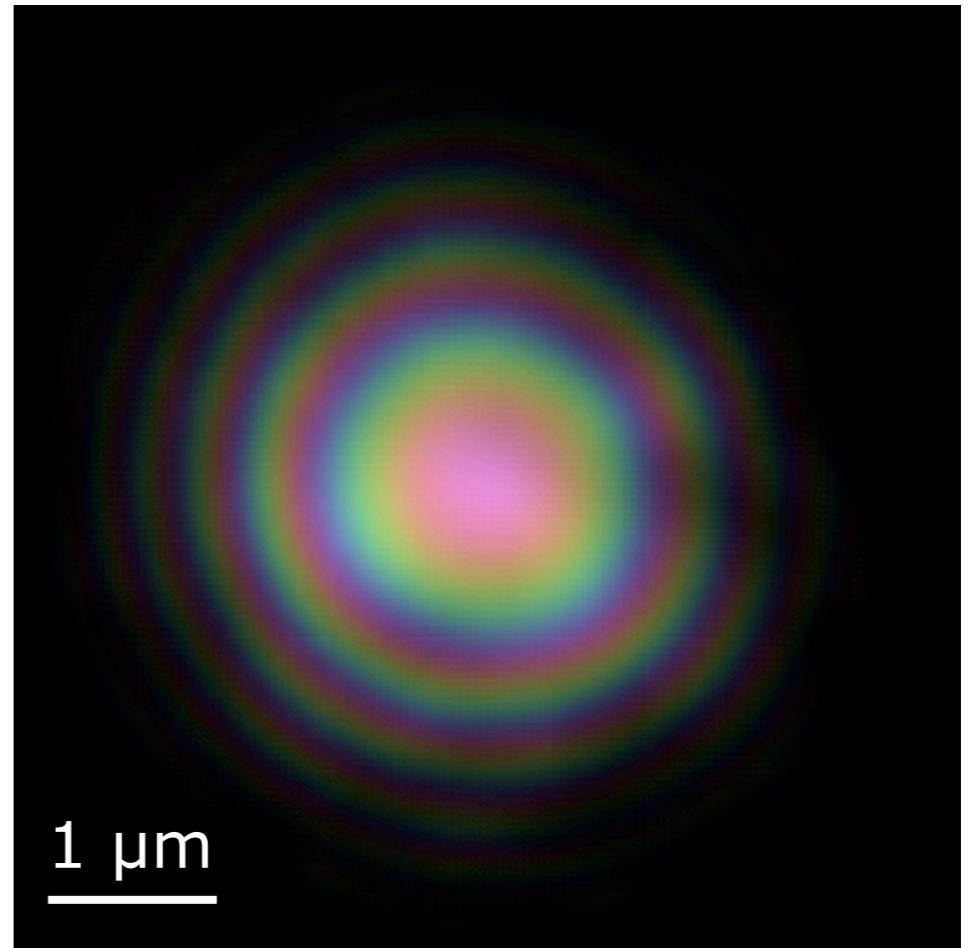
A. Schropp, et al., Appl. Phys. Lett. **96**, 091102 (2010).  
C. G. Schroer, et al., Proc. SPIE **8848**, 884807 (2013).

# Reconstructed Wave Field

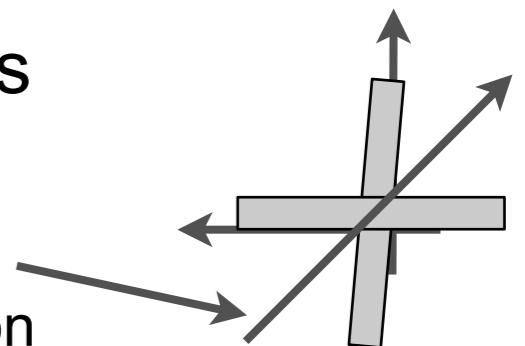


Caustic: -4 mm to 4 mm

A. Schropp, et al., Appl. Phys. Lett. **96**, 091102 (2010).  
C. G. Schroer, et al., Proc. SPIE **8848**, 884807 (2013).

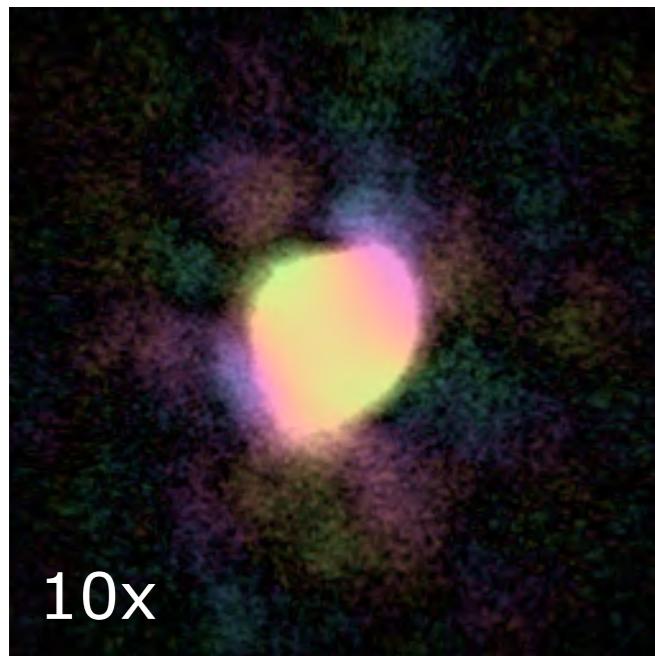
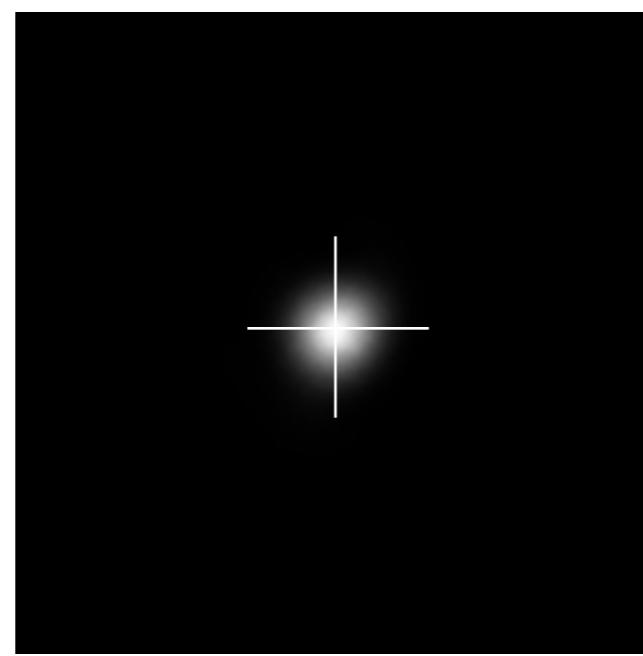
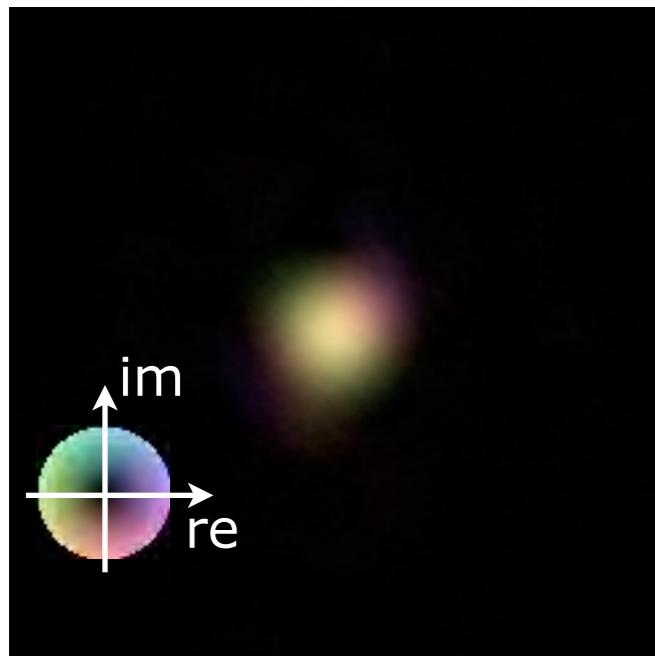


Slight astigmatism:  
improper lens  
alignment:  
more strongly  
focusing direction

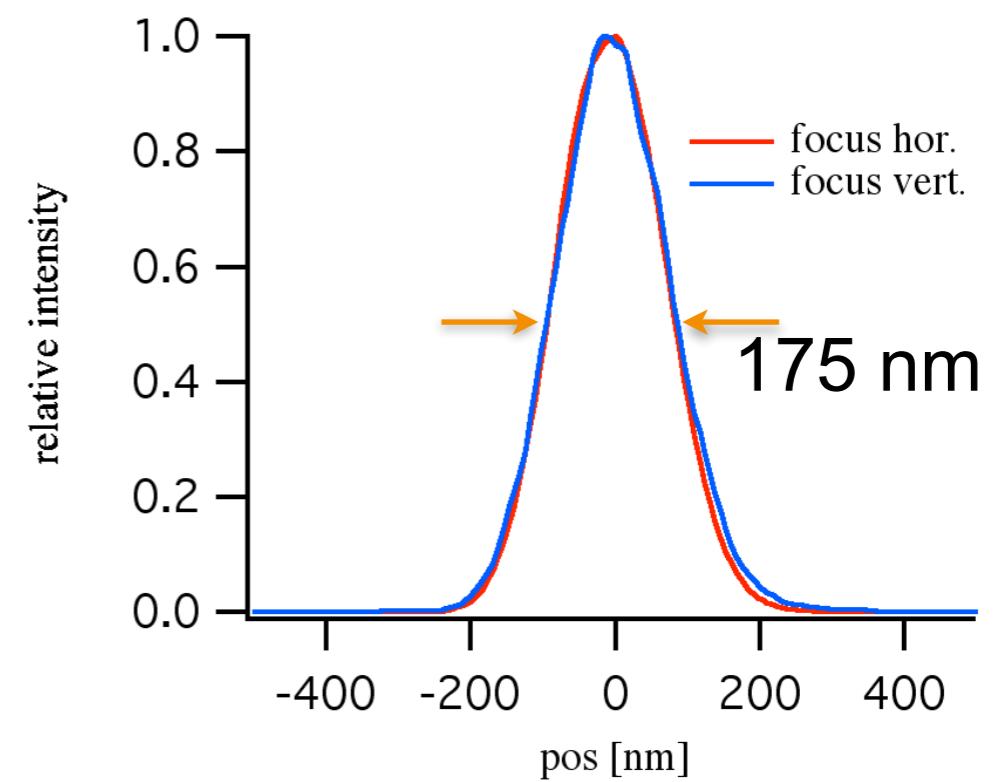


# Evaluation of the Complex Wave Field

complex amplitude:      intensity:



$1/\sqrt{2} \times$  width of amplitude

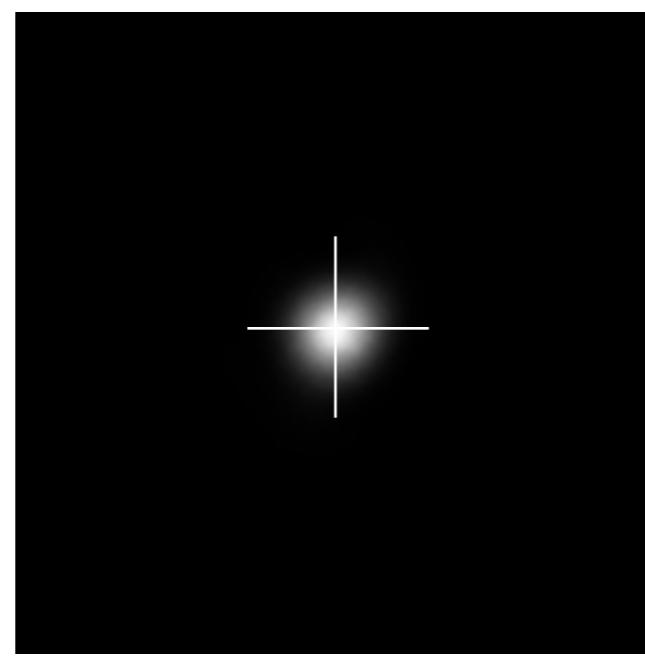
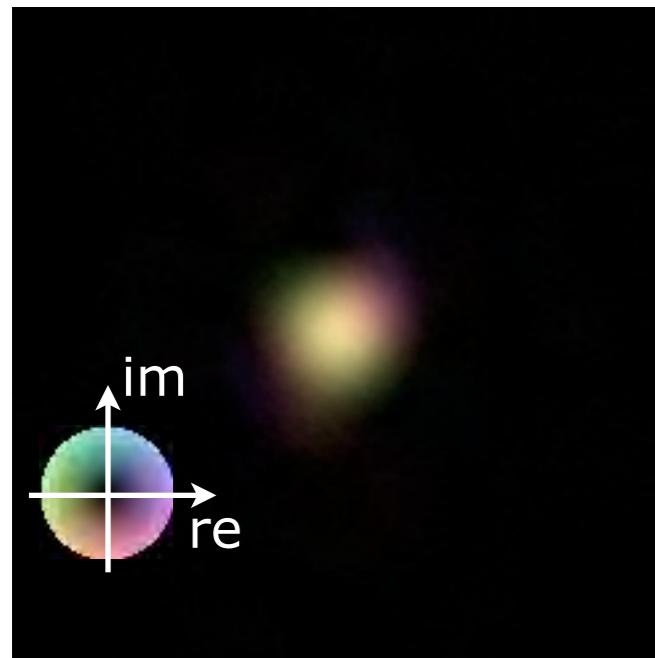


ideal focus:  $155 \times 175 \text{ nm}^2$

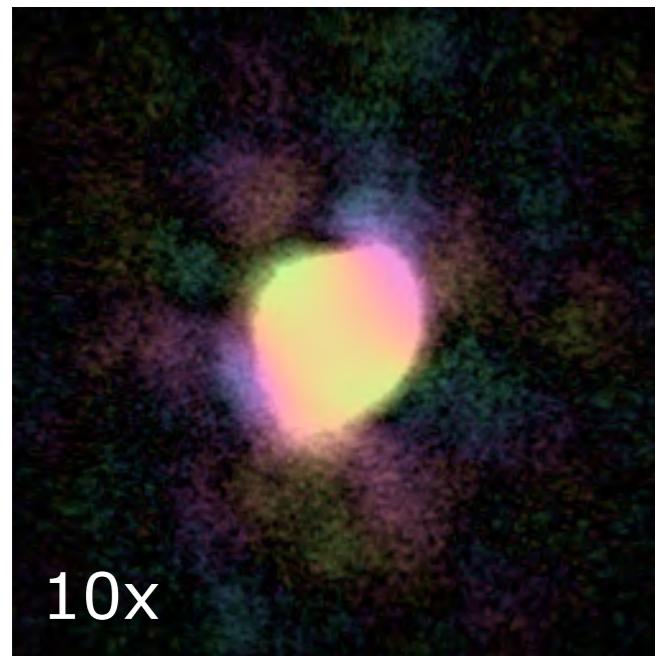
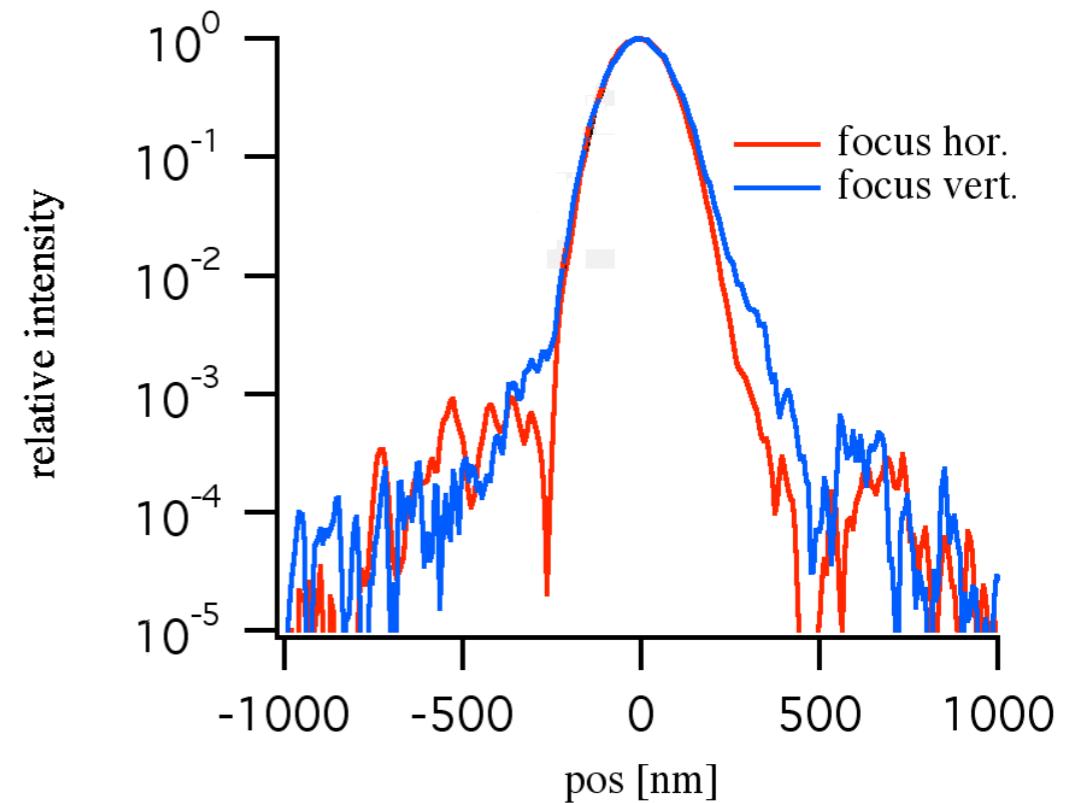
- A. Schropp, et al., Appl. Phys. Lett. **96**, 091102 (2010).  
C. G. Schroer, et al., Proc. SPIE **8848**, 884807 (2013).

# Evaluation of the Complex Wave Field

complex amplitude:      intensity:



$1/\sqrt{2} \times$  width of amplitude



ideal focus:  $155 \times 175 \text{ nm}^2$

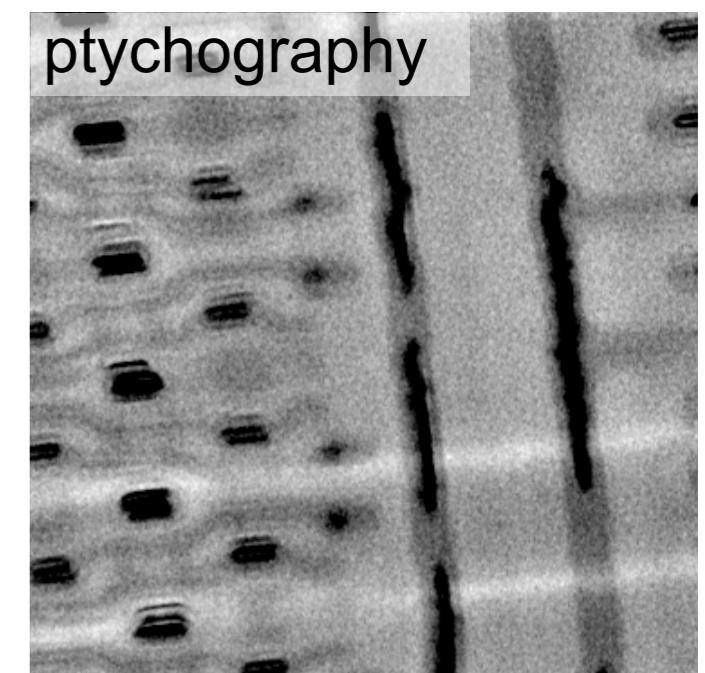
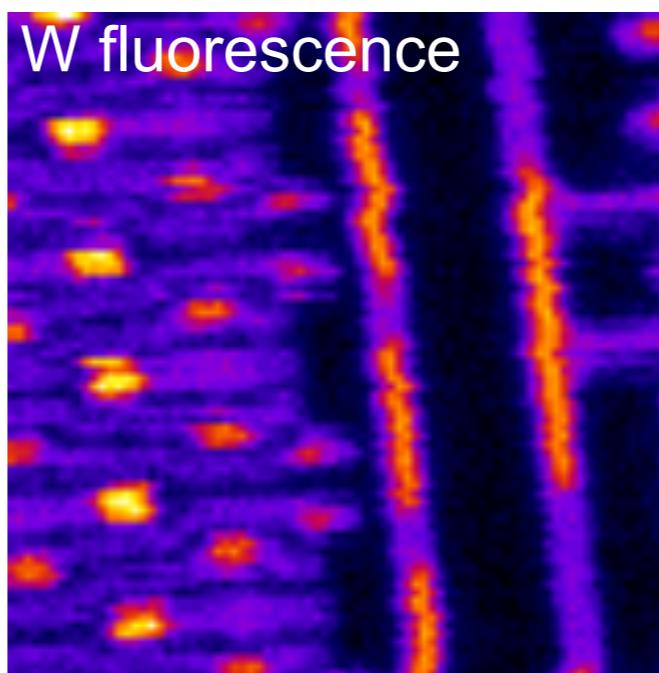
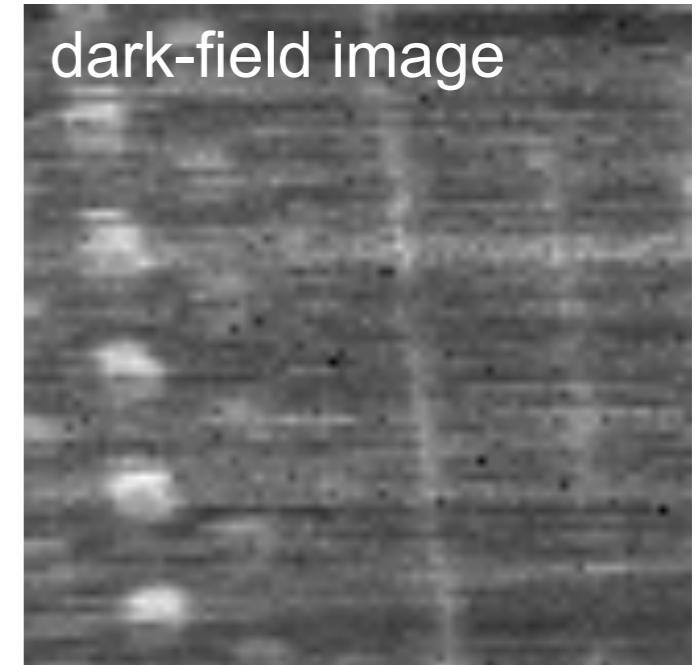
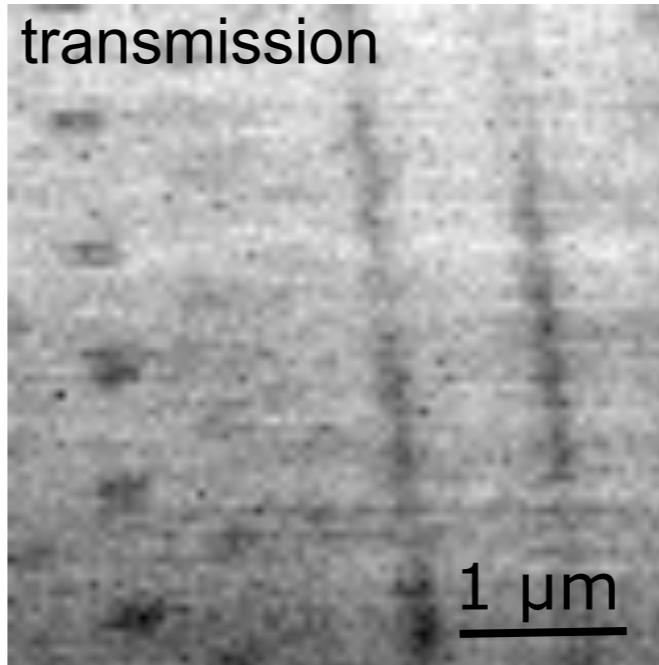
A. Schropp, et al., Appl. Phys. Lett. **96**, 091102 (2010).  
C. G. Schroer, et al., Proc. SPIE **8848**, 884807 (2013).

# Imaging Electronic Nanostructures in a Microchip

$E = 15.25 \text{ keV}$   
focus:  $81 \times 84 \text{ nm}^2$  (FWHM)  
exposure time: 0.1 s  
fluence:  $800 \text{ ph/nm}^2$

scanning parameters:

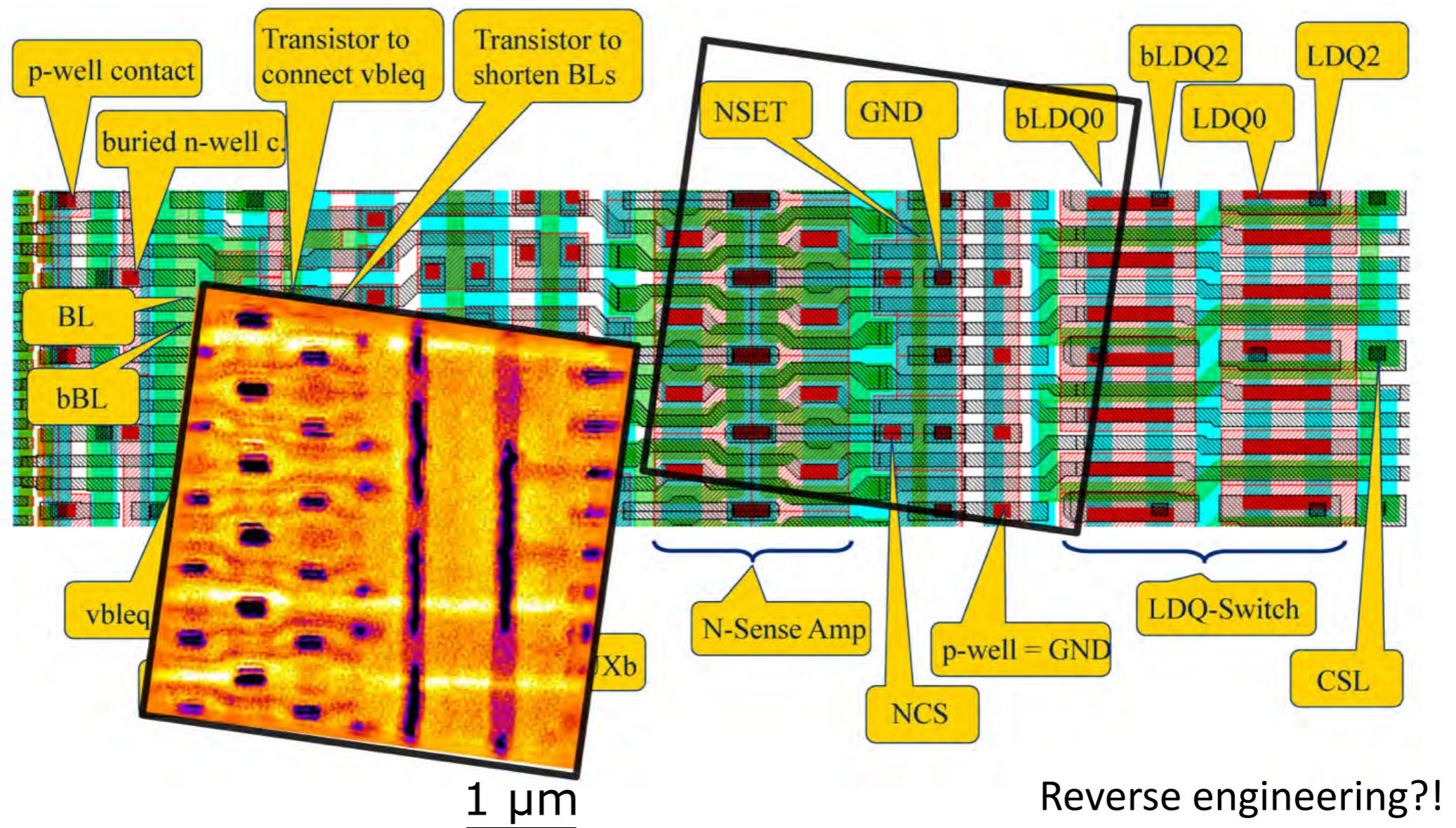
- >  $4 \times 4 \mu\text{m}^2$  (FOV)
- >  $80 \times 80$  steps
- > step size: 50 nm



A. Schropp, et al., Journal of Microscopy **241**, 9 (2011).

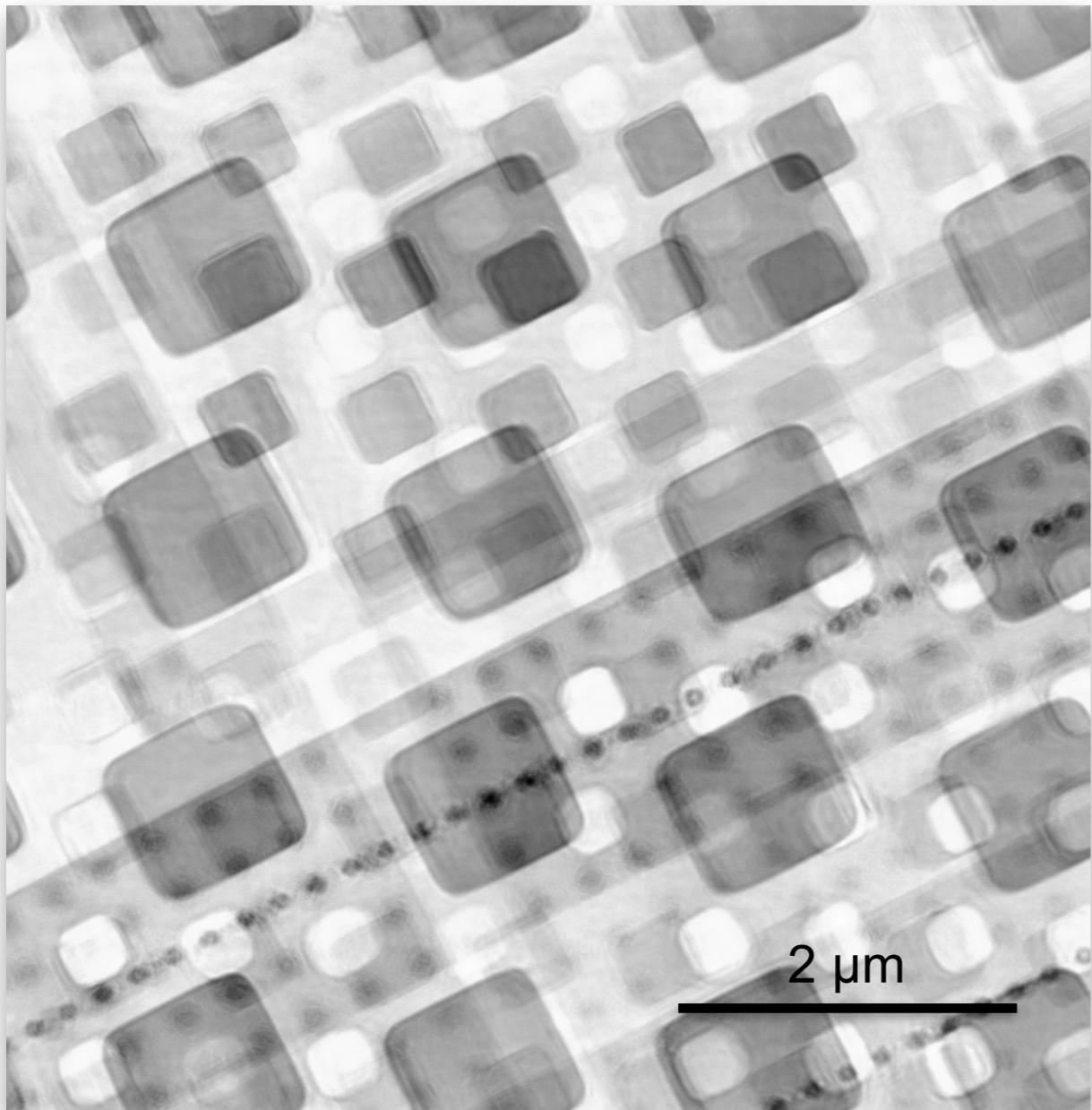
# Imaging Electronic Nanostructures in a Microchip

## Shared sense amplifier (80 nm)



# Imaging Electronic Nanostructures in a Microchip

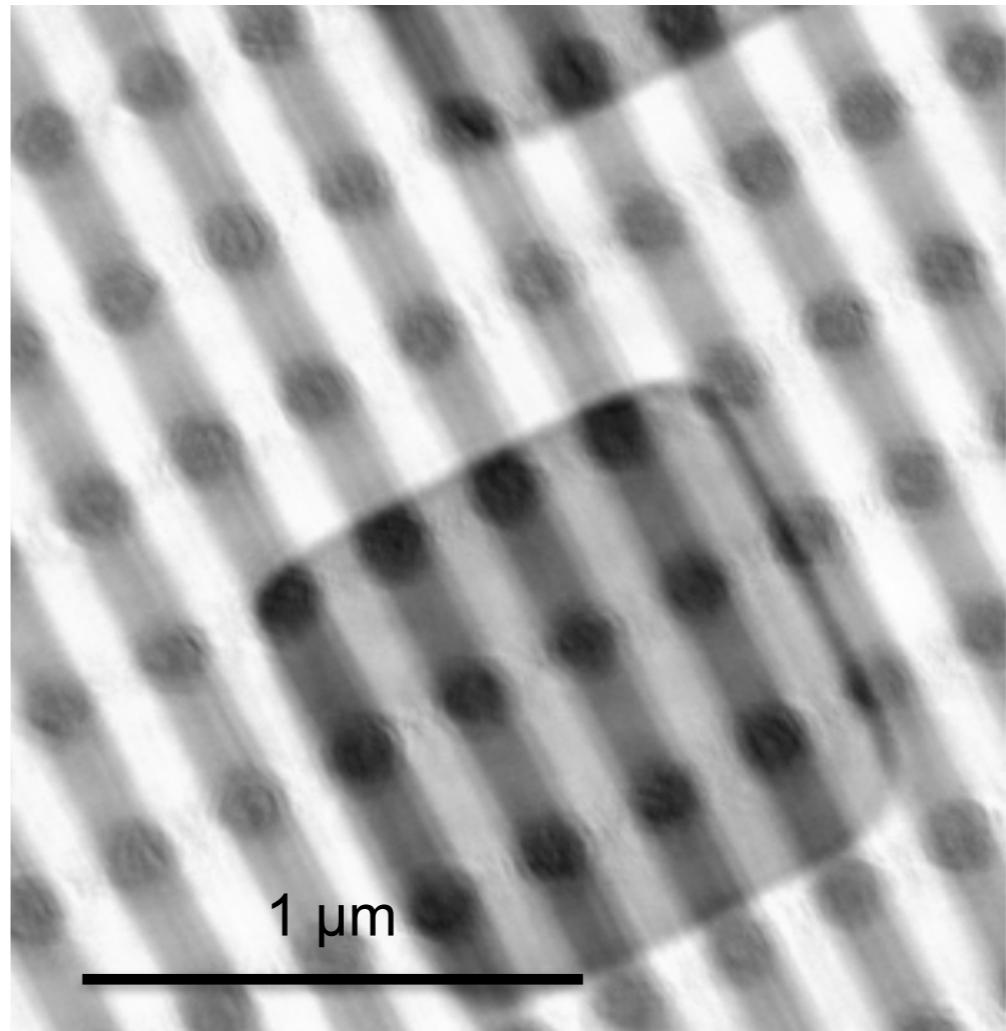
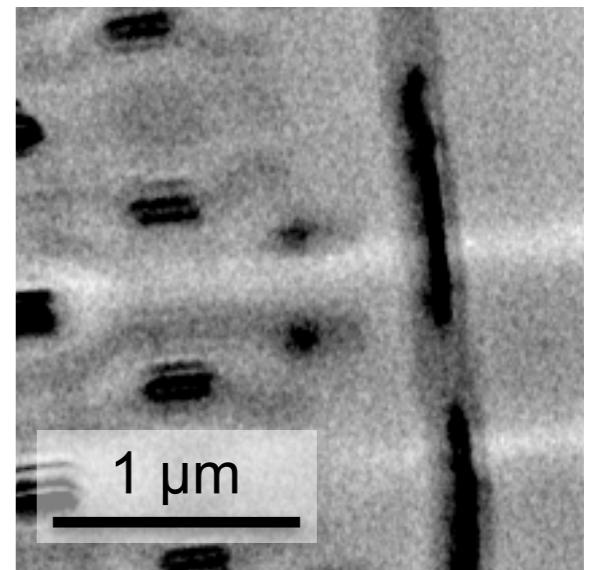
Currently at PETRA III:  
imaging nanostructures in test chip

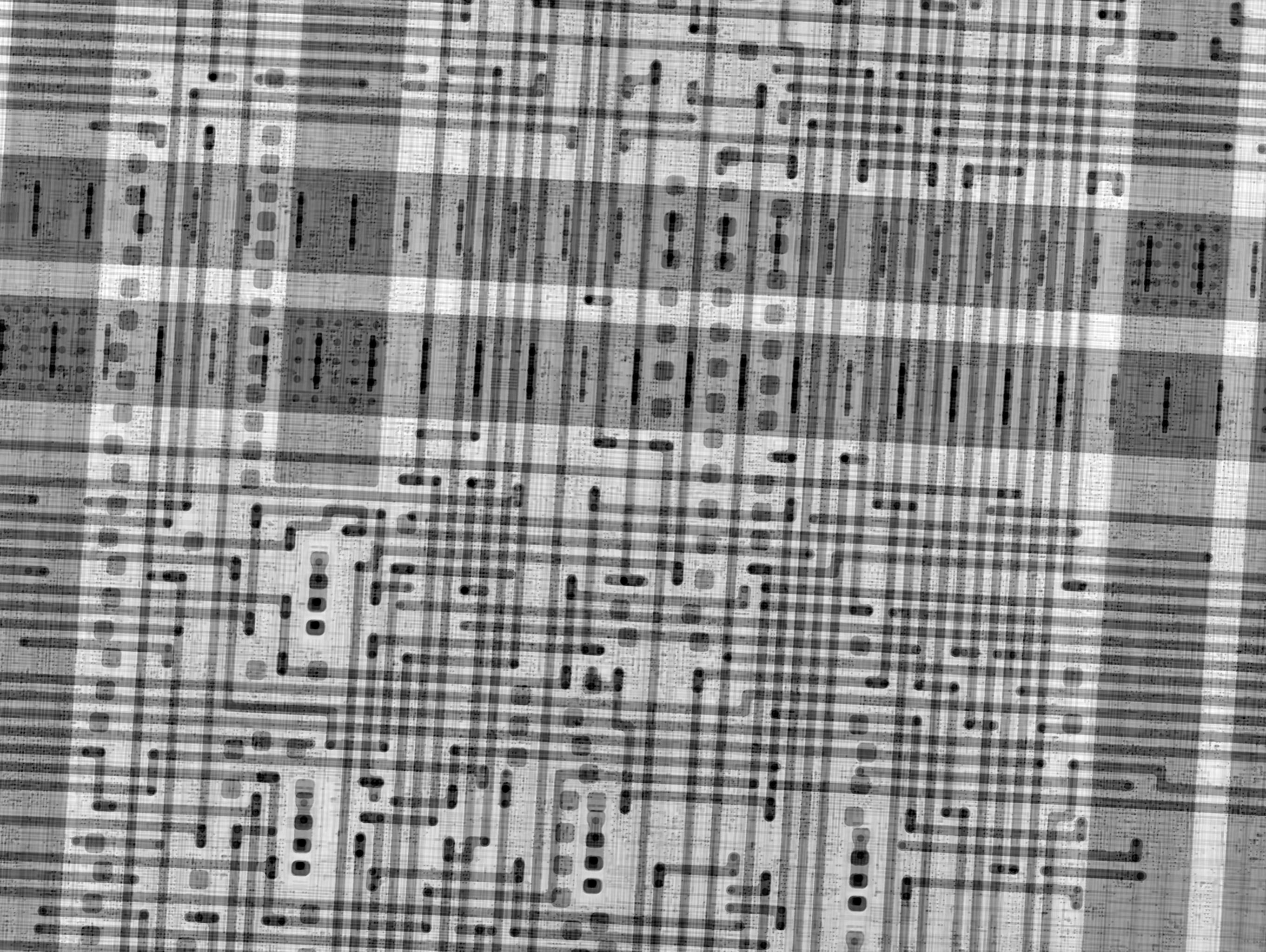


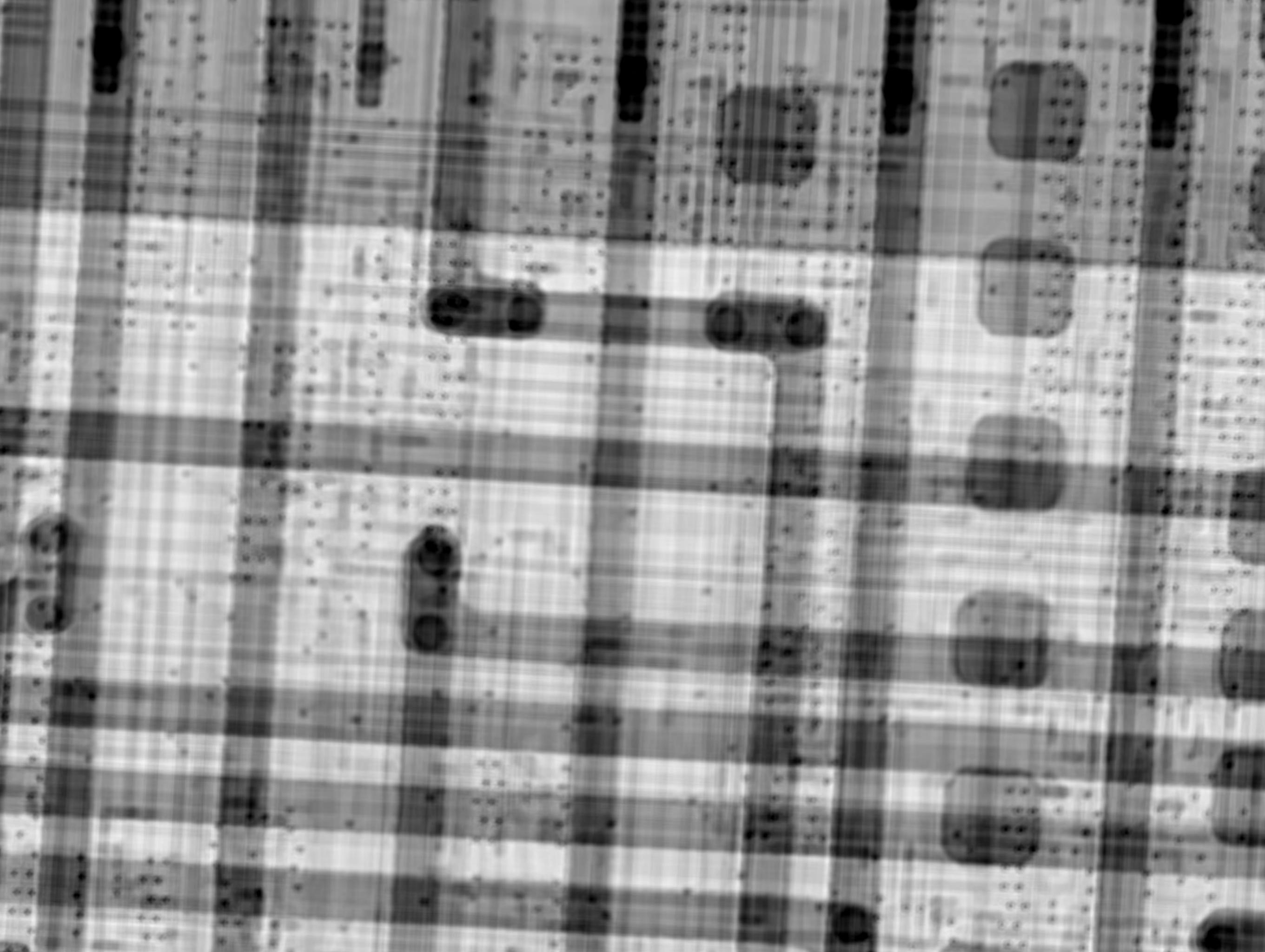
no sample preparation  
collaboration with Infineon (Dresden)

for comparison:

A. Schropp, et al.,  
J. Micro. **241**, 9 (2011).

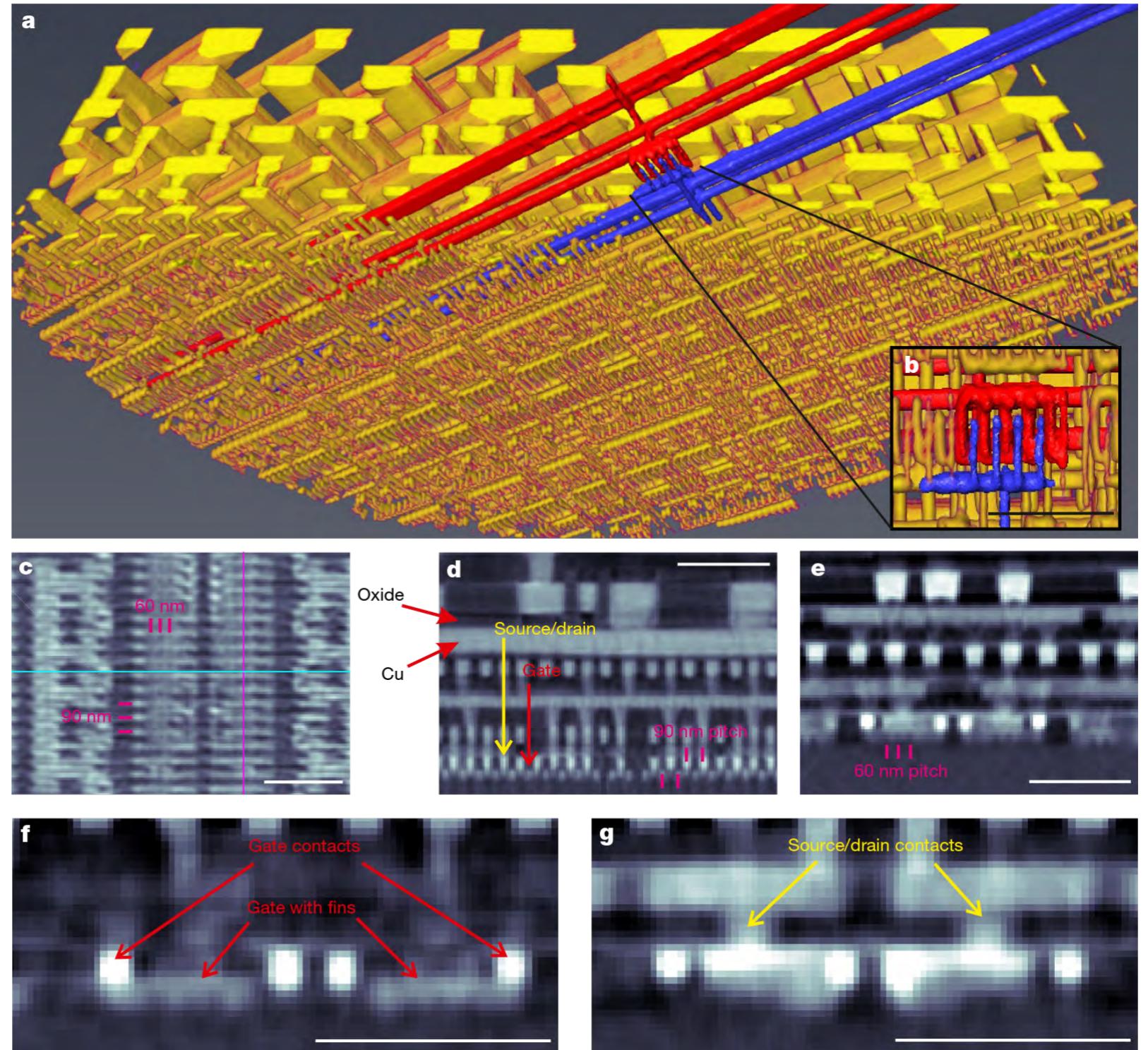






# Ptychography Combined with Tomography

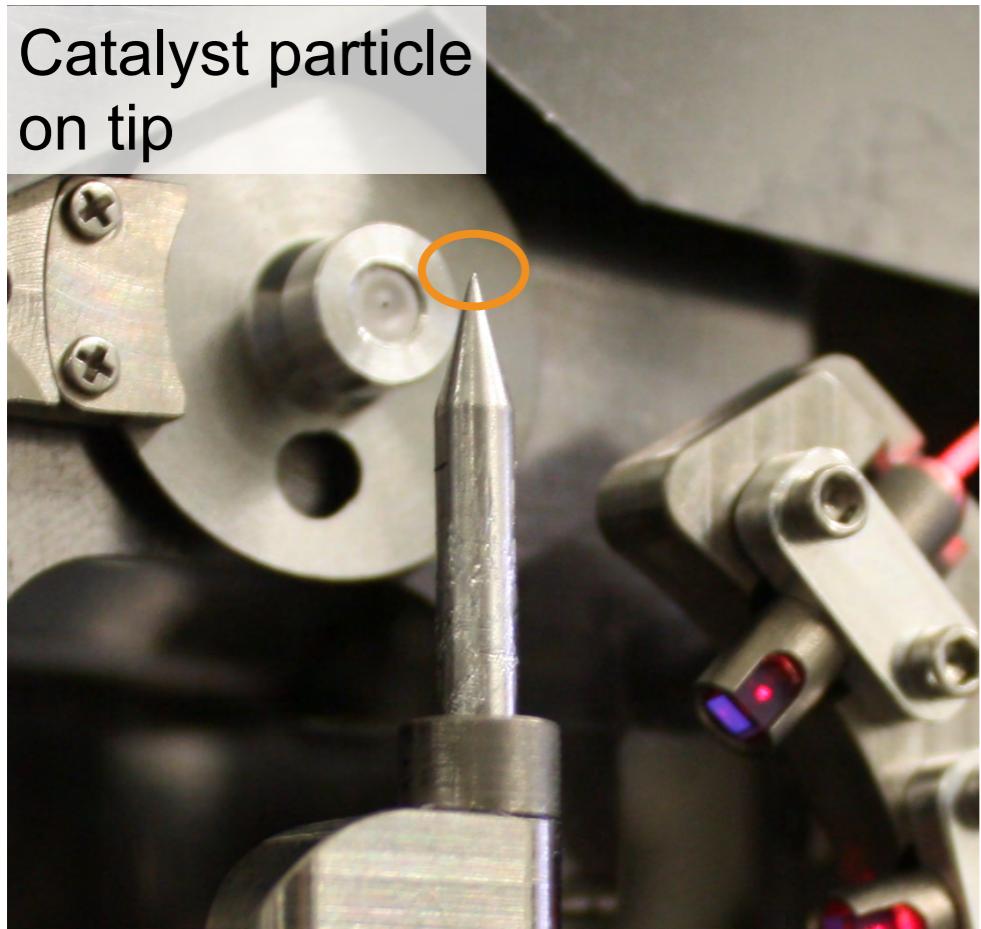
- > **ptychography:**  
record a series of projections  
with high spatial resolution
- > **tomography:**  
combine the projections to a  
three



M. Holler, et al., *High-Resolution Non-Destructive Three-Dimensional Imaging of Integrated Circuits*, Nature **543**, 402 (2017).

# Ptycho-Tomography of Catalysts

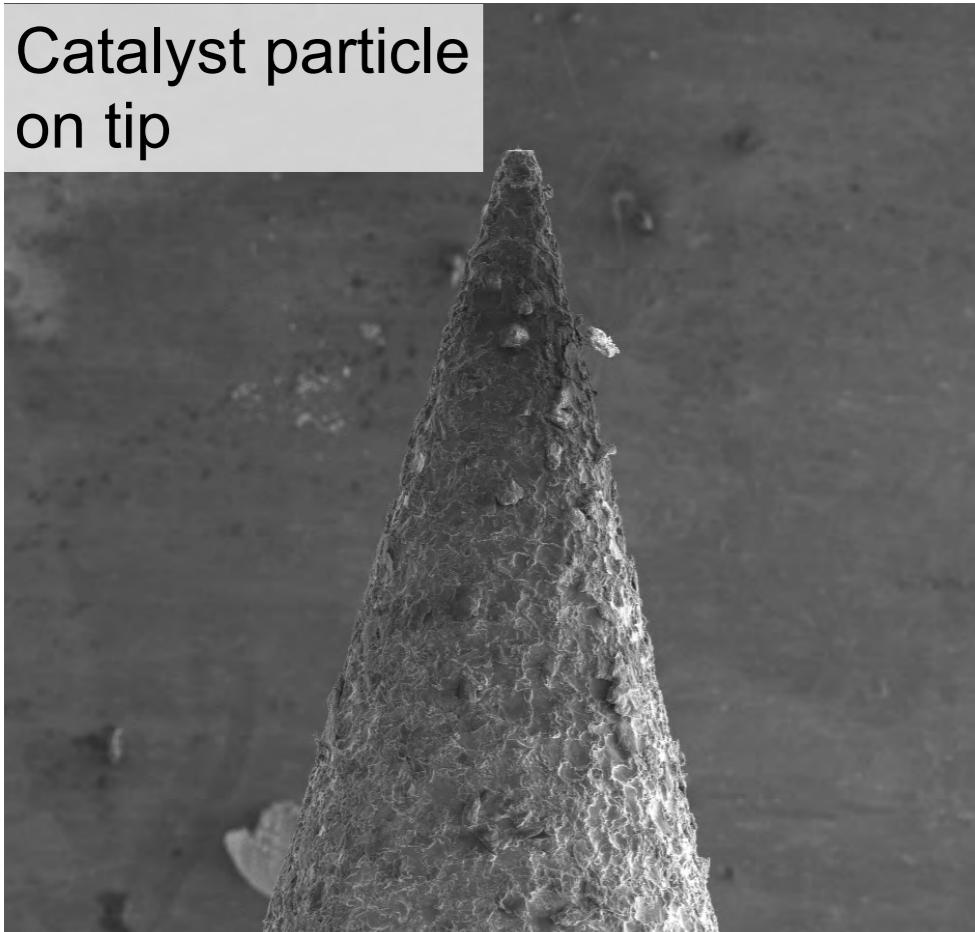
Catalyst particle  
on tip



M. Kahnt, et al., *Coupled Ptychography and Tomography Algorithm Improves Reconstruction of Experimental Data*, Optica **6**, 1282 (2019).

# Ptycho-Tomography of Catalysts

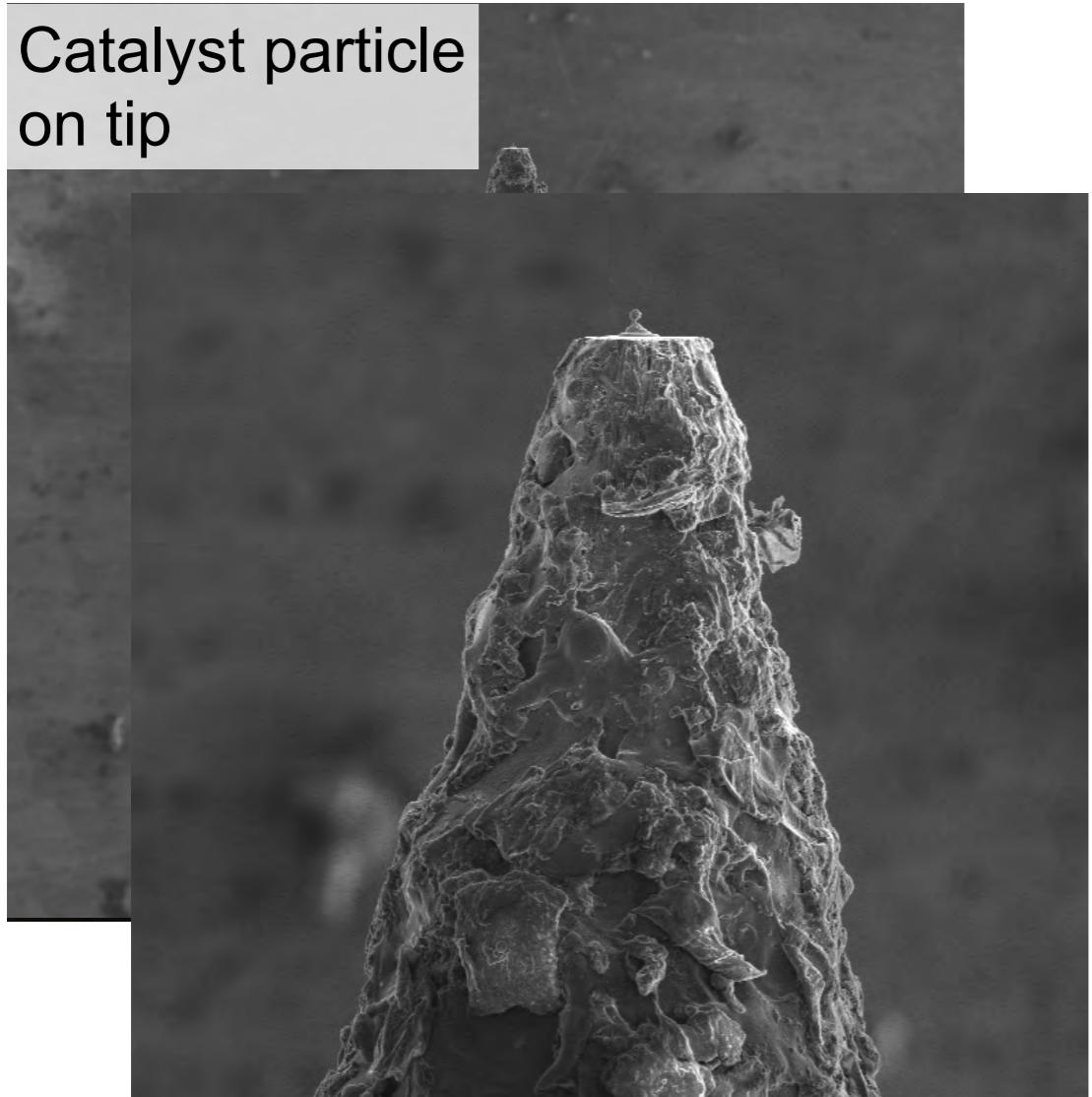
Catalyst particle  
on tip



M. Kahnt, et al., *Coupled Ptychography and Tomography Algorithm Improves Reconstruction of Experimental Data*, Optica **6**, 1282 (2019).

# Ptycho-Tomography of Catalysts

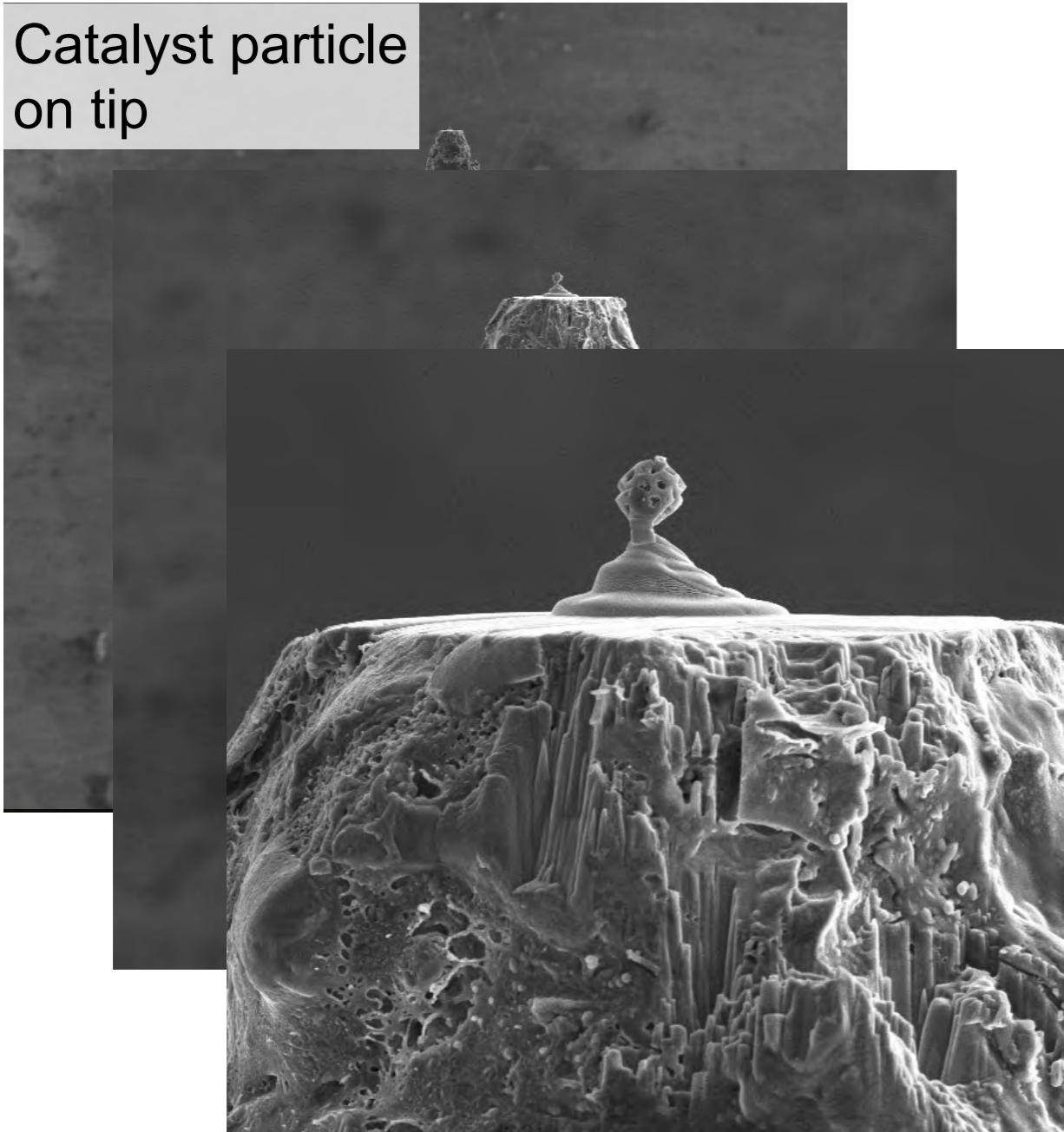
Catalyst particle  
on tip



M. Kahnt, et al., *Coupled Ptychography and Tomography Algorithm Improves Reconstruction of Experimental Data*, Optica **6**, 1282 (2019).

# Ptycho-Tomography of Catalysts

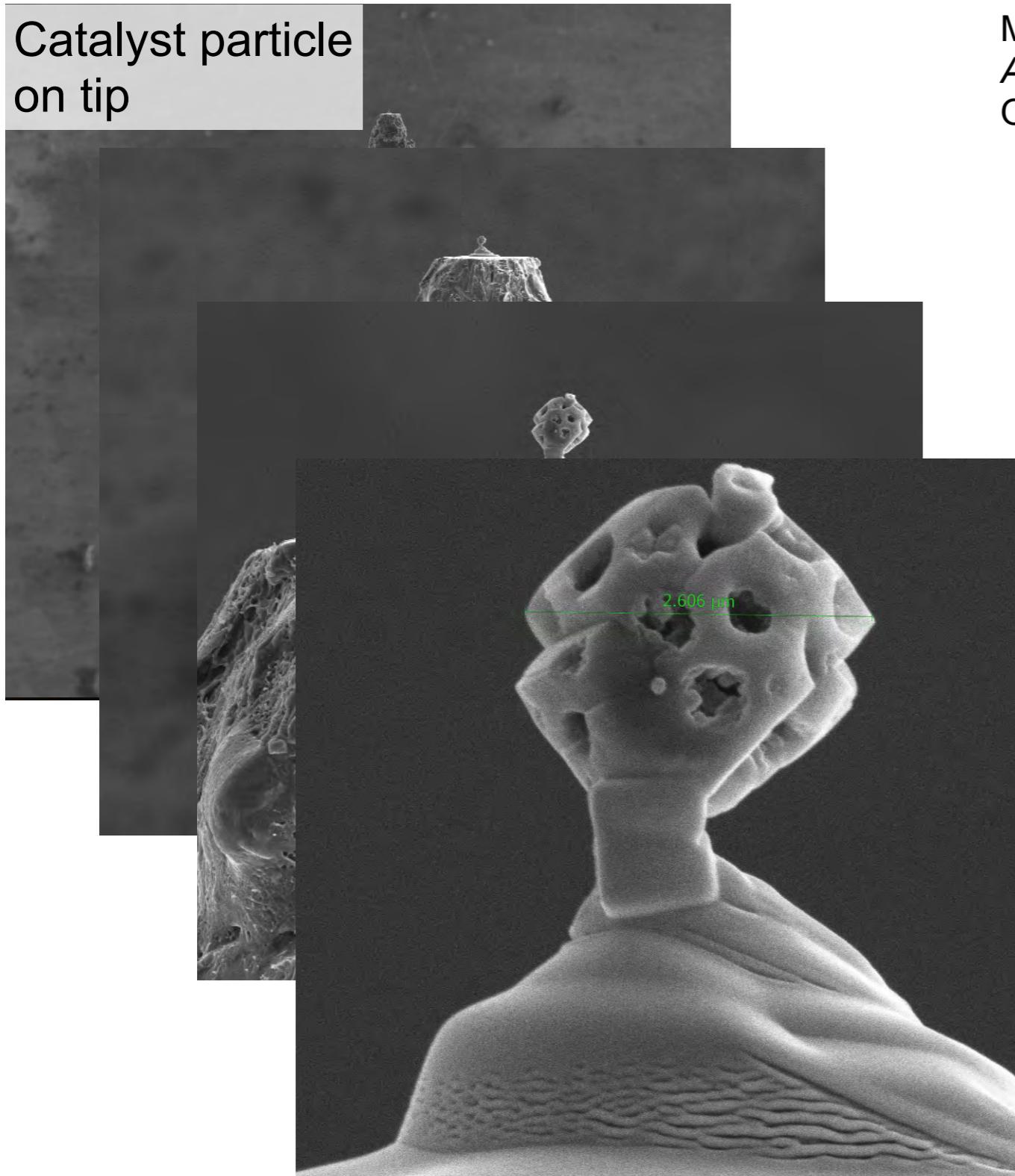
Catalyst particle  
on tip



M. Kahnt, et al., *Coupled Ptychography and Tomography Algorithm Improves Reconstruction of Experimental Data*, Optica **6**, 1282 (2019).

# Ptycho-Tomography of Catalysts

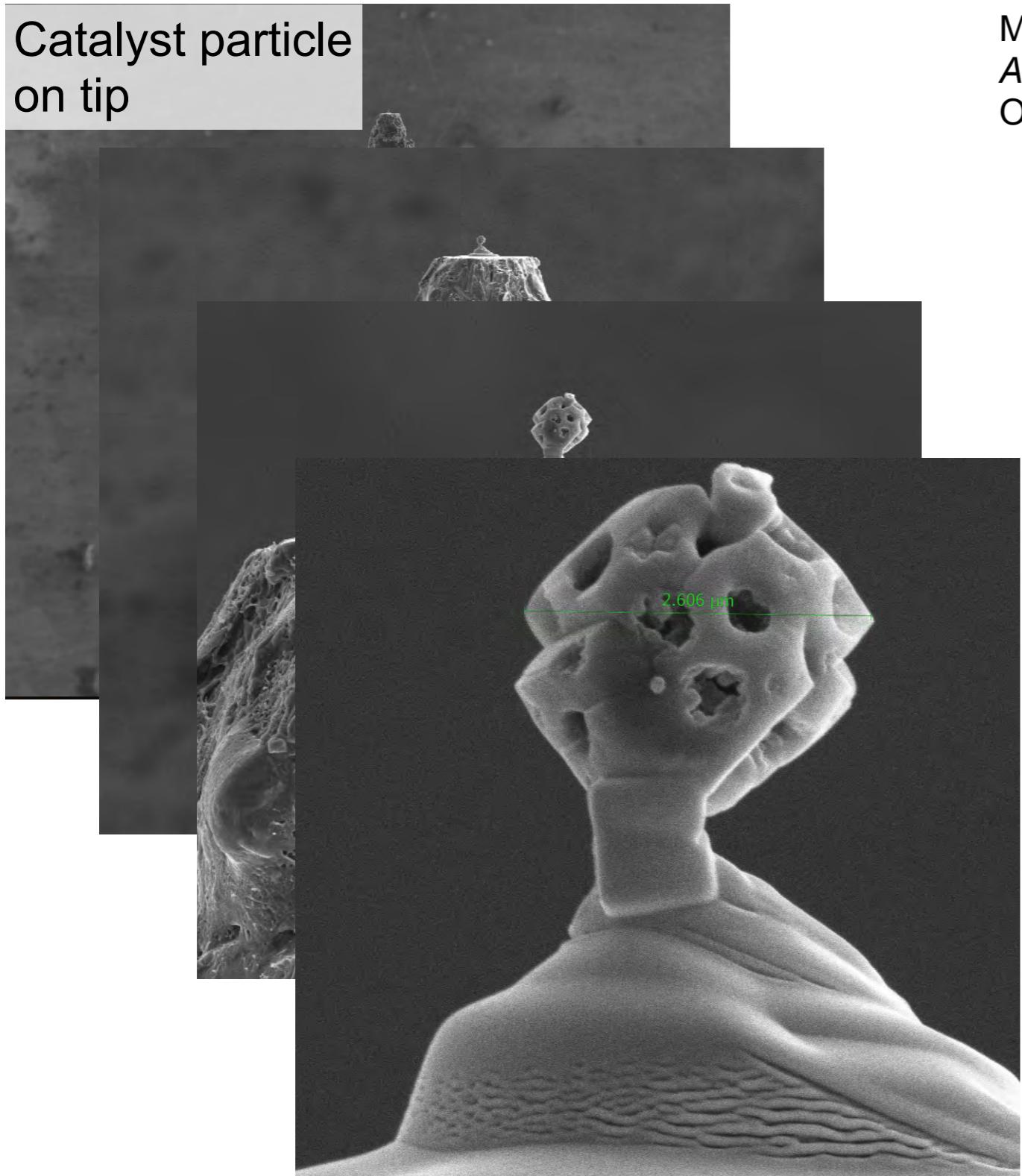
Catalyst particle  
on tip



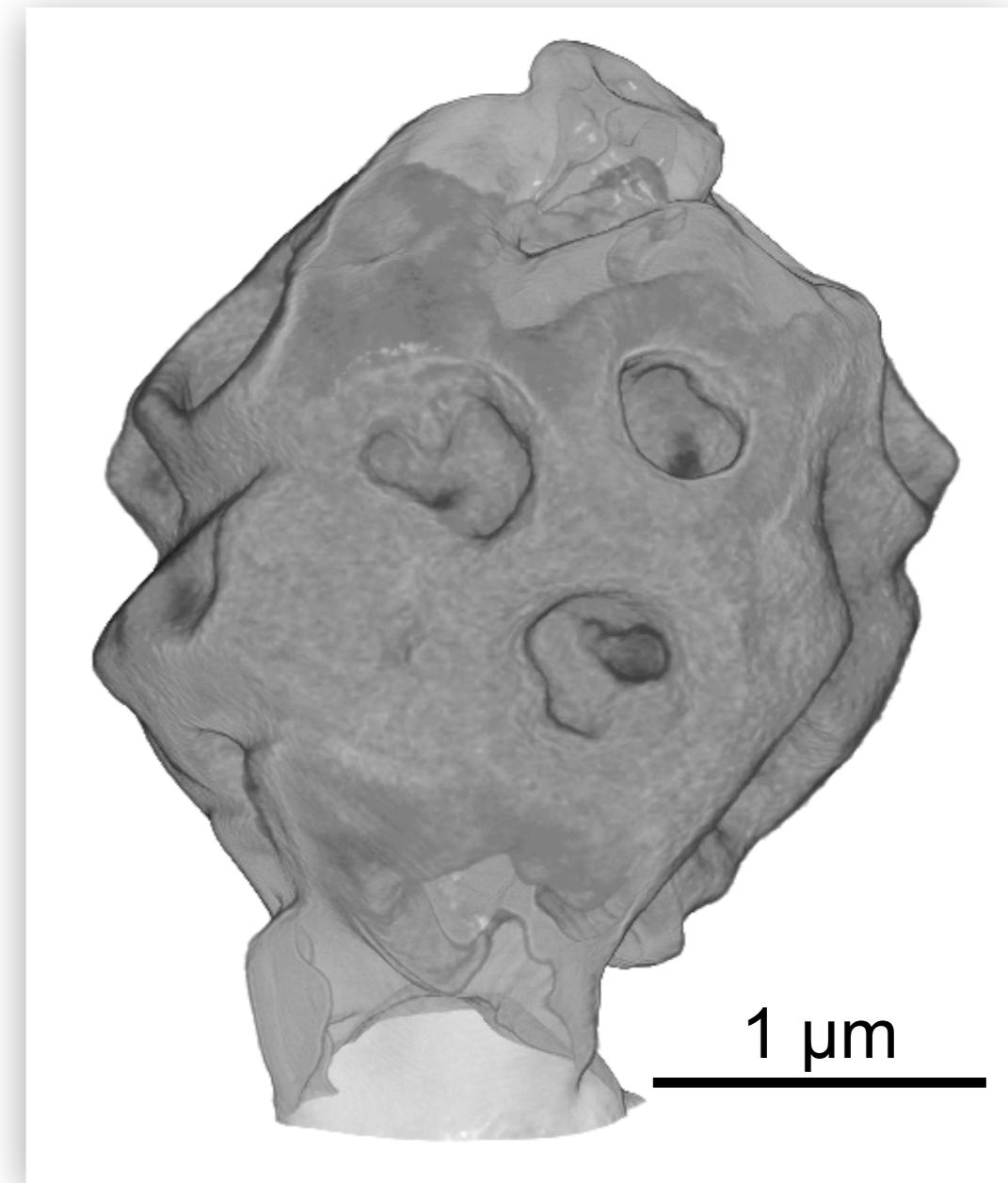
M. Kahnt, et al., *Coupled Ptychography and Tomography Algorithm Improves Reconstruction of Experimental Data*, Optica **6**, 1282 (2019).

# Ptycho-Tomography of Catalysts

Catalyst particle  
on tip



M. Kahnt, et al., *Coupled Ptychography and Tomography Algorithm Improves Reconstruction of Experimental Data*, Optica **6**, 1282 (2019).



# Time-Resolved Imaging at X-Ray Free-Electron Lasers

Microscopy at the XFEL

LCLS at SLAC in Menlo Parc, CA

single-pulse imaging of  
fast processes in matter

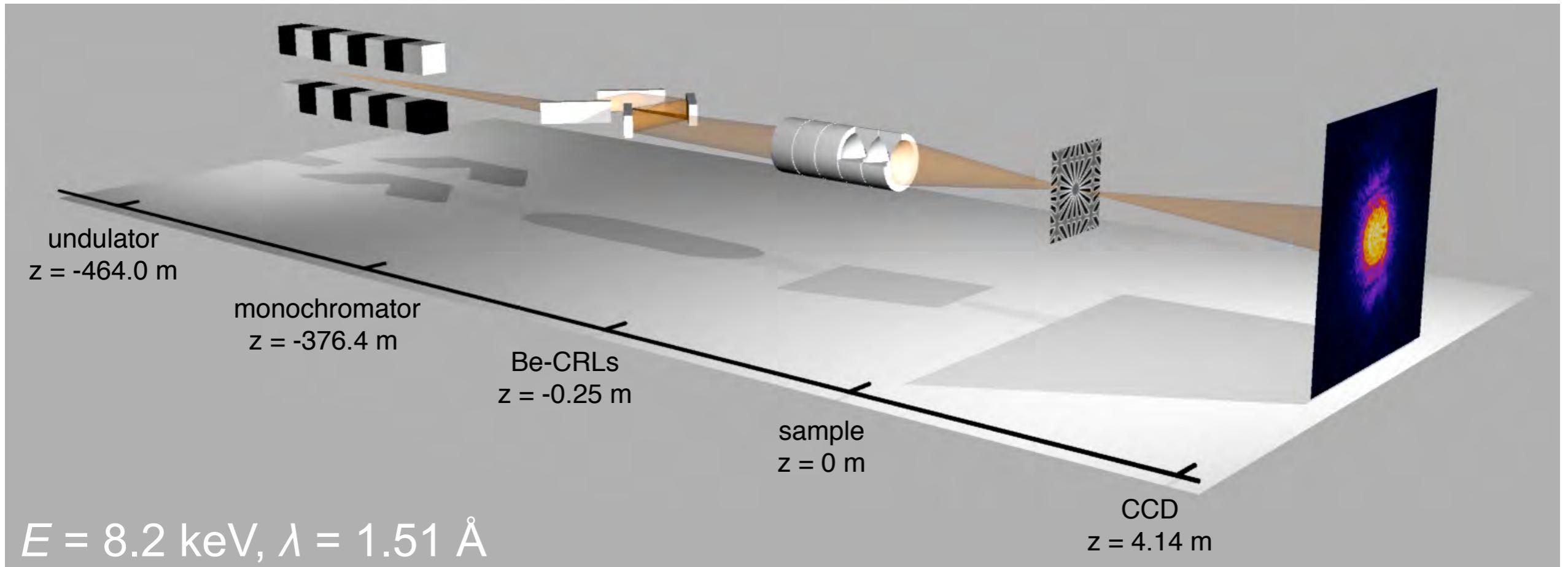


pump-probe experiments:

- > excite process in matter
- > probe by single-pulse microscopy



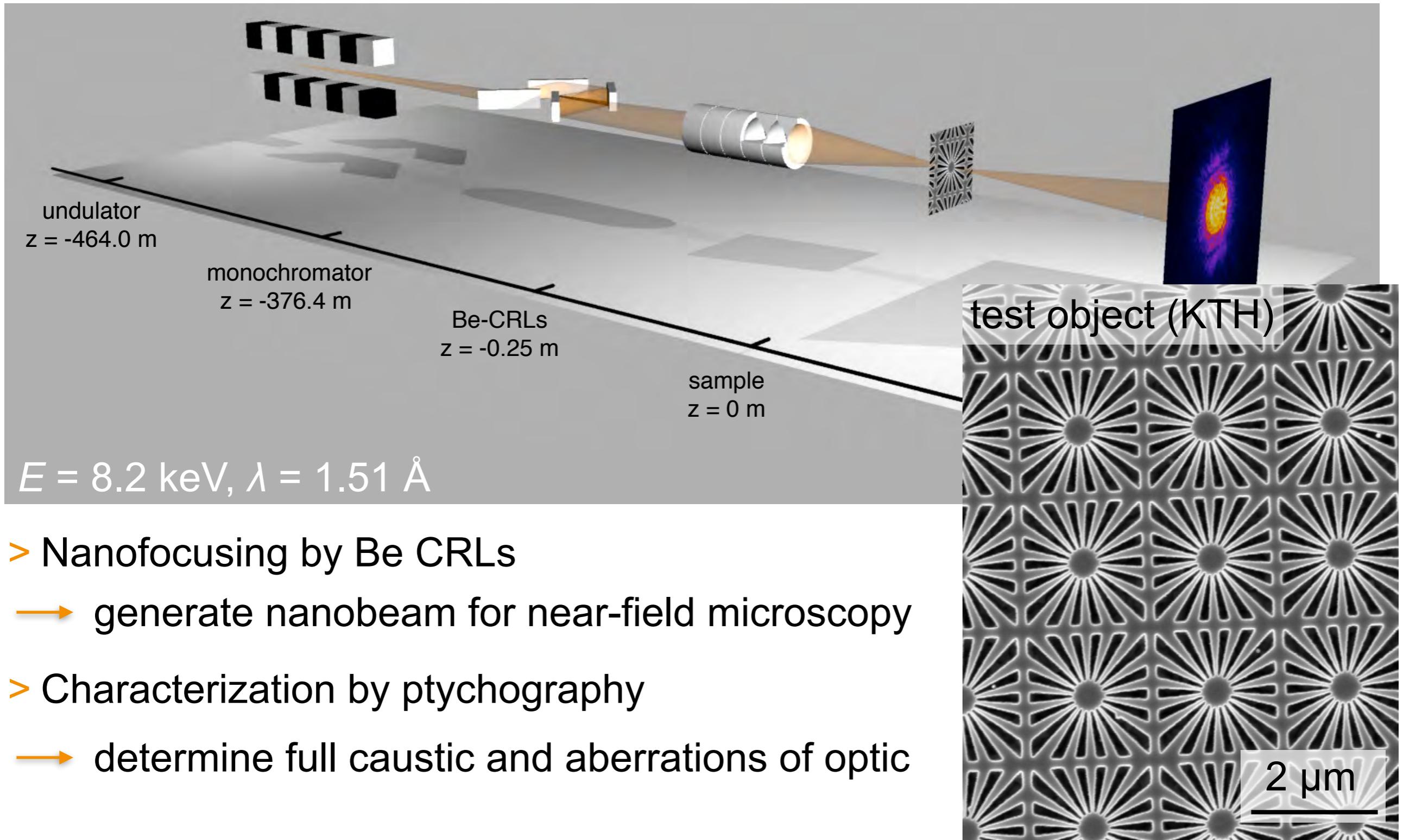
# Nanofocusing and Nanoimaging at LCLS



- > Nanofocusing by Be CRLs
  - generate nanobeam for near-field microscopy
- > Characterization by ptychography
  - determine full caustic and aberrations of optic

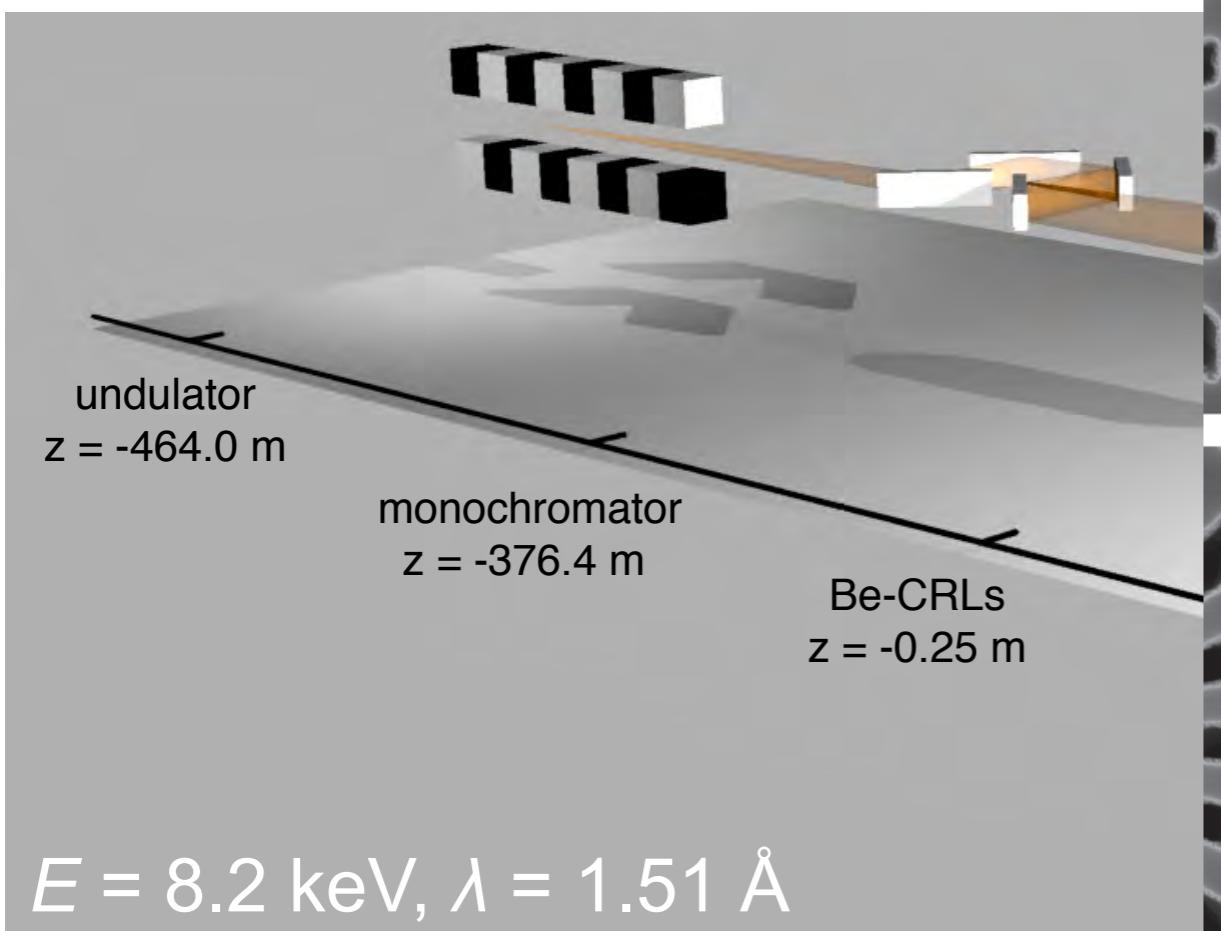
A. Schropp, et al., Sci. Rep. 3, 1633 (2013).

# Nanofocusing and Nanoimaging at LCLS

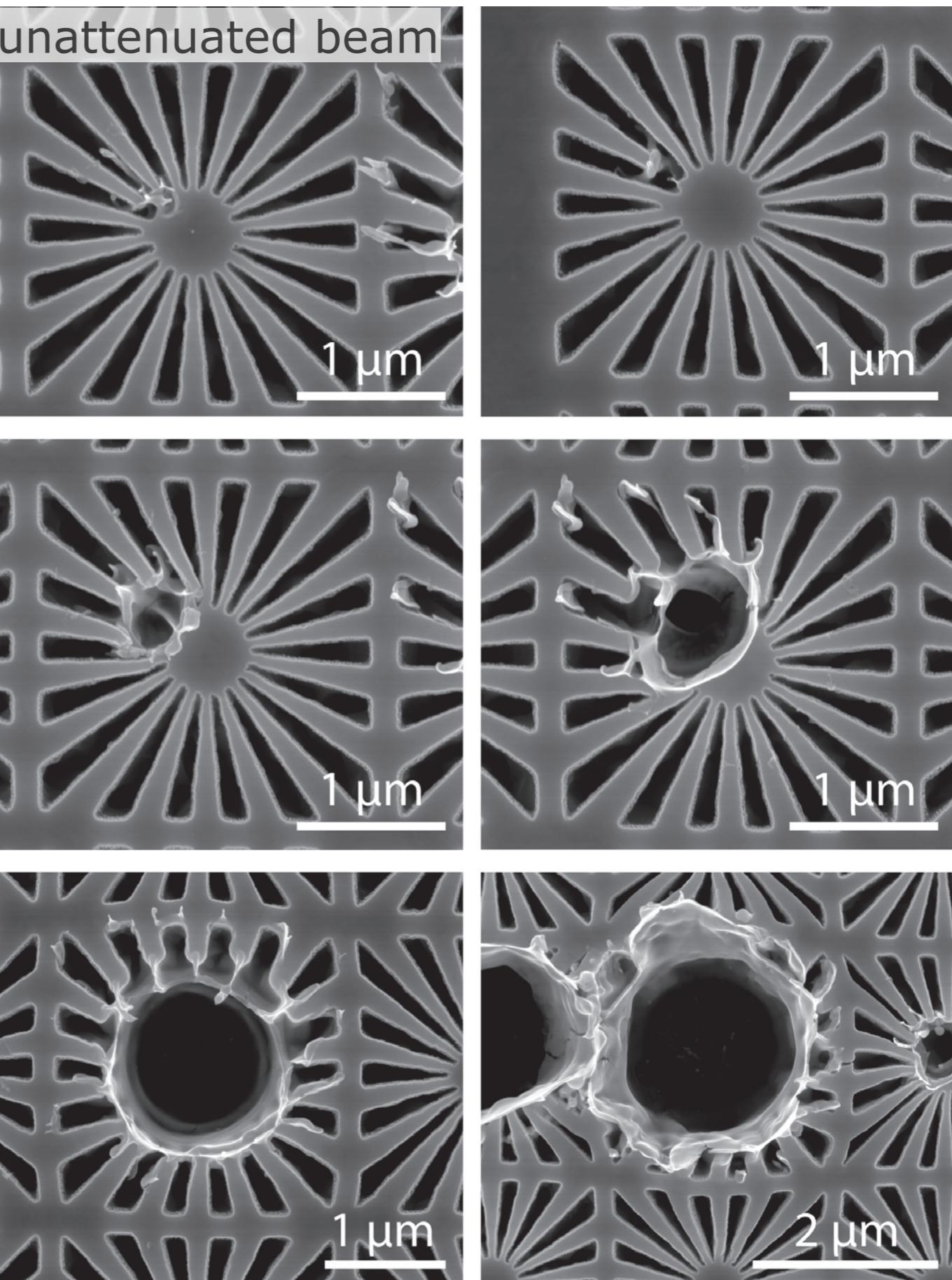


A. Schropp, et al., Sci. Rep. 3, 1633 (2013).

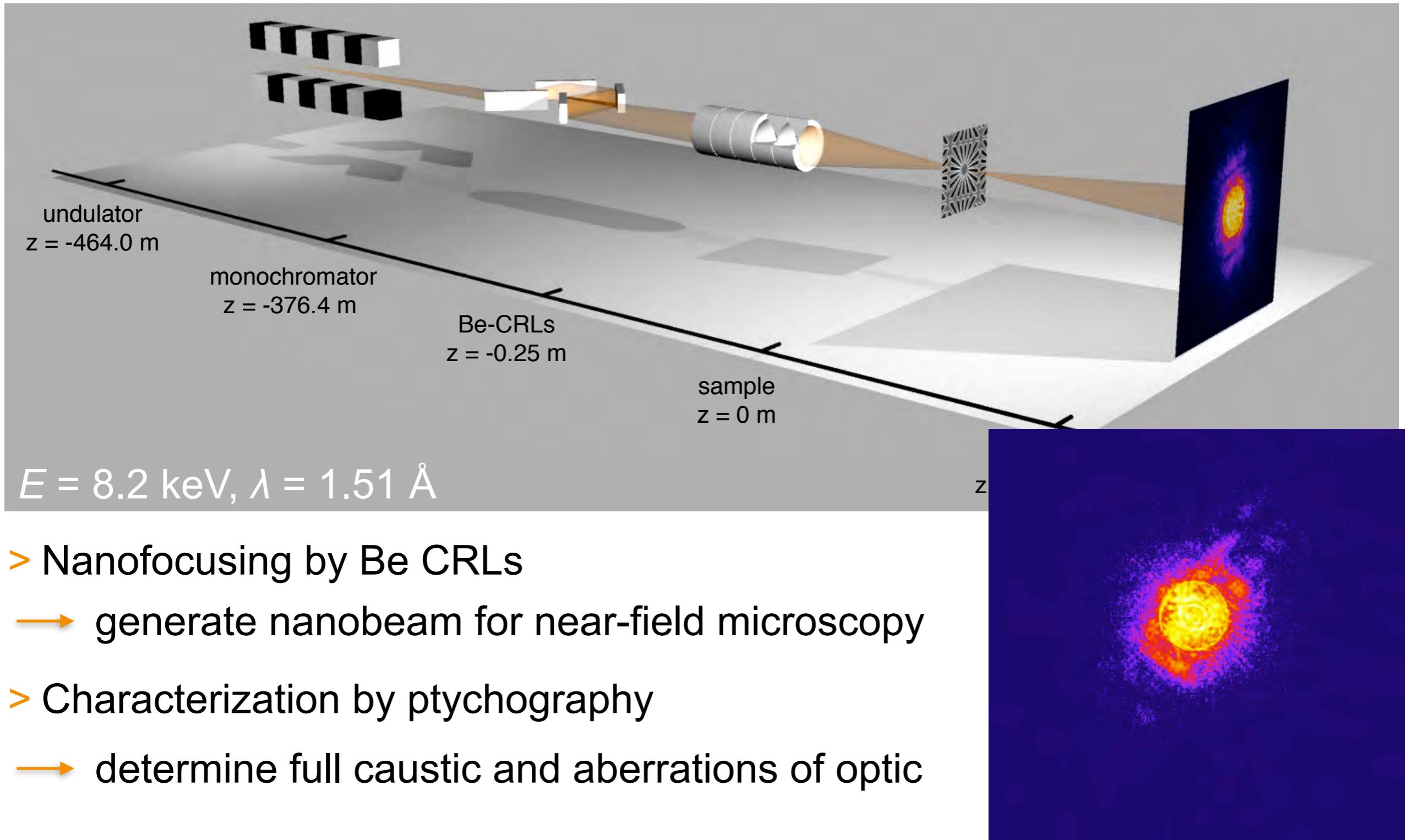
# Nanofocusing and Nan



- > Nanofocusing by Be CRLs
- generate nanobeam for near-field
- > Characterization by ptychography
- determine full caustic and aber



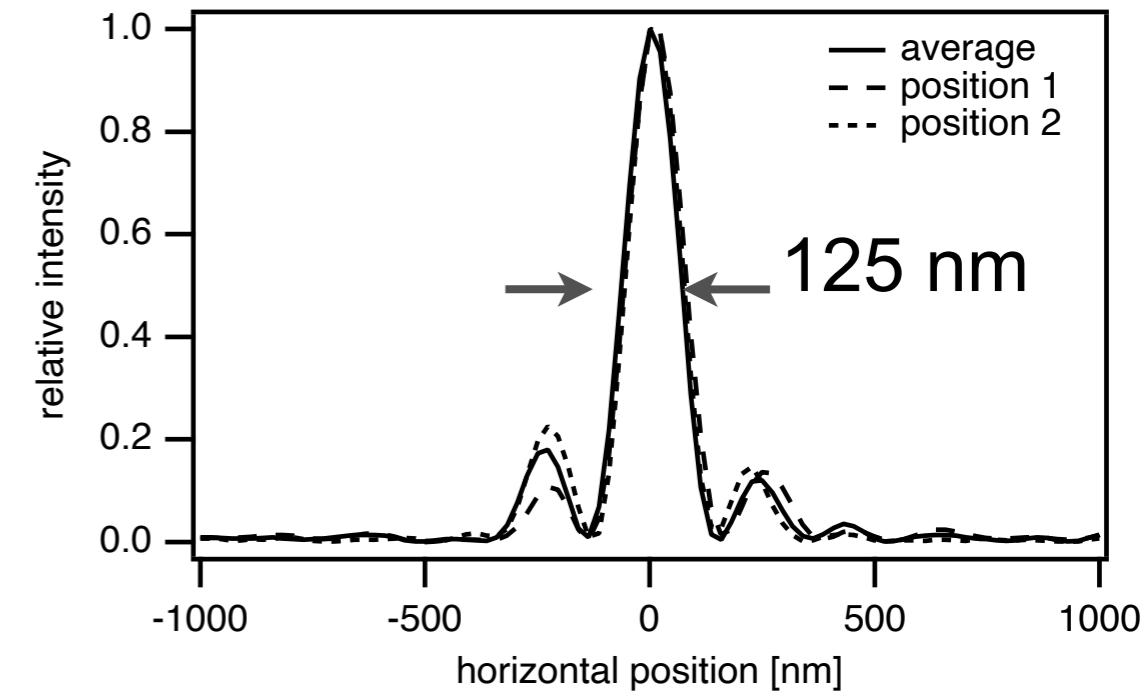
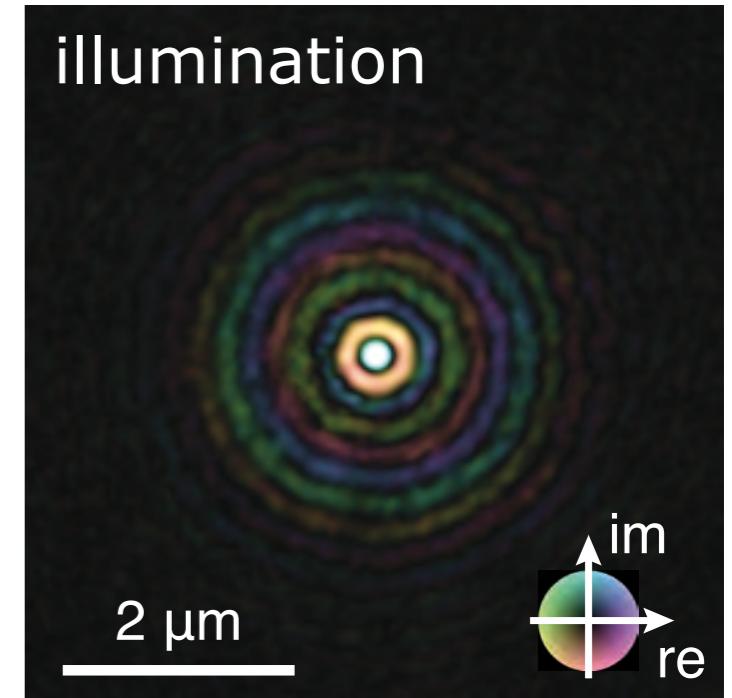
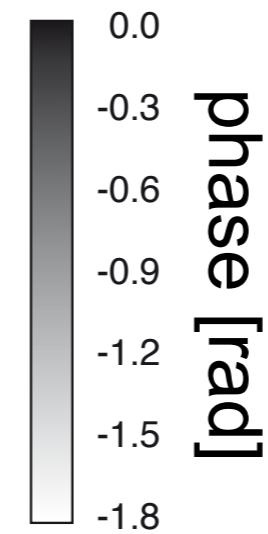
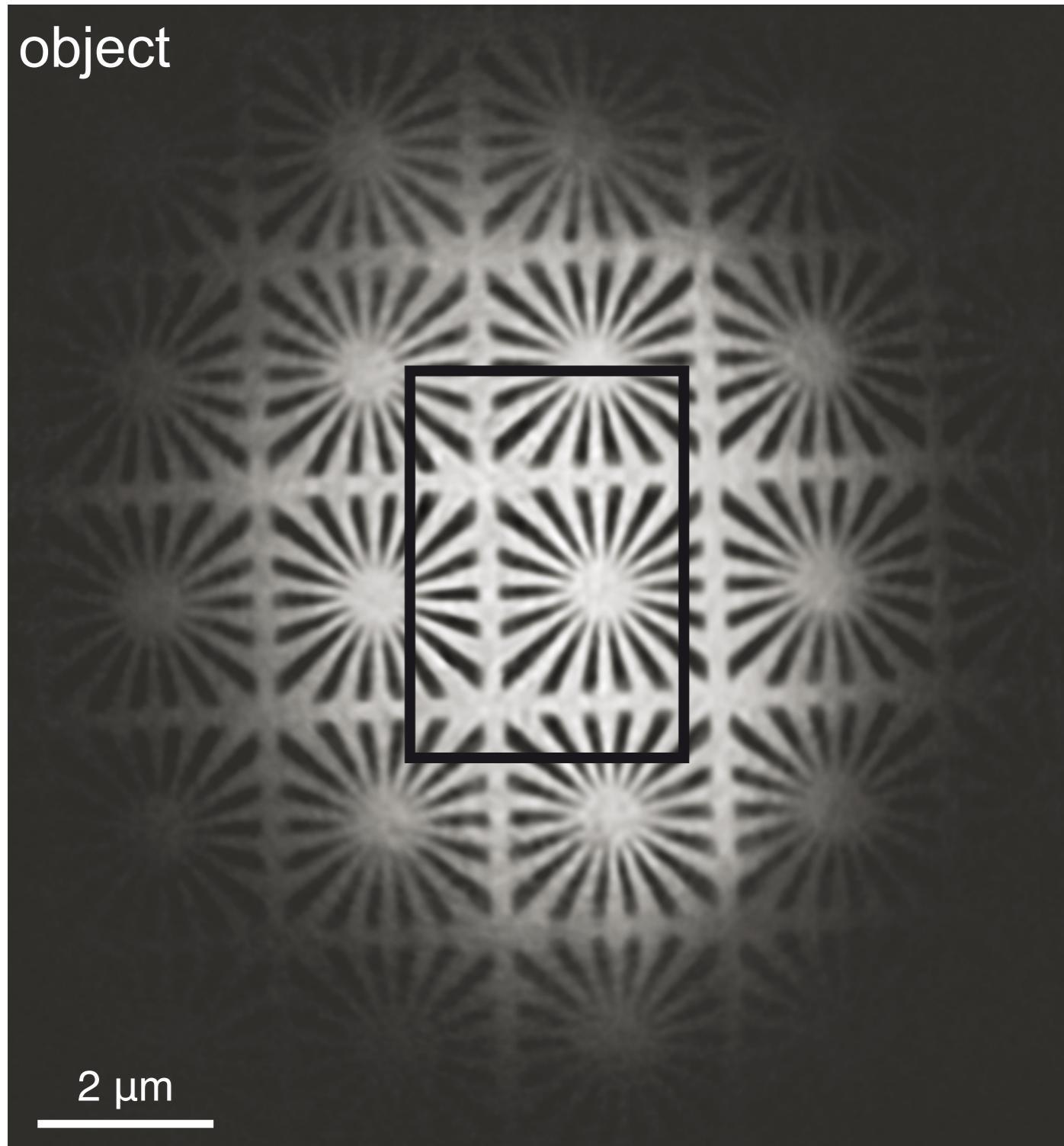
# Nanofocusing and Nanoimaging at LCLS



- > Nanofocusing by Be CRLs
  - generate nanobeam for near-field microscopy
- > Characterization by ptychography
  - determine full caustic and aberrations of optic

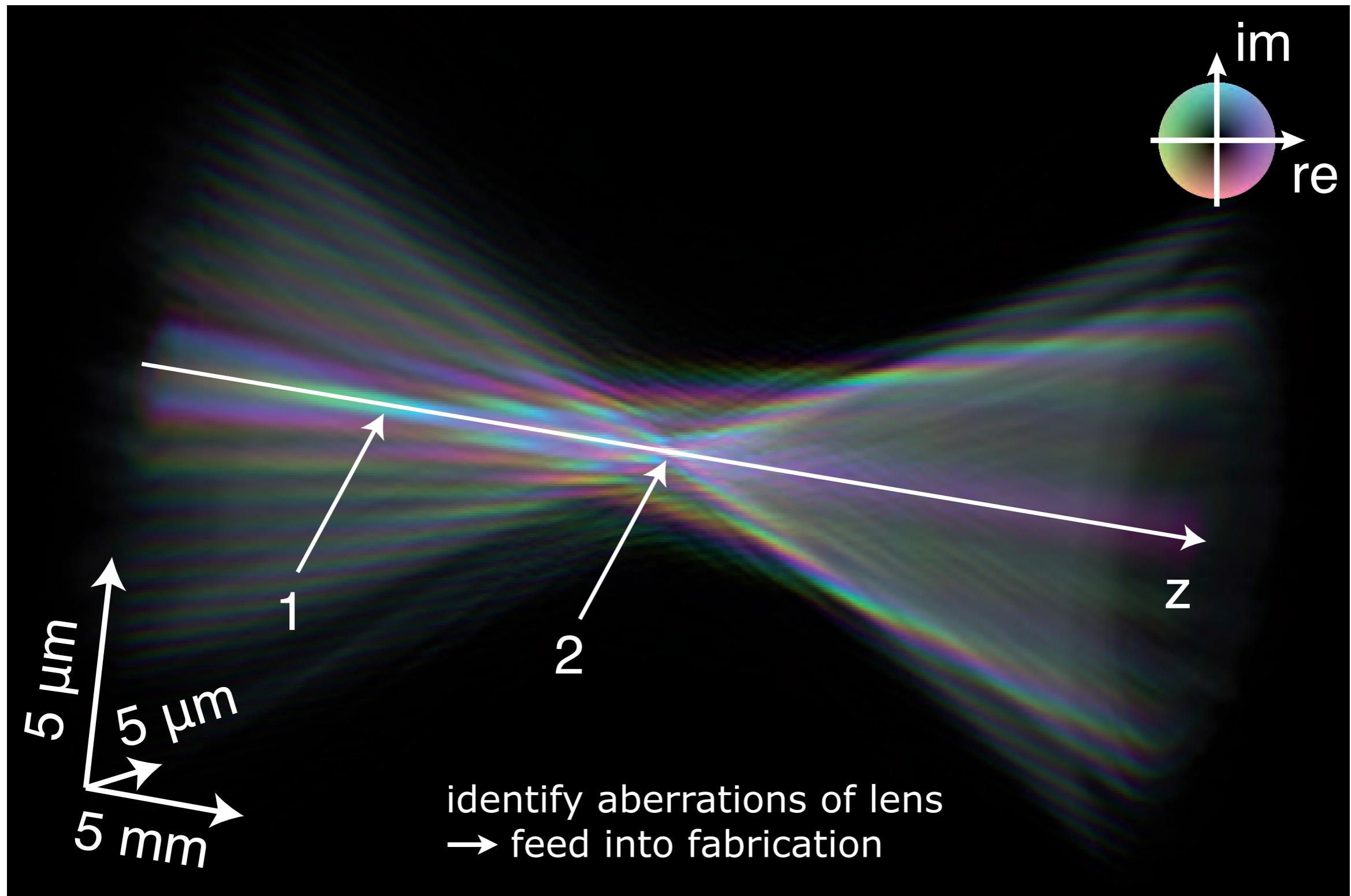
A. Schropp, et al., Sci. Rep. 3, 1633 (2013).

# Ptychographic Reconstruction



A. Schropp, et al., Sci. Rep. 3, 1633 (2013).

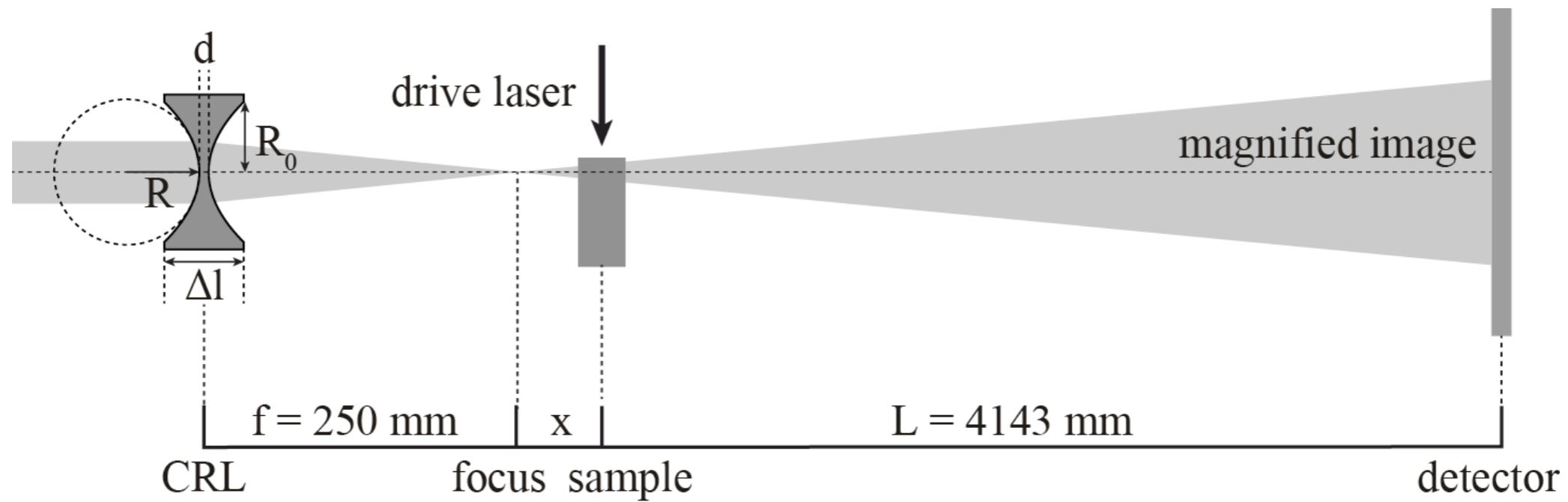
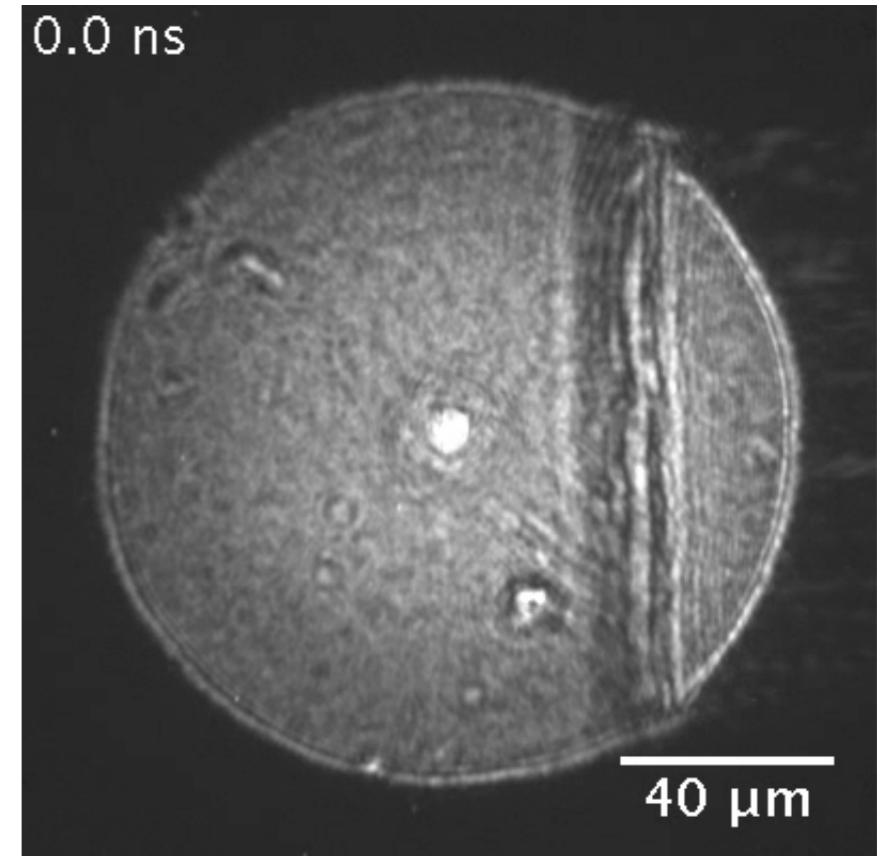
# Nanofocused LCLS Beam Profile



A. Schropp, et al., Sci. Rep. 3, 1633 (2013).

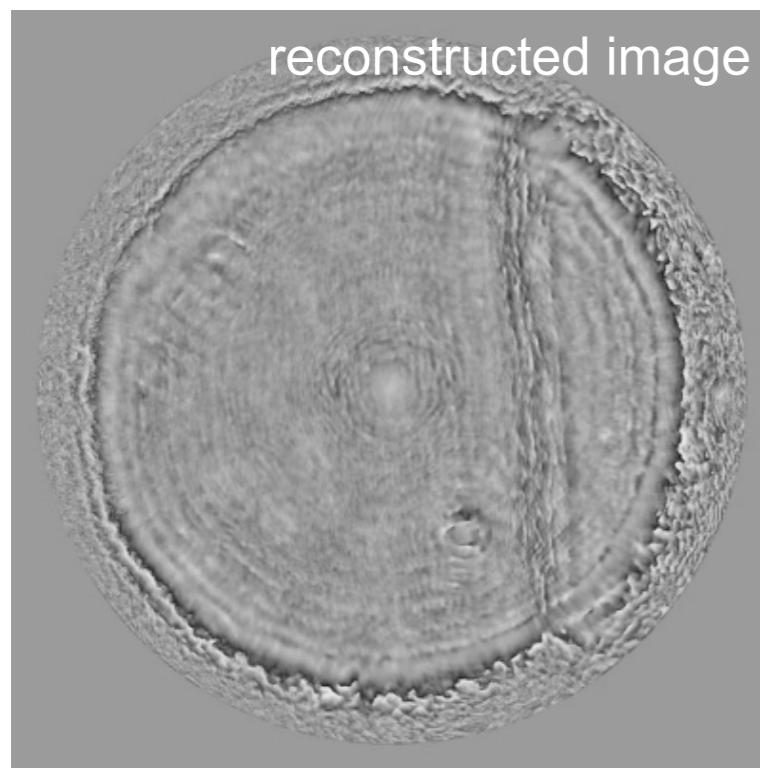
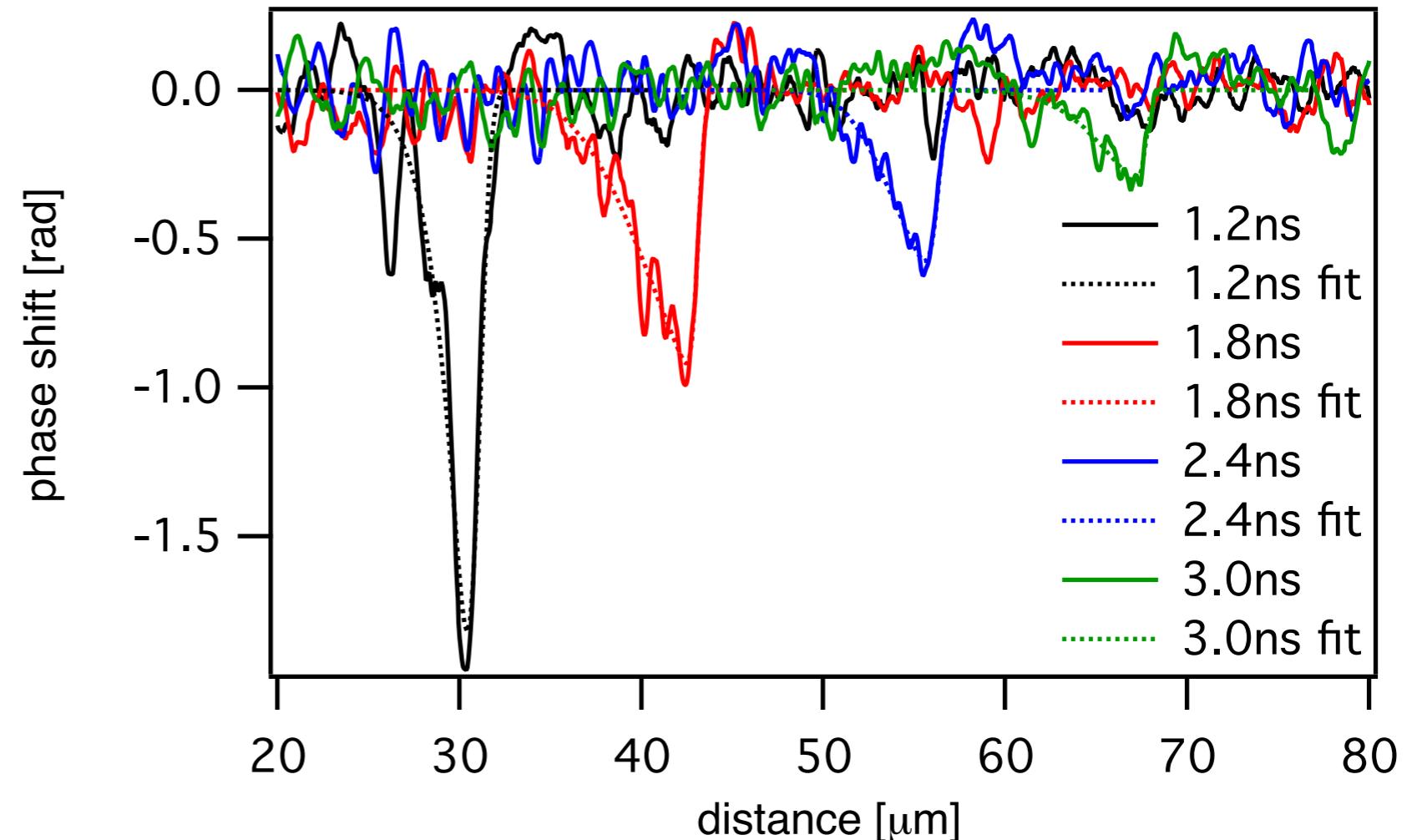
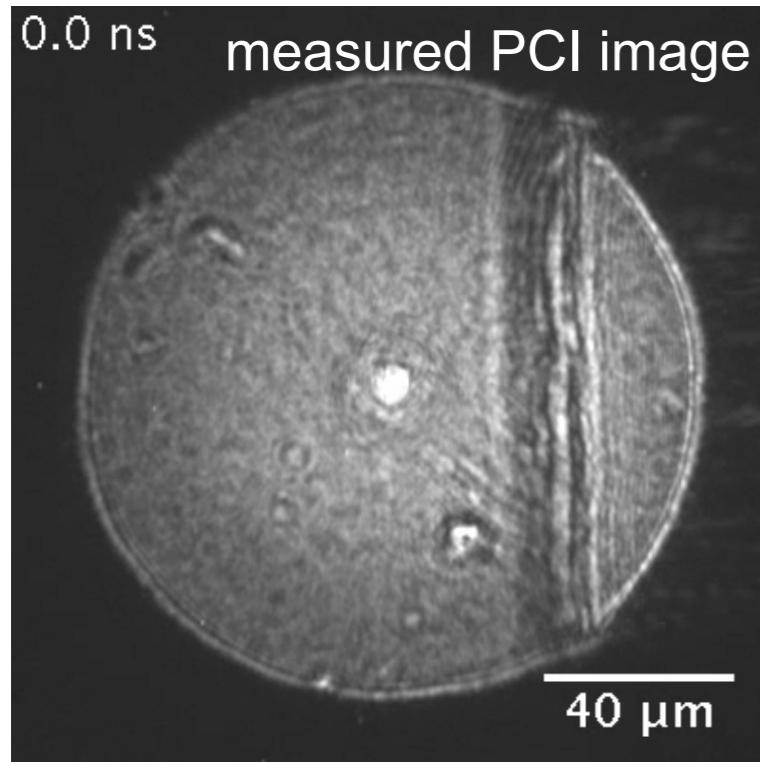
# Elastic Wave in Diamond

- > pump: 150 ps drive laser, 800 nm, 130 mJ
- > probe: XFEL beam:  $E = 8.2 \text{ keV}$ , 50 fs
- > single-pulse imaging (stop-trick movie)
- > pump-probe time delay between 0 ns and 3 ns in steps of 0.2 ns
- > high spatial resolution in the phase contrast image of about 300 - 600 nm
- > phase retrieval required



A. Schropp, et al., Sci. Rep. 5, 11089 (2015).

# Elastic Wave in Diamond



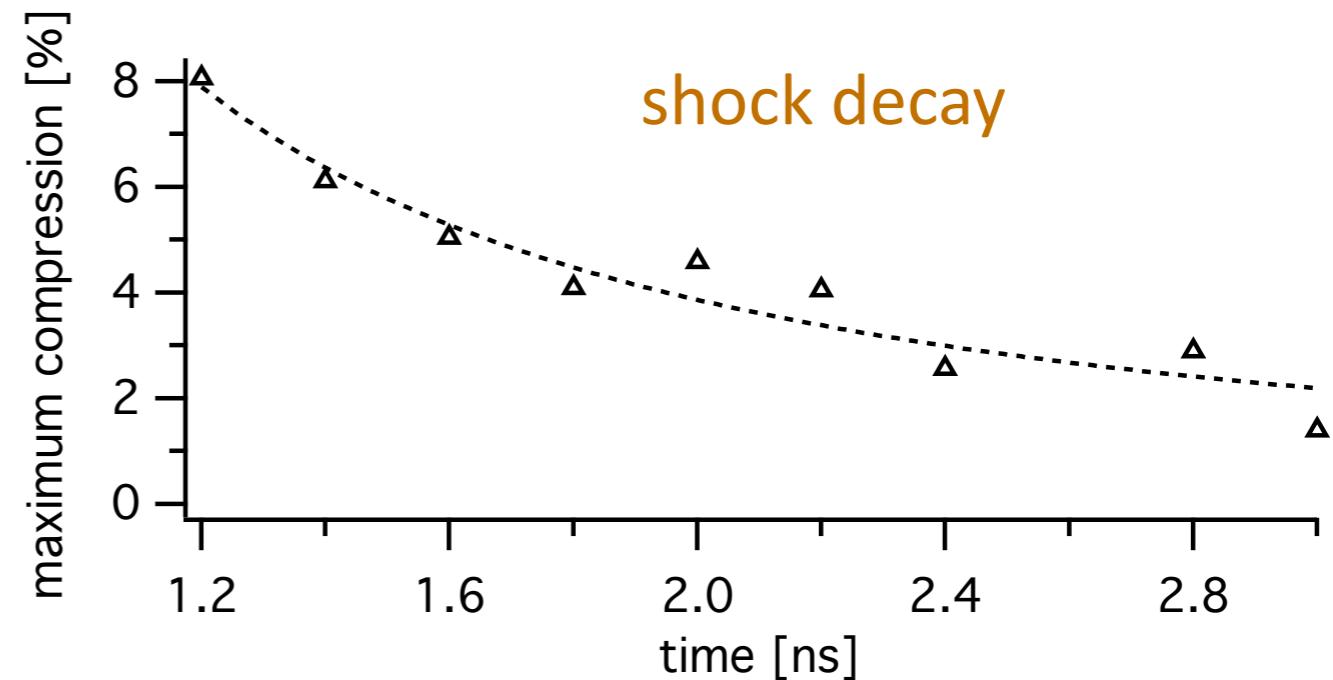
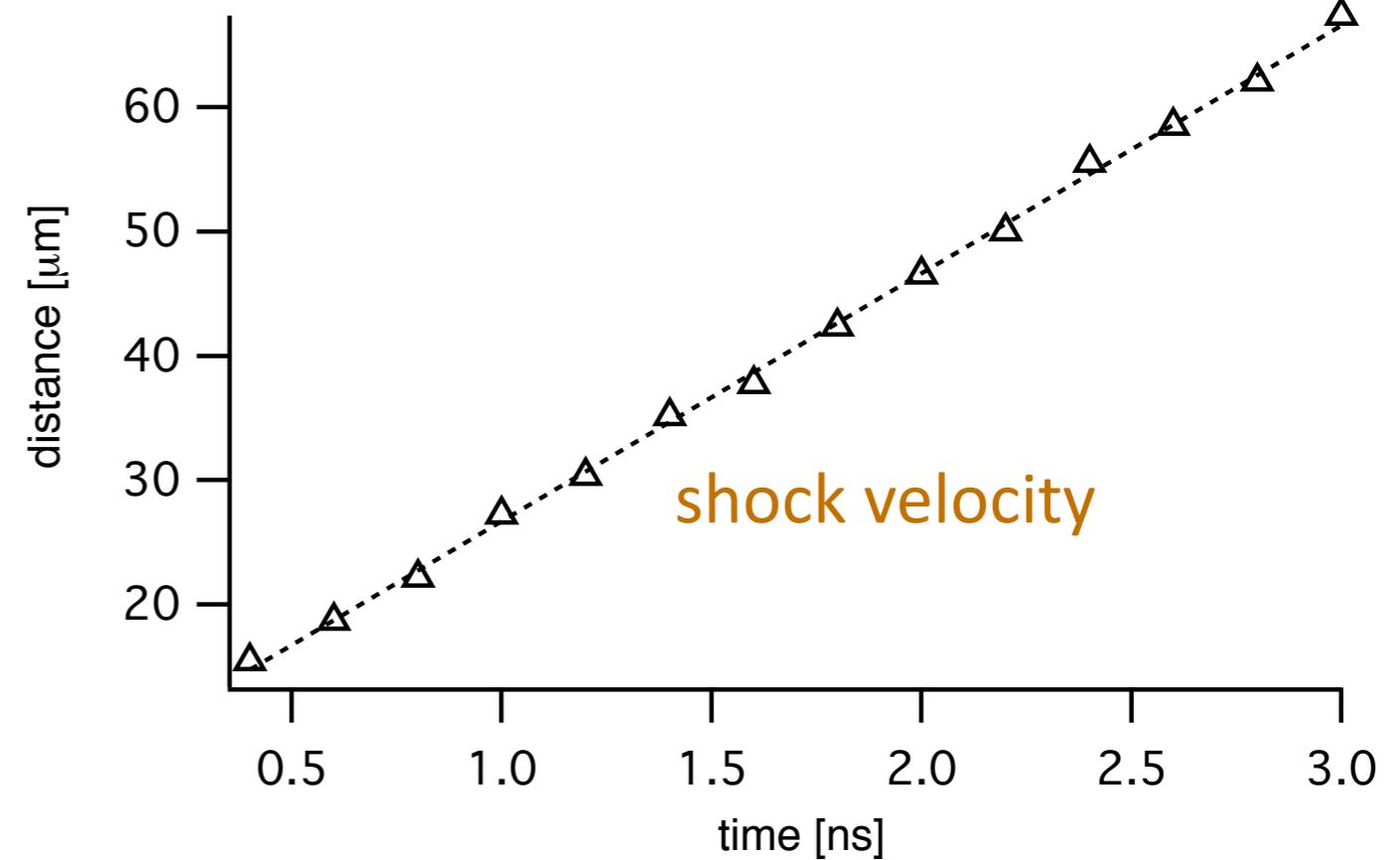
- > shock velocity
- > density distribution with both high spatial and temporal resolution

A. Schropp, et al., Sci. Rep. 5, 11089 (2015).

# Elastic Wave in Diamond

Quantitative information on

- > shock velocity
- > compression values
- > characteristic time scale of shock decay
- > spatial resolution of about 300 nm (SASE)
- > PCI: high sensitivity of about 1% lattice compression (not visible in absorption!)

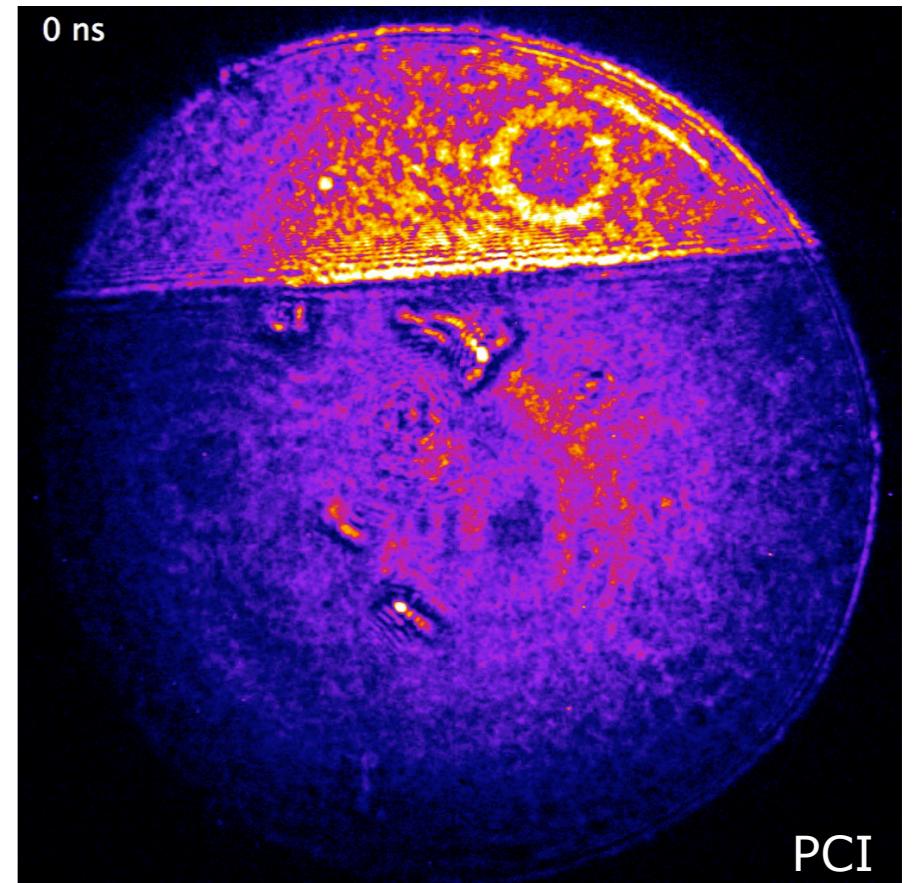
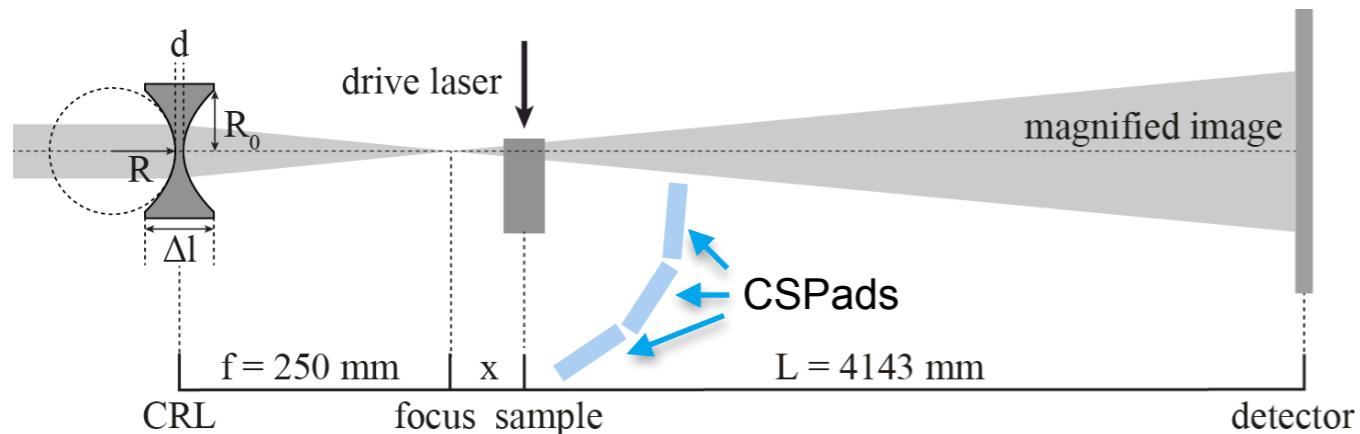


# Combining PCI and WAXS - Shock Wave in Silicon

Combining high-resolution phase-contrast imaging with wide-angle X-ray scattering

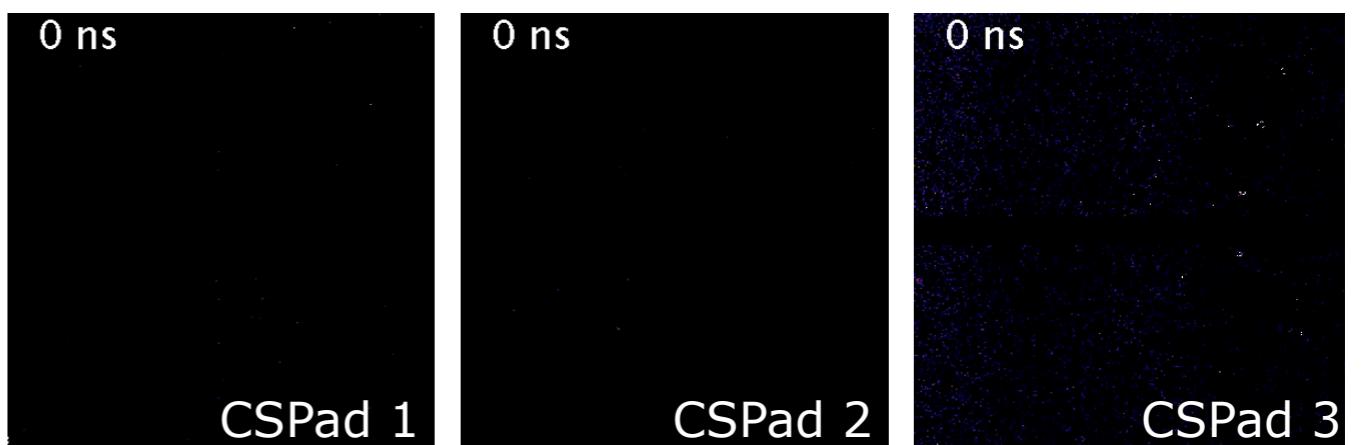
Drive laser parameters:

- > long pulse laser (527 nm)
- > 10 ns, 8 J, ramped pulse shape
- > spot size 30  $\mu\text{m}$  (flat top)



Simultaneous measurement of PCI and wide angle X-ray scattering

- > watch phase transformations in real time
- > material recrystallizes (polycrystalline)



ARTICLE

Received 22 Nov 2016 | Accepted 17 Jan 2017 | Published 1 Mar 2017

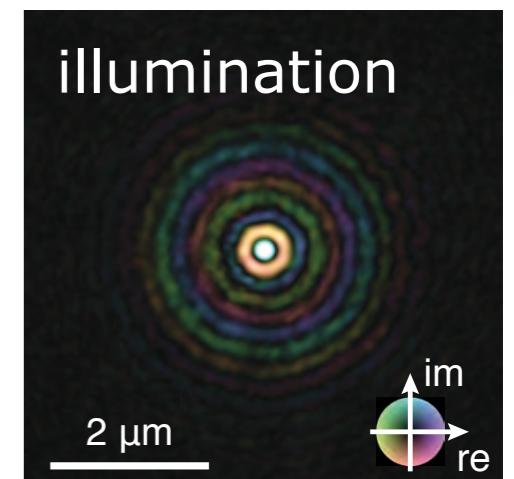
DOI: 10.1038/ncomms14623

OPEN

# Perfect X-ray focusing via fitting corrective glasses to aberrated optics

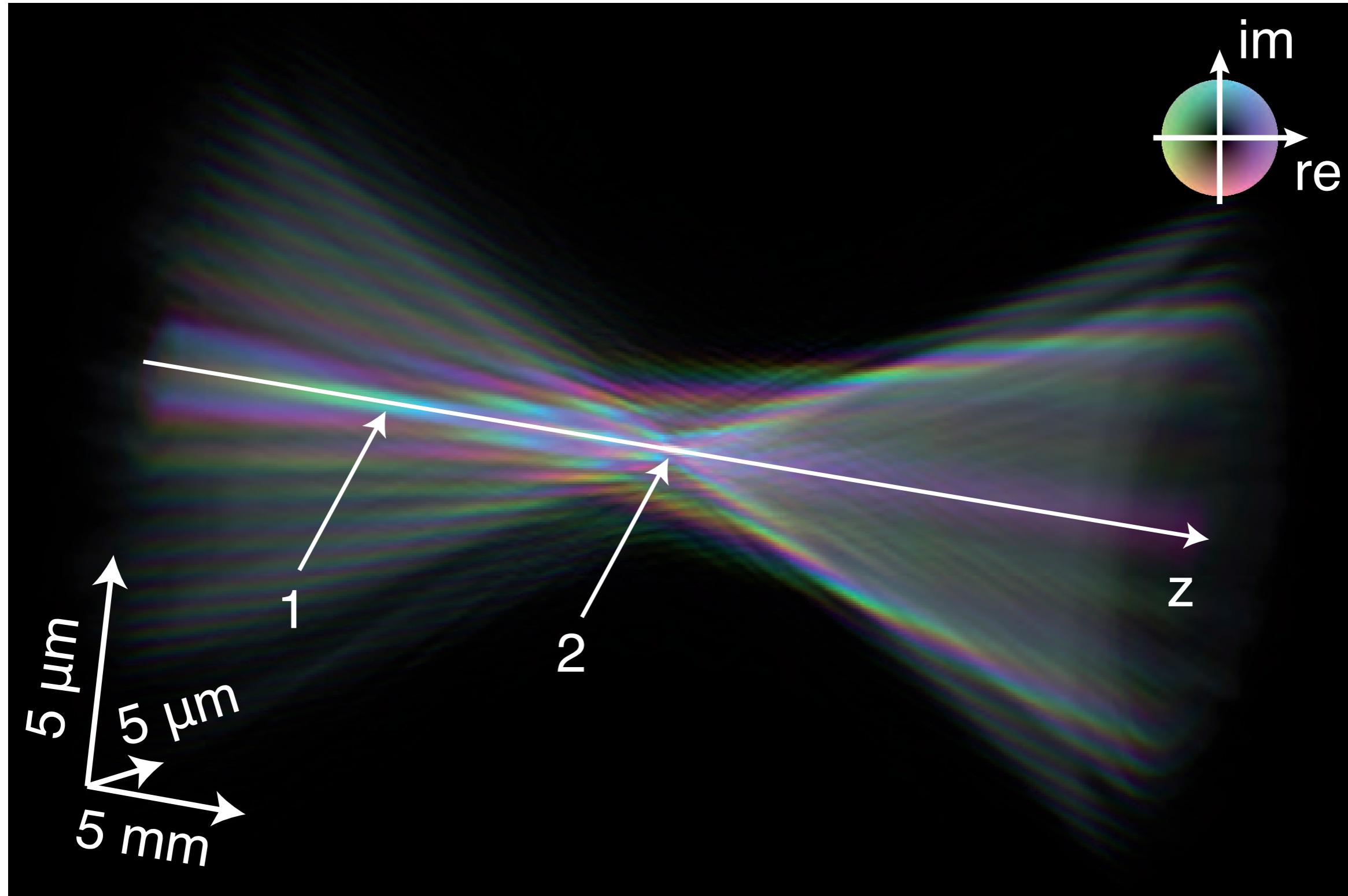
Frank Seiboth<sup>1,†</sup>, Andreas Schropp<sup>2</sup>, Maria Scholz<sup>2</sup>, Felix Wittwer<sup>1,2</sup>, Christian Rödel<sup>3,4</sup>, Martin Wünsche<sup>3</sup>, Tobias Ullsperger<sup>5</sup>, Stefan Nolte<sup>5</sup>, Jussi Rahomäki<sup>6</sup>, Karolis Parfeniukas<sup>6</sup>, Stylianos Giakoumidis<sup>6</sup>, Ulrich Vogt<sup>6</sup>, Ulrich Wagner<sup>7</sup>, Christoph Rau<sup>7</sup>, Ulrike Boesenberg<sup>2</sup>, Jan Garrevoet<sup>2</sup>, Gerald Falkenberg<sup>2</sup>, Eric C. Galtier<sup>4</sup>, Hae Ja Lee<sup>4</sup>, Bob Nagler<sup>4</sup> & Christian G. Schroer<sup>2,8</sup>

- wave-field near focus known from ptychography
- propagate wavefield to exit of optic ➤ determine phase error
- make corrective phase plate to measure  
➤ eliminate spherical aberration: perfect focusing



F. Seiboth, *et al.*, Nat. Commun. **8**, 14623 (2017).

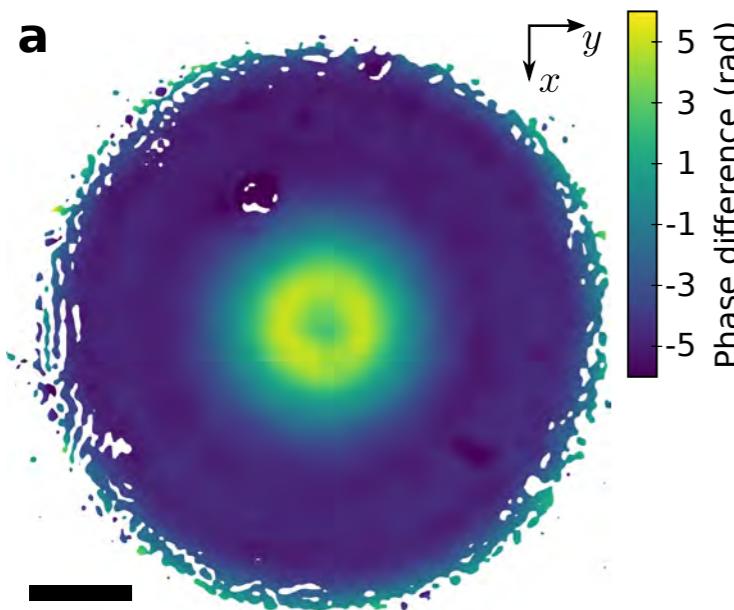
# Nanofocused Free-Electron Laser Beam Profile



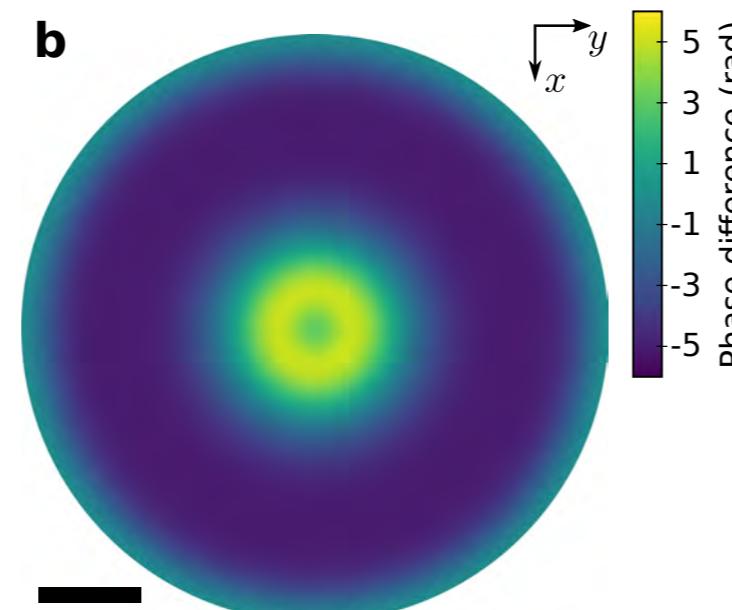
A. Schropp, et al., Sci. Rep. 3, 1633 (2013).

# Aberrations: Determination of Lens Shape and Error

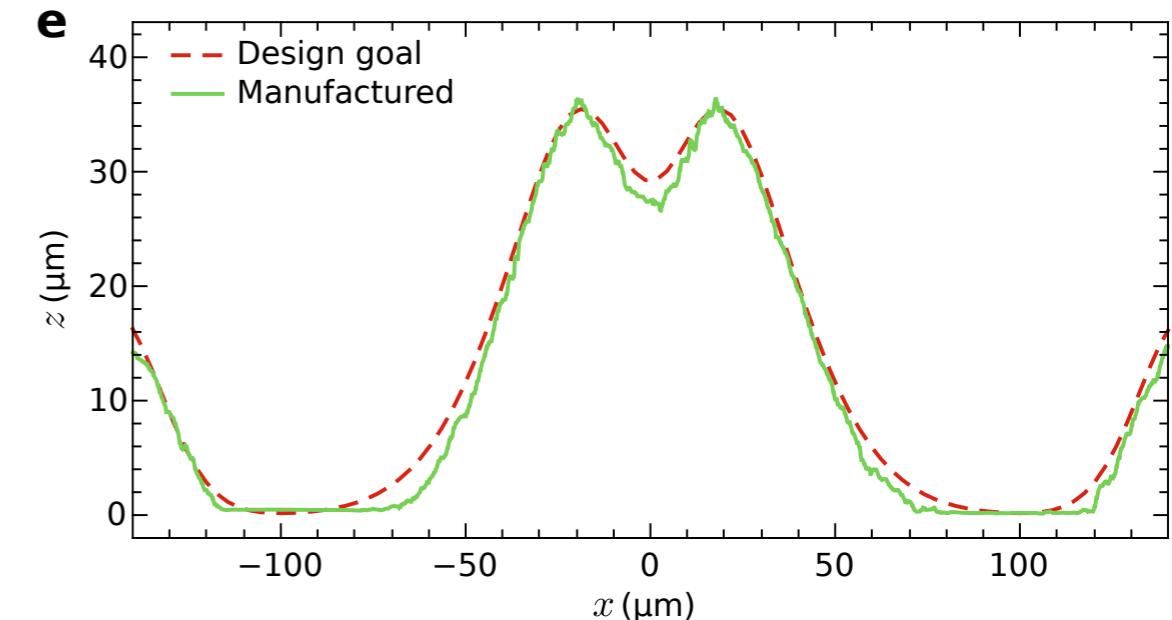
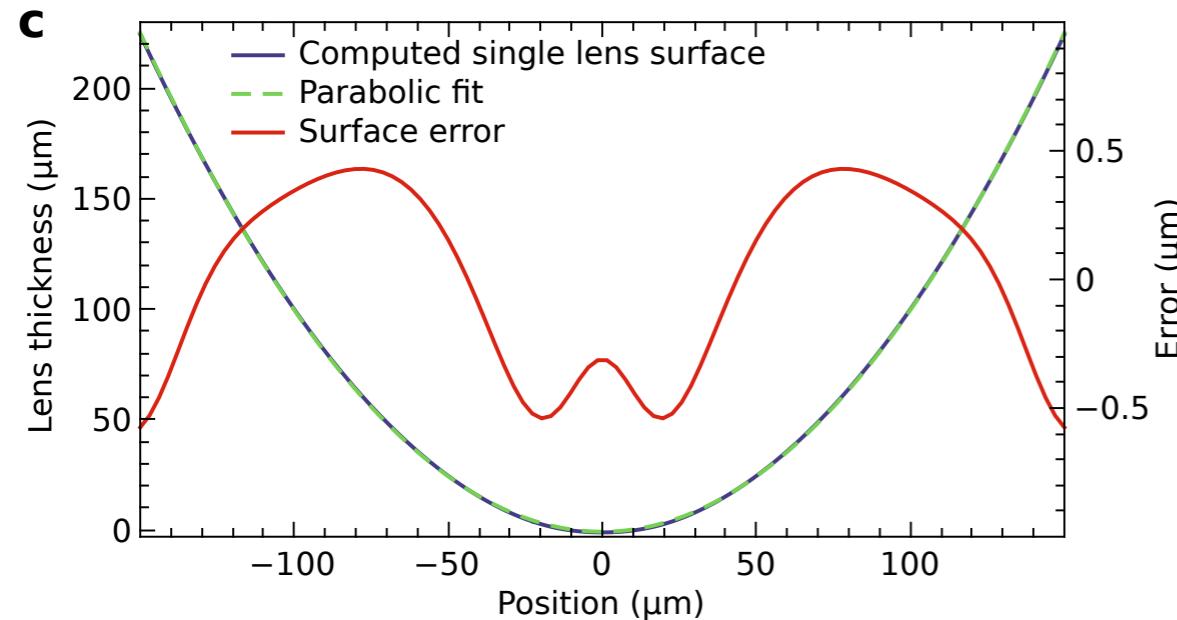
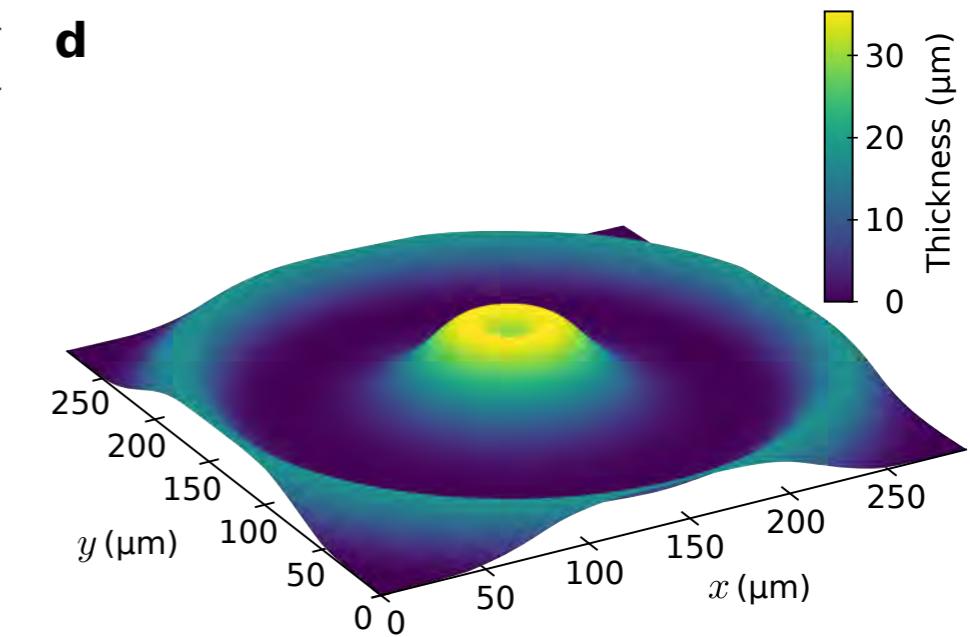
measured phase error



modelled phase error



modelled phase plate

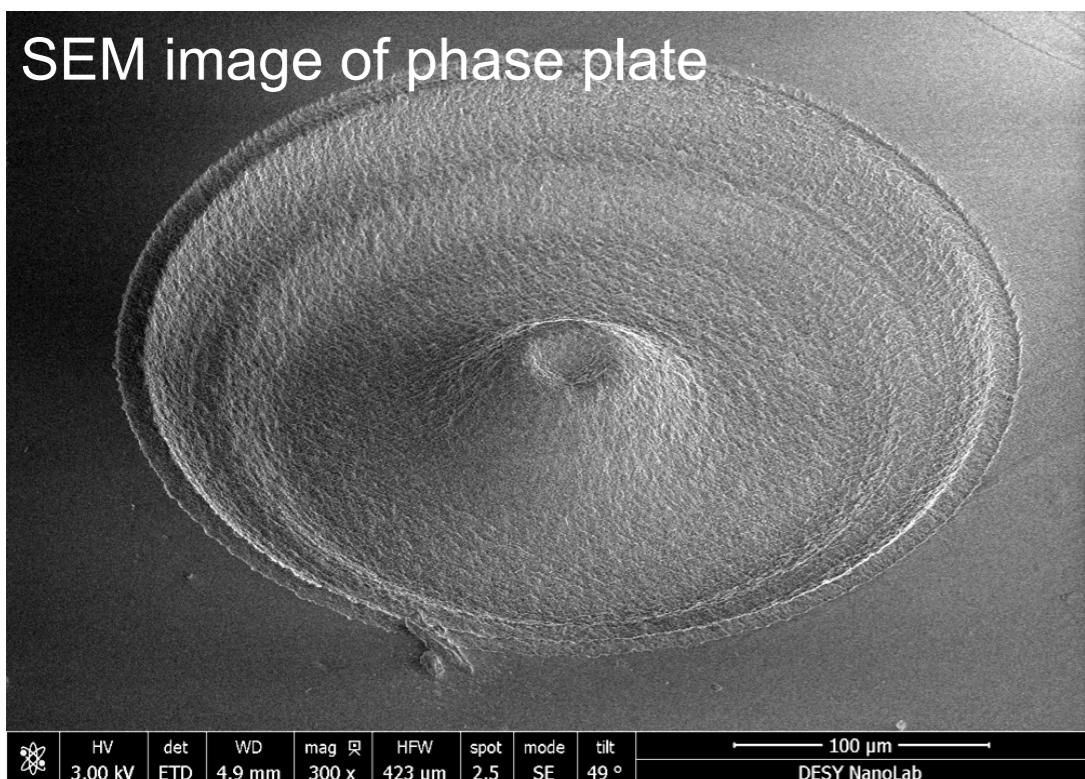


- Shape errors of single Be-CRLs are smaller than 500 nm! Very challenging to improve!
- phase plate for whole stack of lenses easier to fabricate.

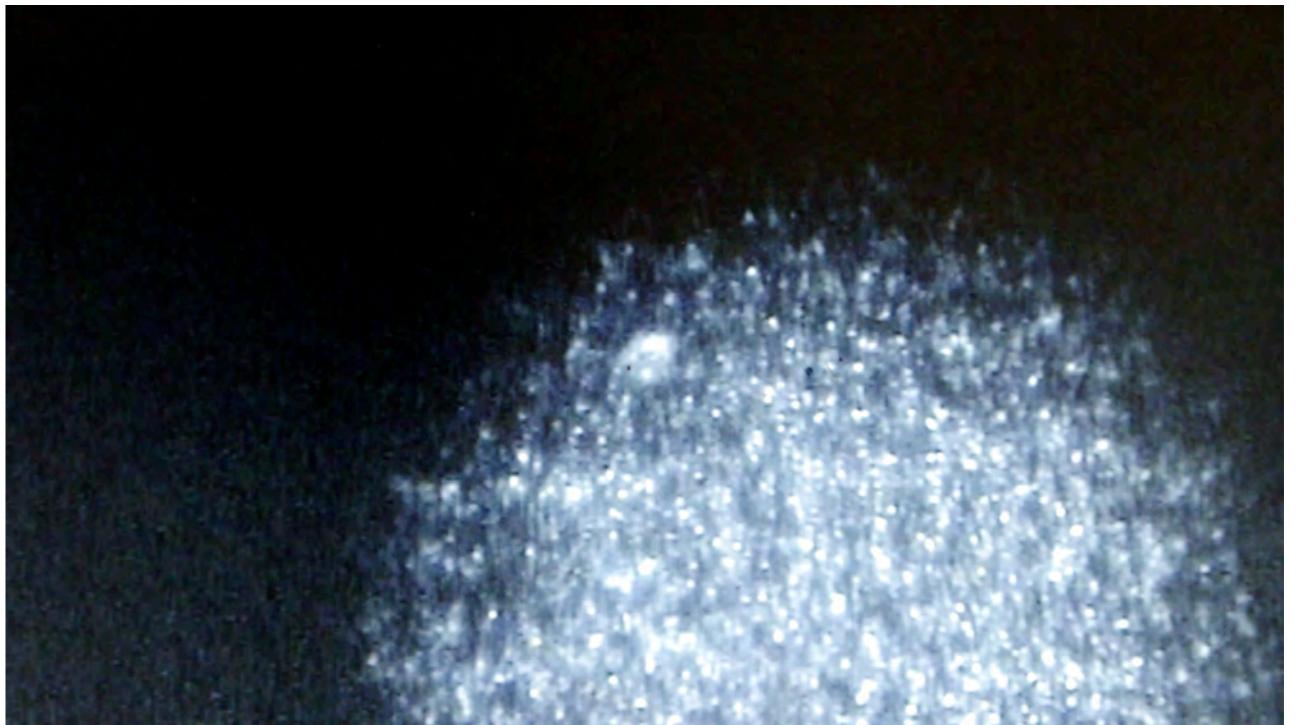
F. Seiboth, et al., Nat. Commun. **8**, 14623 (2017).

# Aberration Correction: Fabrication of Phase Plate

- > For given lens set, make phase plate to measure
- > accumulated phase error is more easily corrected
- > transmission optic not sensitive to roughness



F. Seiboth, et al., Nat. Commun. 8, 14623 (2017).

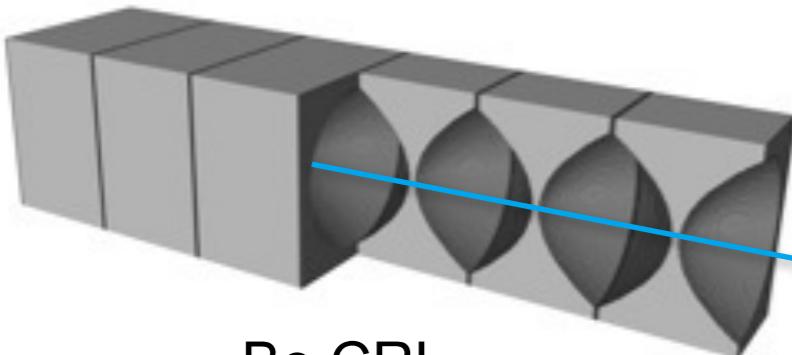
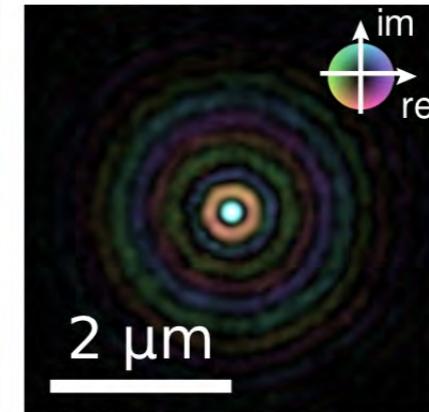
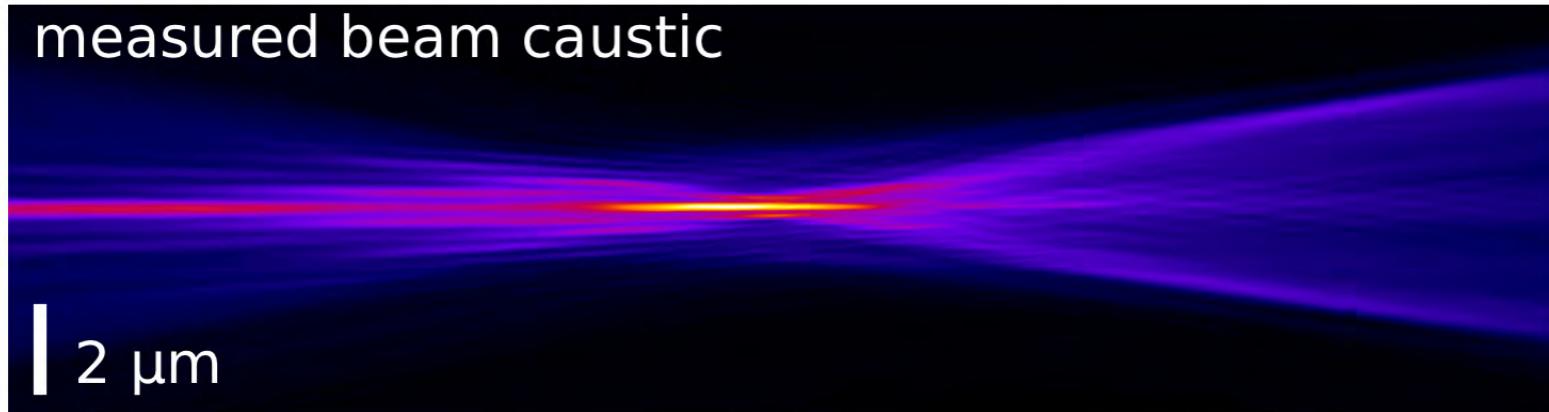


University of Jena:  
Fabrication of corrective phase plate  
by laser ablation:

- > 8 ps pulses
- > 1030 nm wavelength
- > 0.2 mJ pulse energy
- > focused to substrate with NA = 0.4
- > removed layer thickness ~ 1 μm

# Aberration Correction: Experimental Verification

measured beam caustic

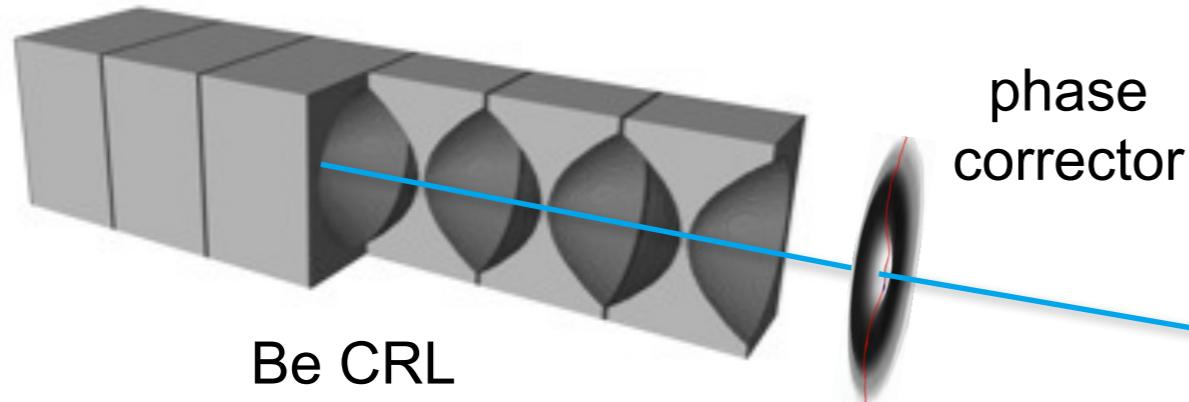
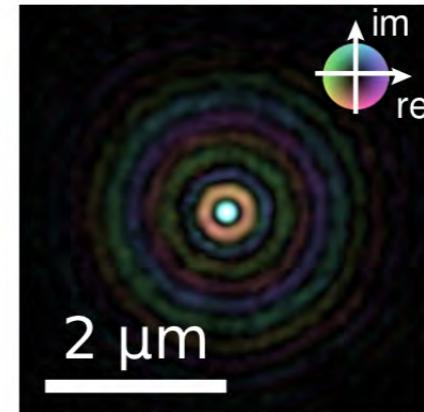
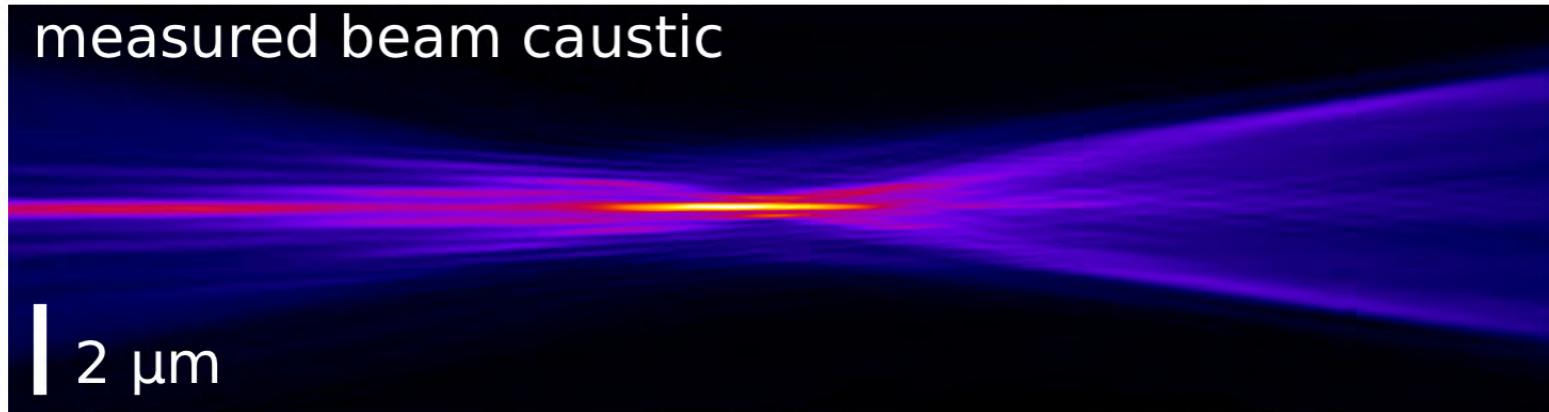


Be CRL

Ptychographic verification  
of focusing properties

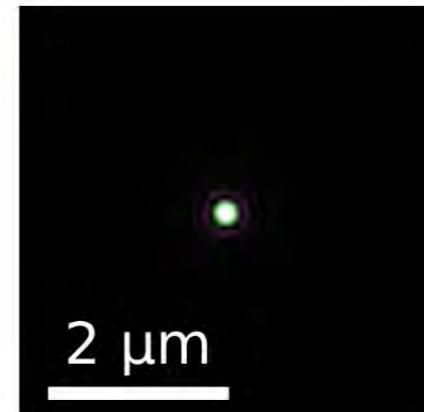
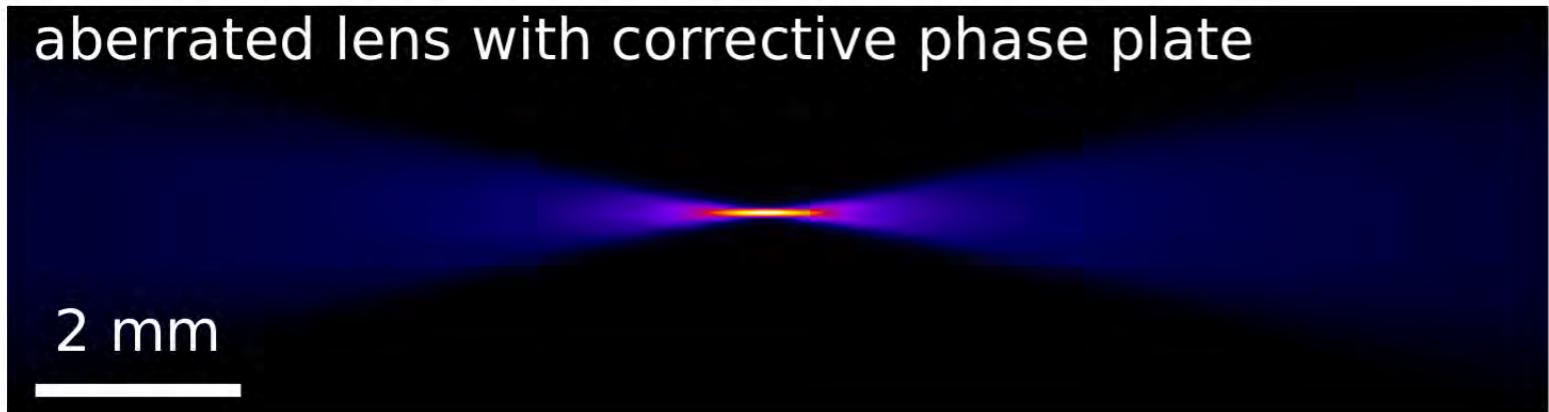
# Aberration Correction: Experimental Verification

measured beam caustic



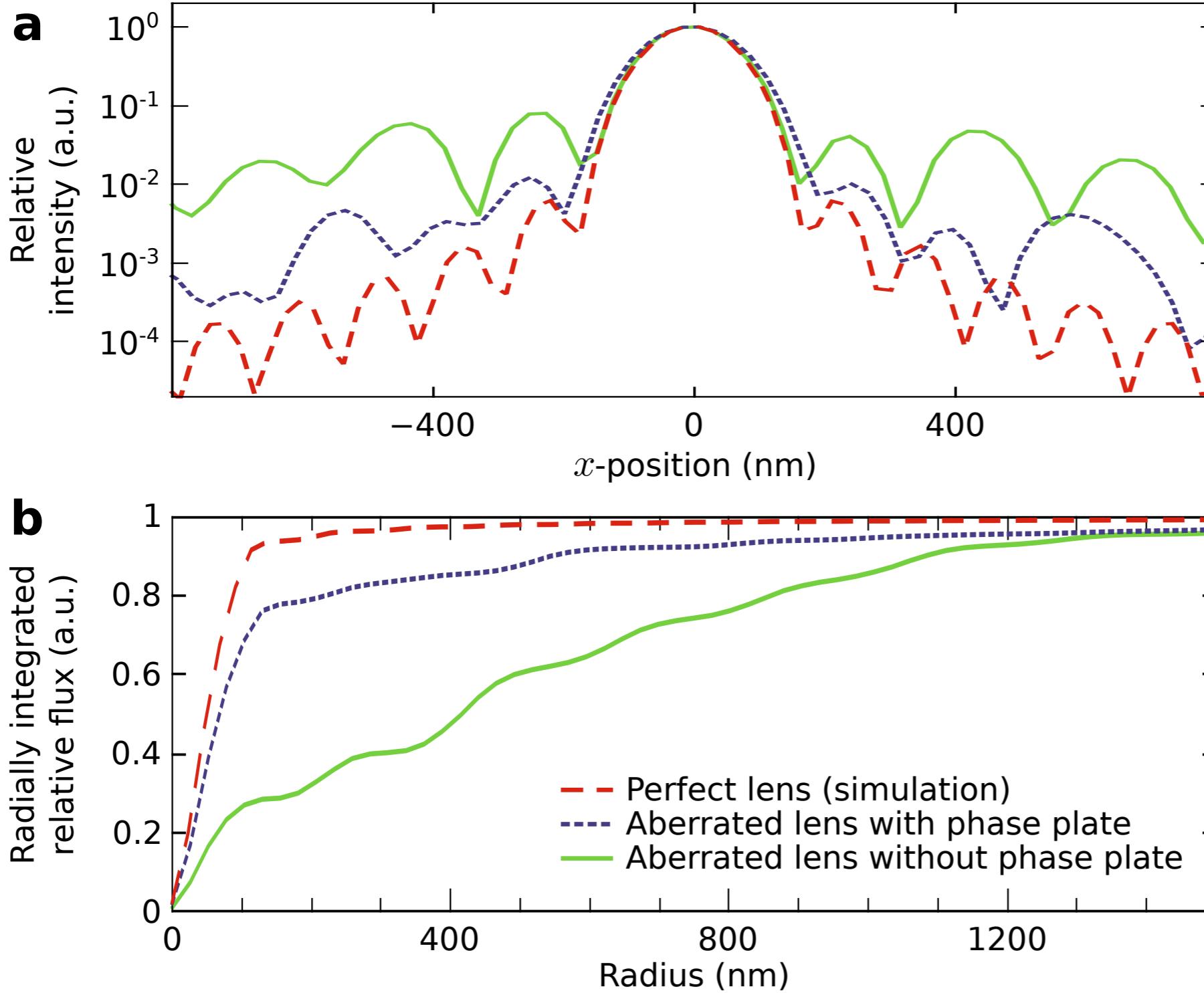
Ptychographic verification  
of focusing properties

aberrated lens with corrective phase plate



F. Seiboth, et al., Nat. Commun. 8, 14623 (2017).

# Aberration Correction: Experimental Verification



Lens with  
Strehl ratio > 0.8!

75 % of the radiation  
are concentrated in  
the central speckle!



Focus full beam!

F. Seiboth, et al., Nat. Commun. 8, 14623 (2017).

# Conclusion & Outlook: An X-ray Microscopists Dream

Quantitive in-situ measurement of physical properties of matter

- > on all relevant length scales → (in principle) from Å to millimeters
- > on all relevant time scales

Key technology: brilliant, coherent X-rays with time structure

Requirements:

Fusion of real and reciprocal space!

- > high coherent flux
  - X-ray free-electron lasers
  - diffraction-limited storage rings (PETRA IV, ...)
- > efficient nanofocusing
  - aberration-free optics with high numerical aperture
- > stability on nanometer scale

